Cause, Detection, and Impact of Charge Trapping on Aging

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An electronic version of this presentation containing all animations is available at
http://www.iue.tuwien.ac.at/pdf/ib_2011/VLSI_Grasser_2011.pdf

Idealized Aging Mechanisms

In order to characterize degradation, stress is accelerated

    Idealized stress conditions are defined

Time-dependent dielectric breakdown (TDDB)

    Very large gate voltages $\Rightarrow$ oxide loses insulating property

Bias temperature instability (BTI)

    S/D grounded, elevated temperature
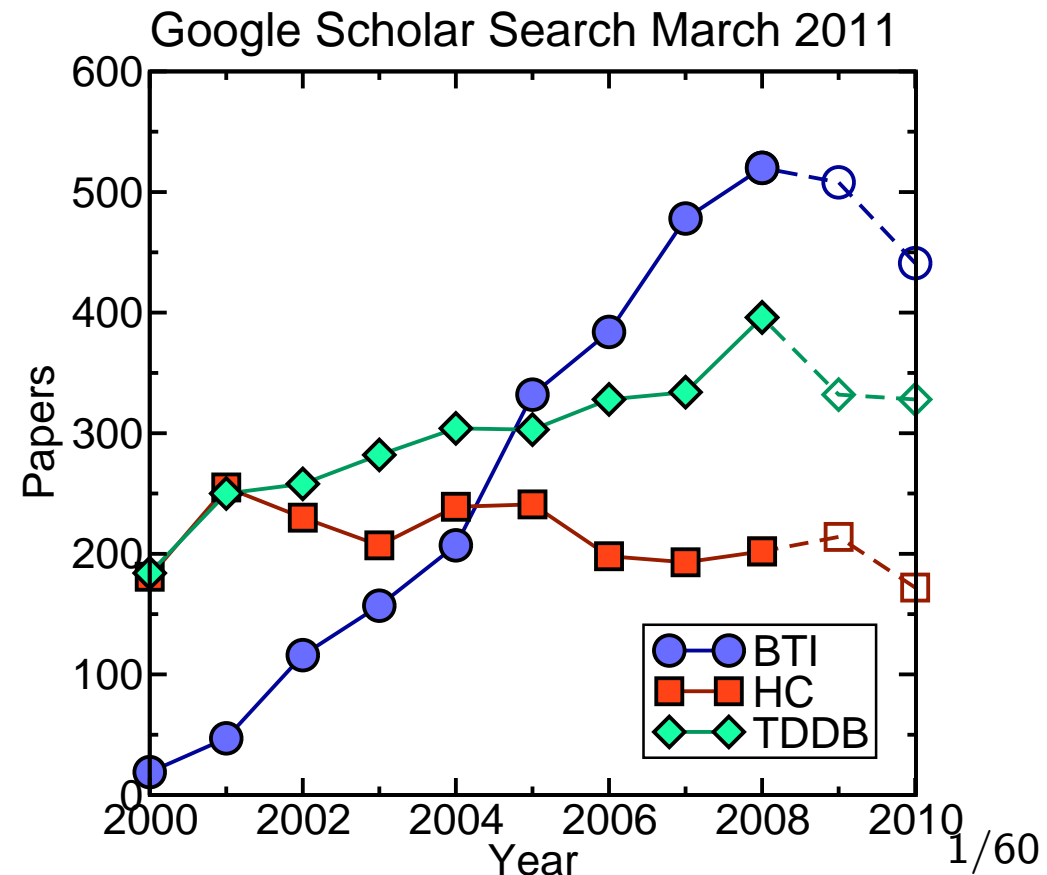
    pMOS: $-V_G \Rightarrow$ NBTI

    nMOS: $+V_G \Rightarrow$ PBTI (mostly high-κ)

Hot carrier (HC) degradation

    Current flow between S/D

Circuit:

    All of the above in a mixed form!

Time Dependent Dielectric Breakdown
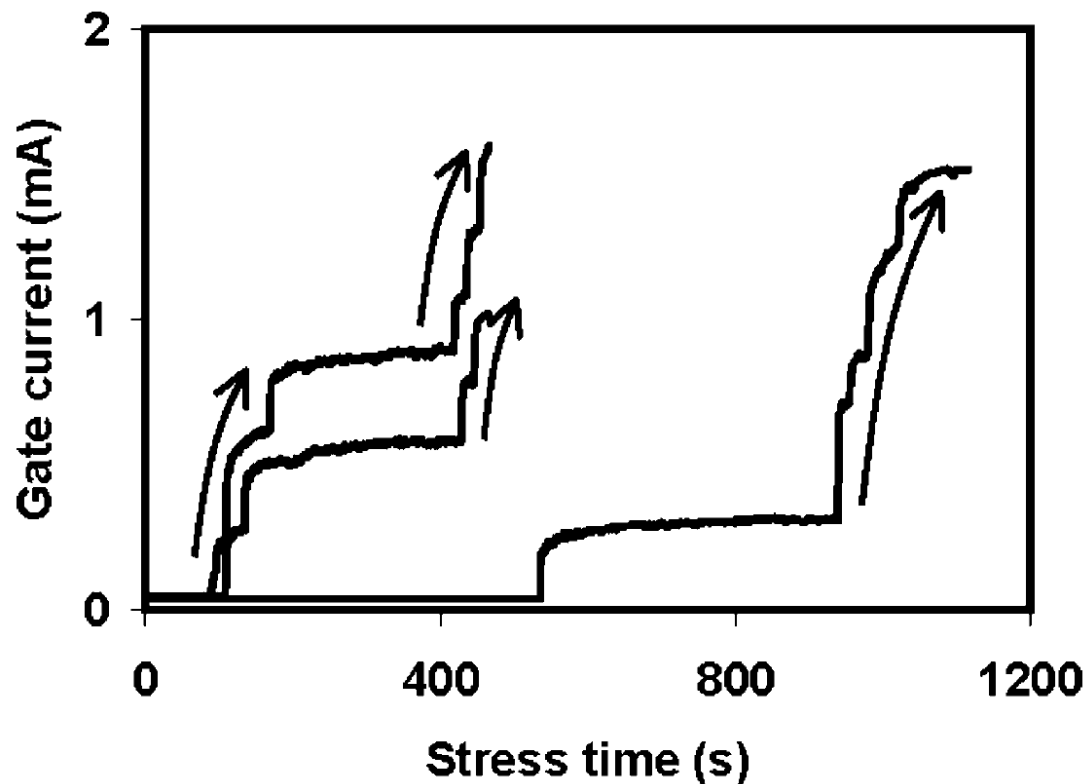
Very large voltages applied to the gate

Larger than about $10\,\text{MV/cm}$

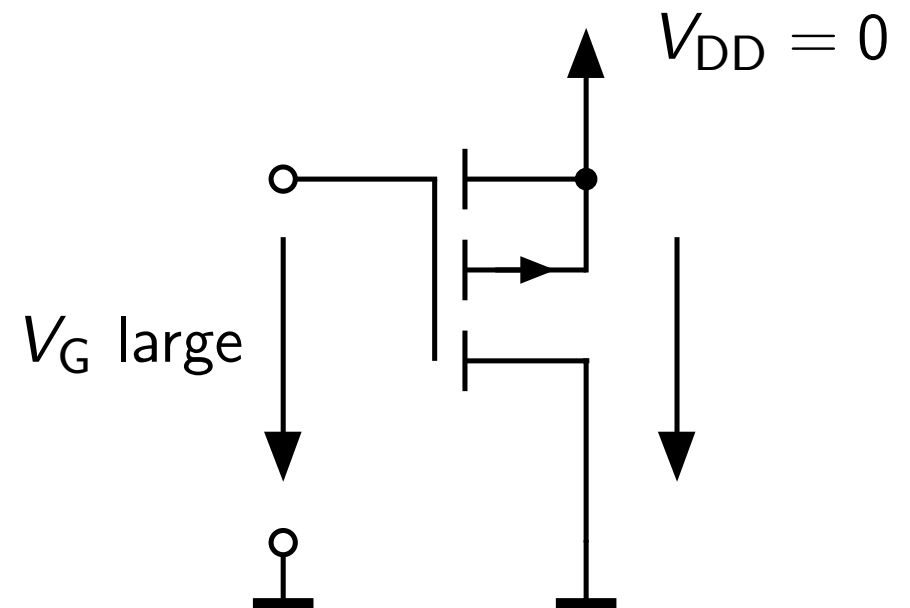All other terminals grounded

Cause of degradation: creation of defects (conducting paths in the oxide)

Oxide loses insulating property

Soft and hard breakdowns

[Sune *et al.*, T-ED '04]

The Negative Bias Temperature Instability

Large negative voltage applied to the gate of a PMOS (NBTI)

> Larger than about $4\,\mathrm{MV/cm}$
>
> All other terminals grounded

Elevated temperatures (NBTI)

> Typically $125\,^\circ\mathrm{C}$

Cause of degradation: oxide charges and defects

> Drift of V_th, g_m, etc.

$$V_\mathrm{DD} = 0$$

$$V_\mathrm{G} < 0$$

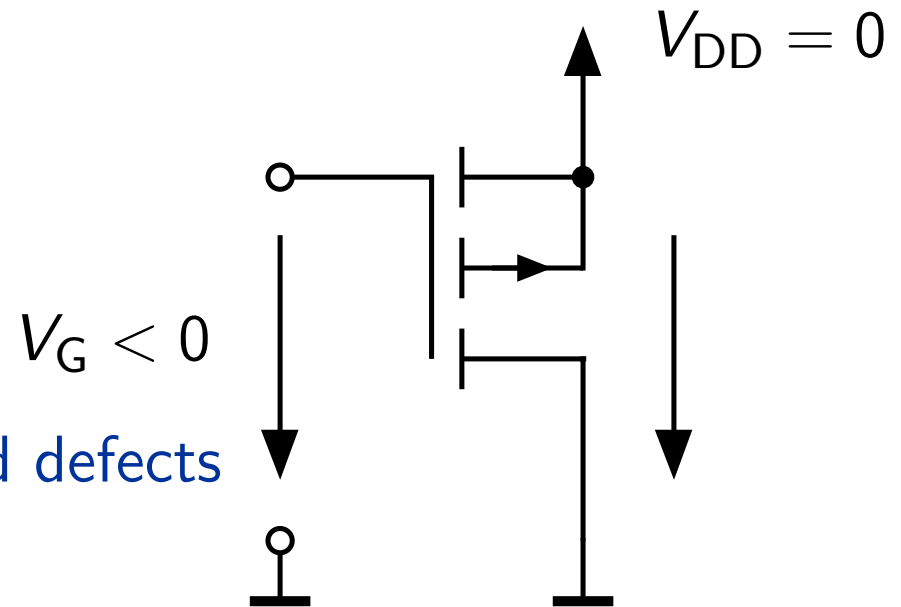Degradation occurs in all four configurations

> NMOS/PMOS
>
> Negative and positive stress voltages
>
> NBTI in PMOS most important
>
> In high-k NMOSFETs, PBTI equally important

Note:

> Degradation occurs also at room temperature and voltages slightly larger than V_th

Hot Carrier Degradation

Voltages applied to both gate and drain

Like BTI, but with current flow from S/D

Carriers become 'hot' as they traverse the channel

Excess energy can create defects at drain side
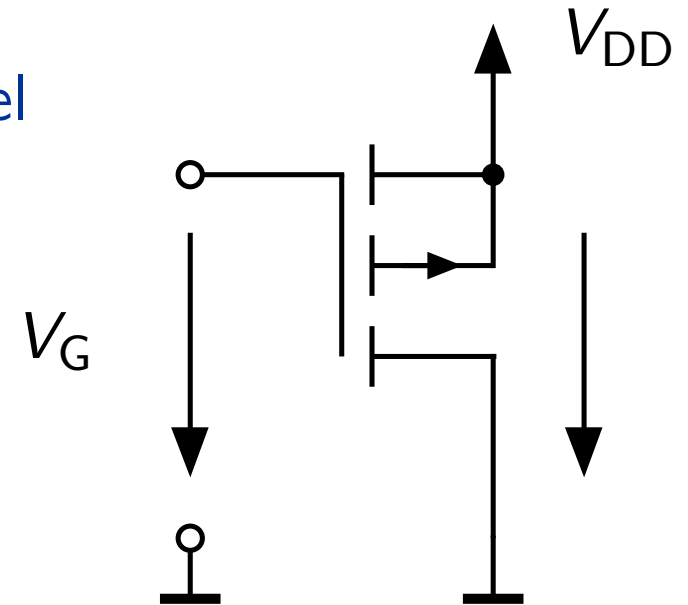
Cause of degradation: oxide charges and defects

Drift of V_{th}, g_{m}, etc.

Very similar to BTI, except:

Inhomogeneous degradation at the drain side

Degradation does not recover that well

Degradation typ. becomes weaker with increasing T

V_{DD}

V_{G}

NBTI vs. HC Degradation

In a circuit NBTI and HC degradation can occur simultaneously

Separation using modified ring-oscillators[1]

Feedback interruptable by control circuitry

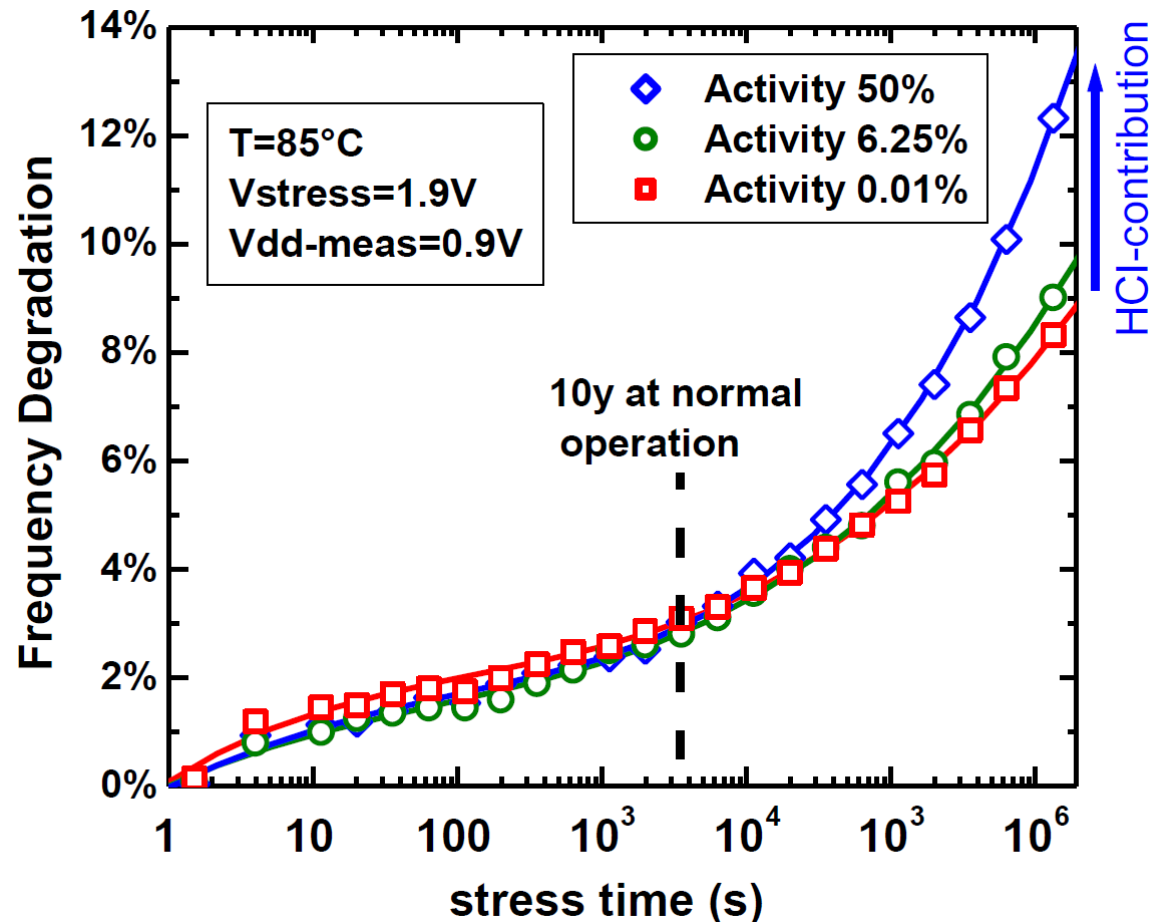Allows separation of BTI and HCI

Activity 50%: BTI + HCI

Activity 0.01%: Almost static BTI

At normal operating conditions

Degradation NBTI dominated

At least for combinatorial logic
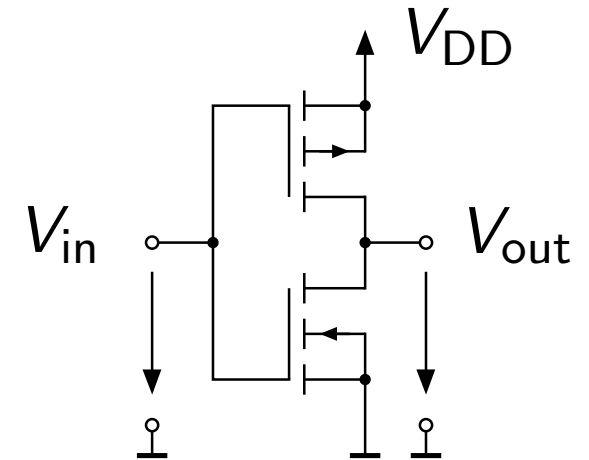

[1] Hofmann *et al.*, VLSI Symp. '10

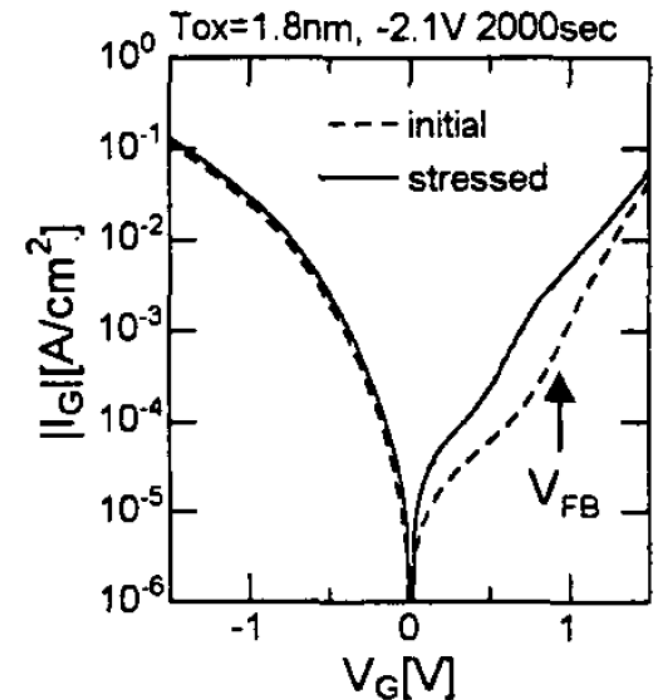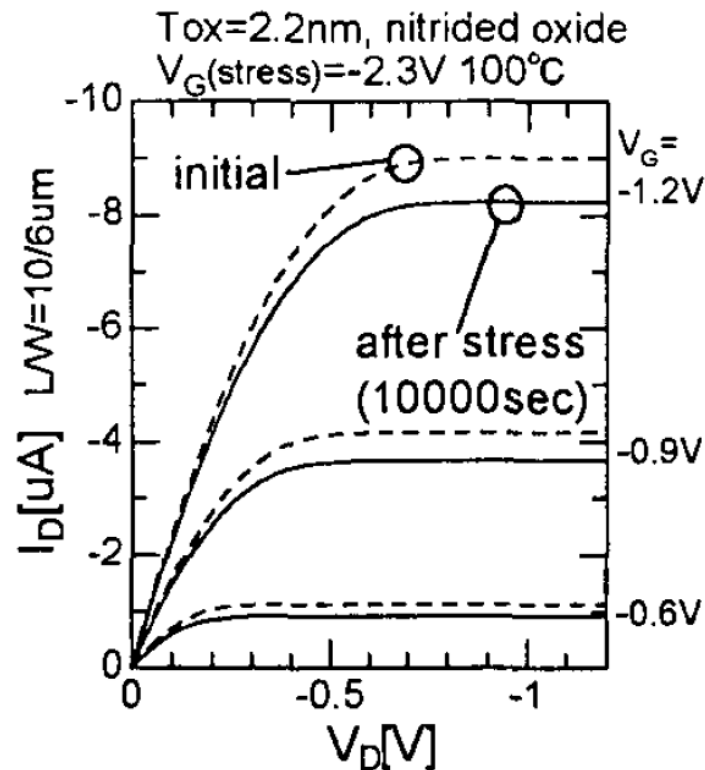# The Negative Bias Temperature Instability
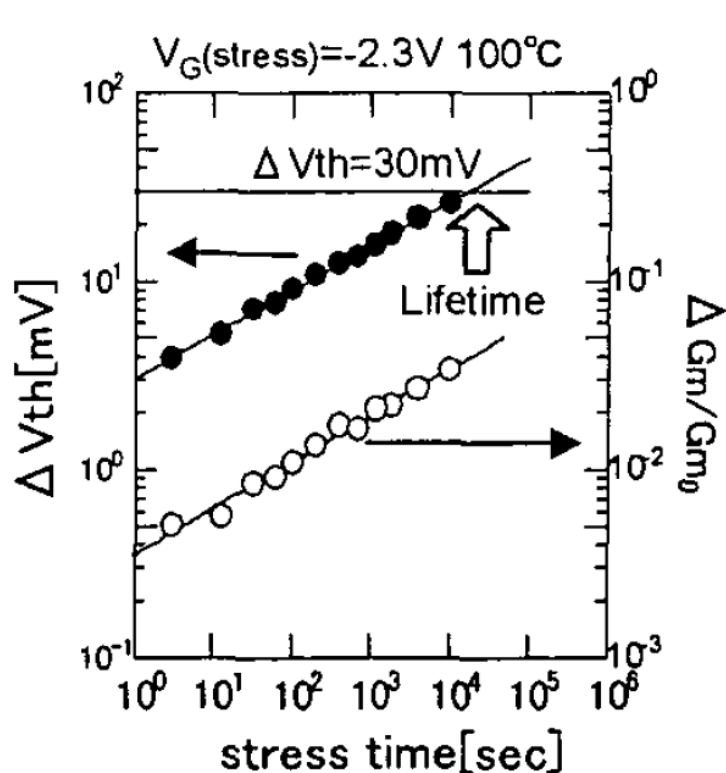
When does the NBTI scenario occur?

NBTI: $V_G \ll 0\,V$, $V_S = V_D = 0\,V$

Example: inverter with $V_{in} = 0\,V$

Similar scenarios in ring-oscillators, SRAM cells, etc.

What happens to the pMOS transistor?

Kimizuka *et al.*, VLSI Symp. '00

Most popularized model for NBTI

Reaction-diffusion theory

Stress

Si–H breaks

Creation of Si–•

H diffuses away

2 H form H_2

H_2 diffusion controls kinetics

Interface | **Oxide Bulk**

Si

H^0

H_2

Conventional NBTI Model

Most popularized model for NBTI

    Reaction-diffusion theory

Stress

    Si–H breaks
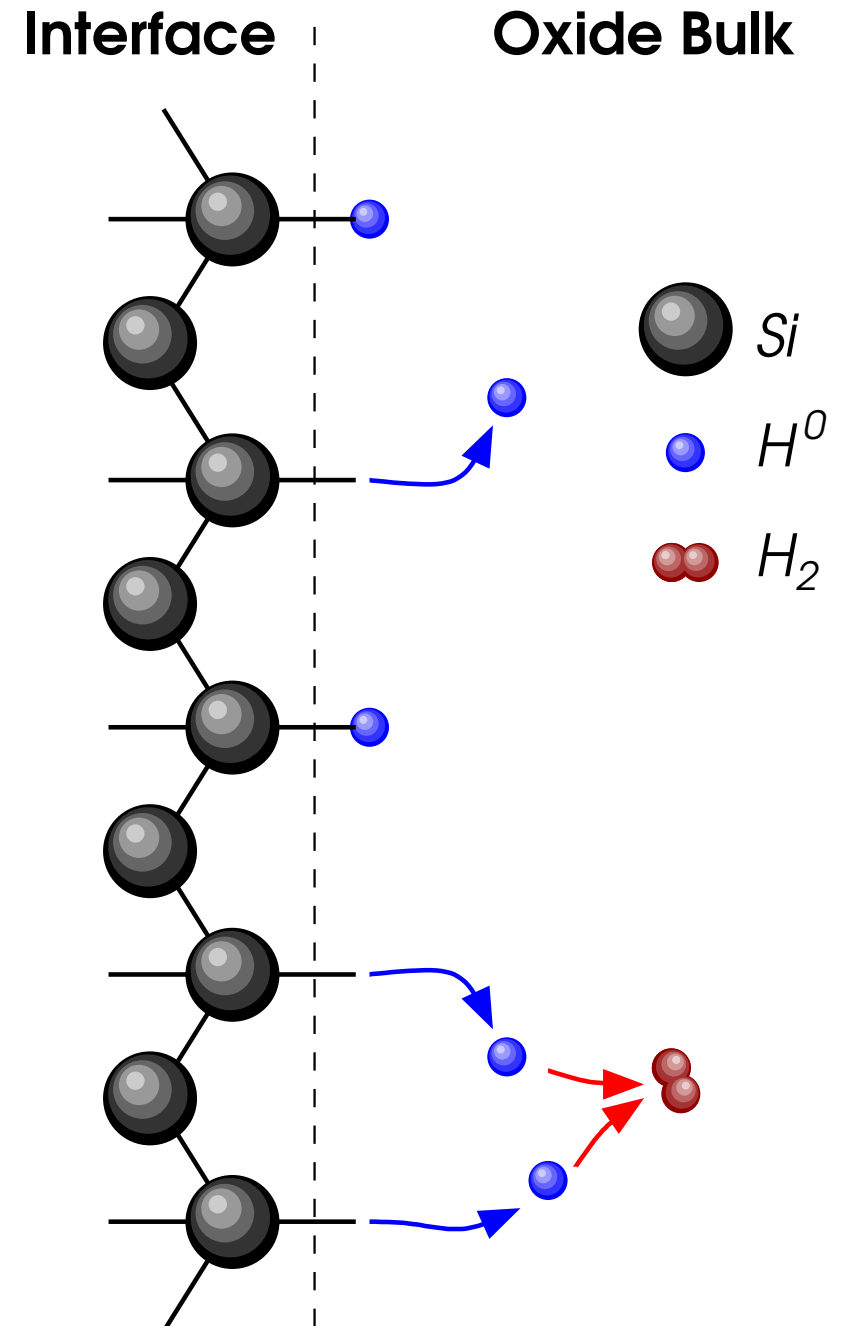
    Creation of Si–$^\bullet$

    H diffuses away

    2 H form H_2
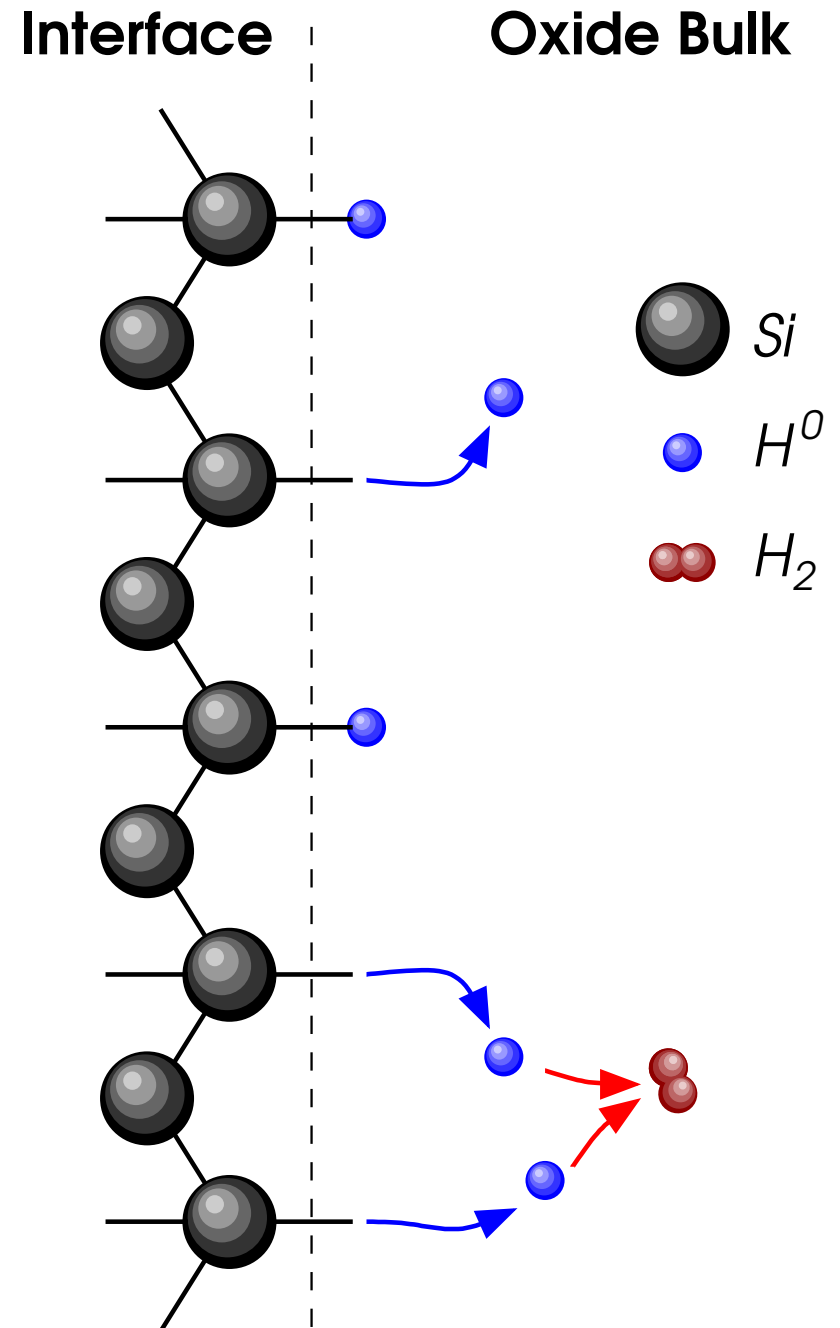
    H_2 diffusion controls kinetics

Recovery

    H_2 repassivates Si–$^\bullet$

    H_2 back-diffusion controls kinetics

Si

H^0

H_2

Conventional NBTI Model

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    Reaction-diffusion theory

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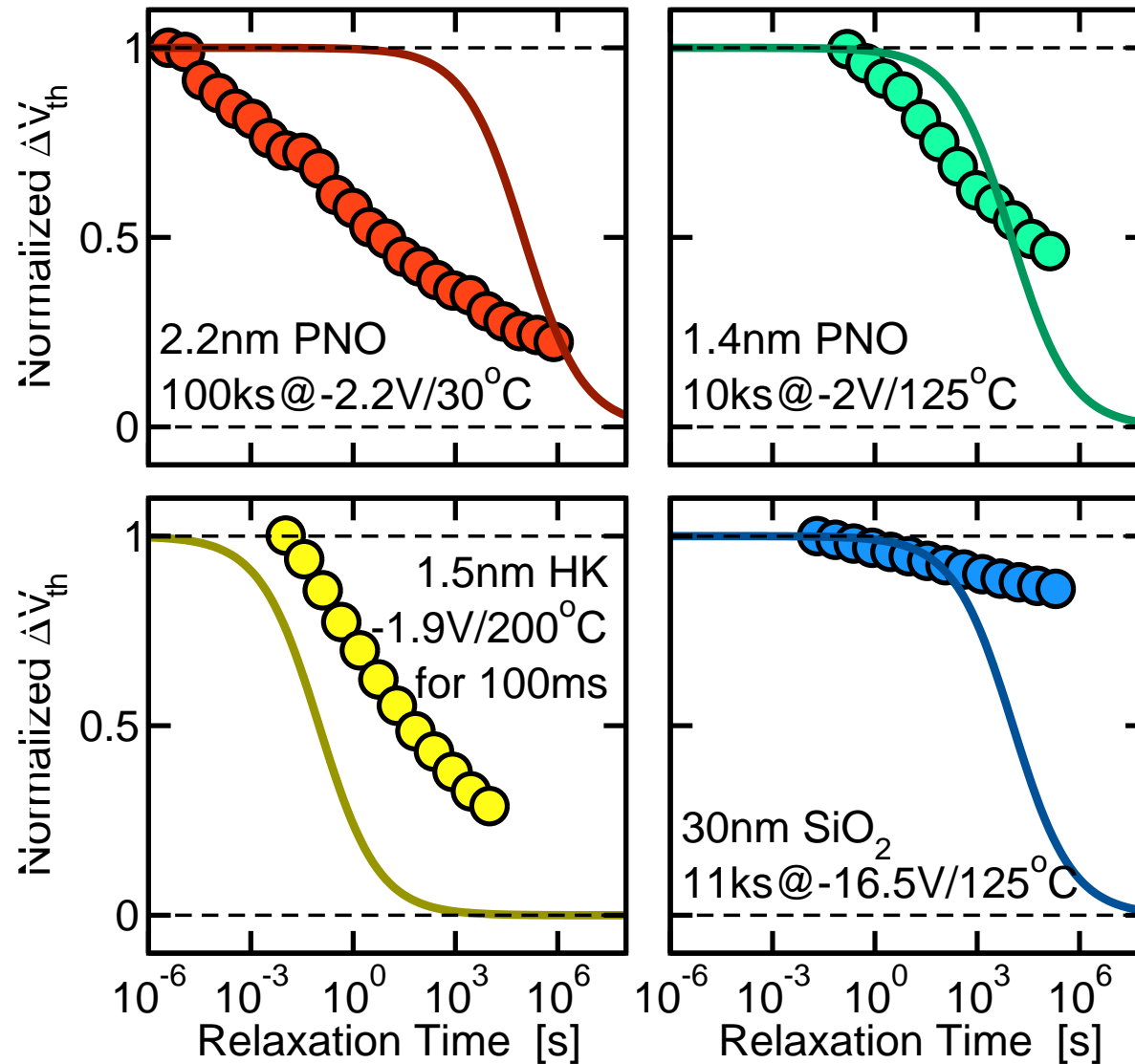
Hole trapping

    Obscures data up to 1 s

    Has to be 'subtracted'

Interface   **Oxide Bulk**

Si

H^0

H_2

Reaction-diffusion (RD) theory

Problem #1: cannot reproduce recovery

Reaction-diffusion (RD) theory
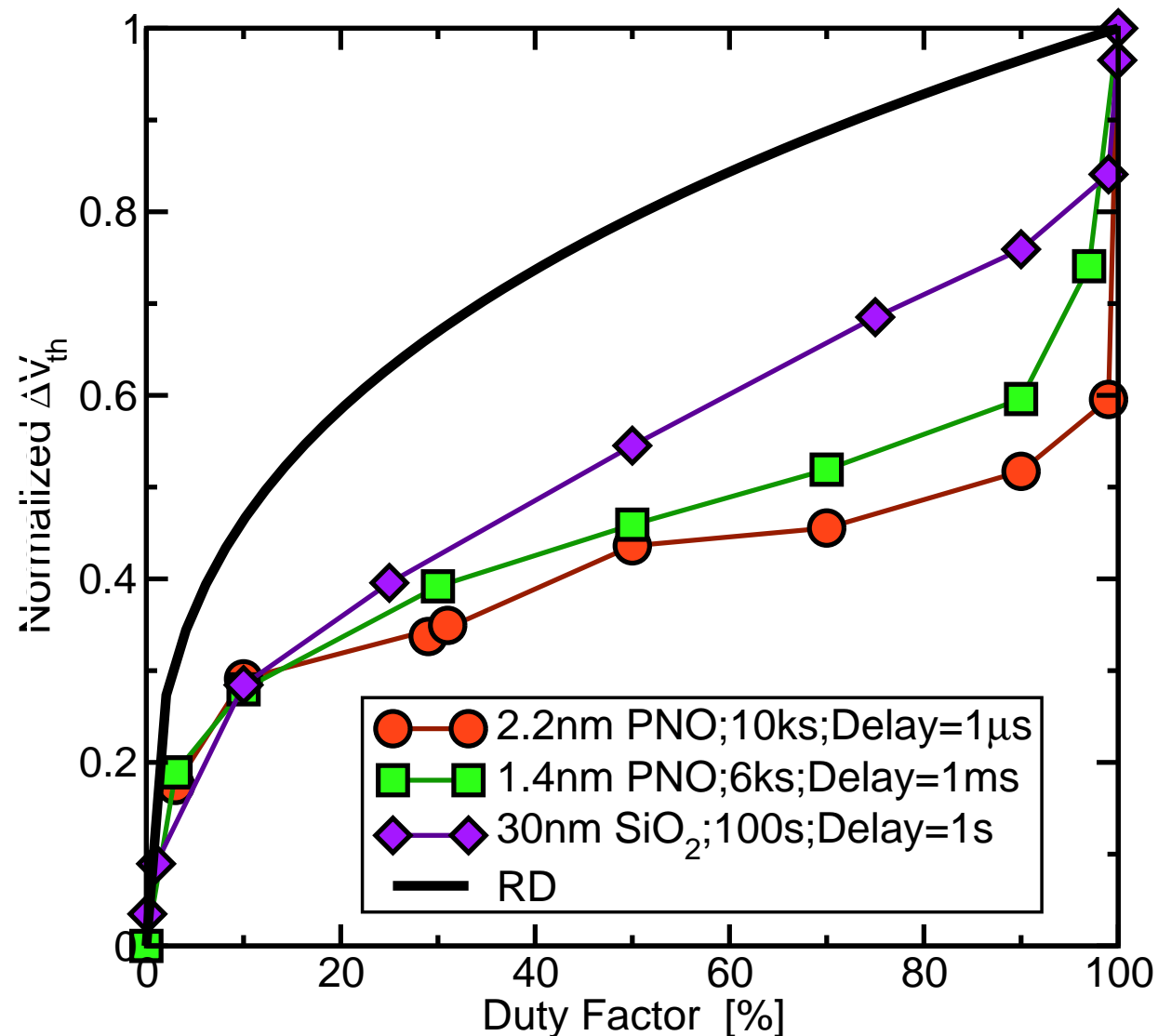
Problem #2: long-time recovery is due to back-diffusion of neutral H_2
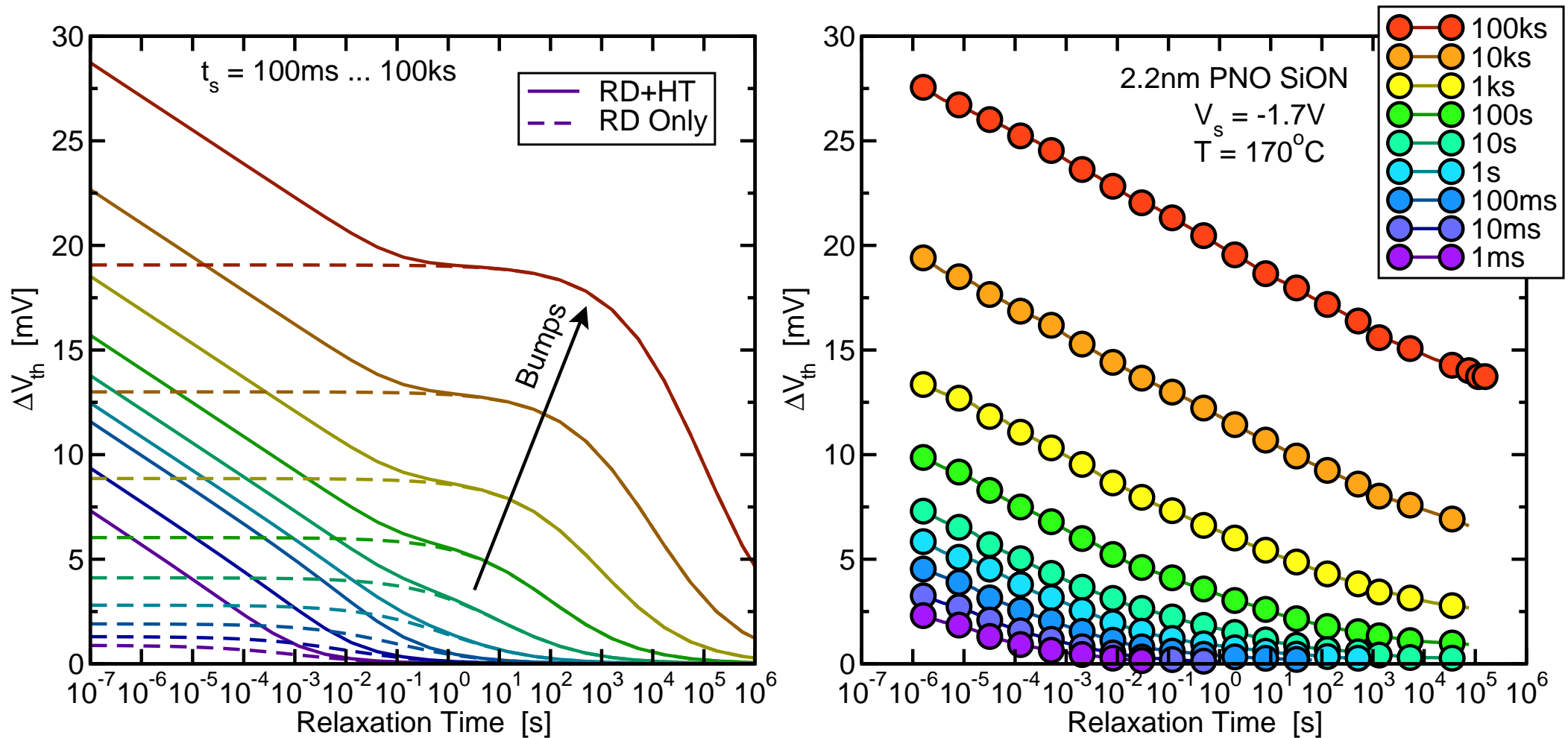
Reaction-diffusion (RD) theory

Problem #3: Duty-factor (DF) dependence nearly constant for DF $\rightarrow$ 100%
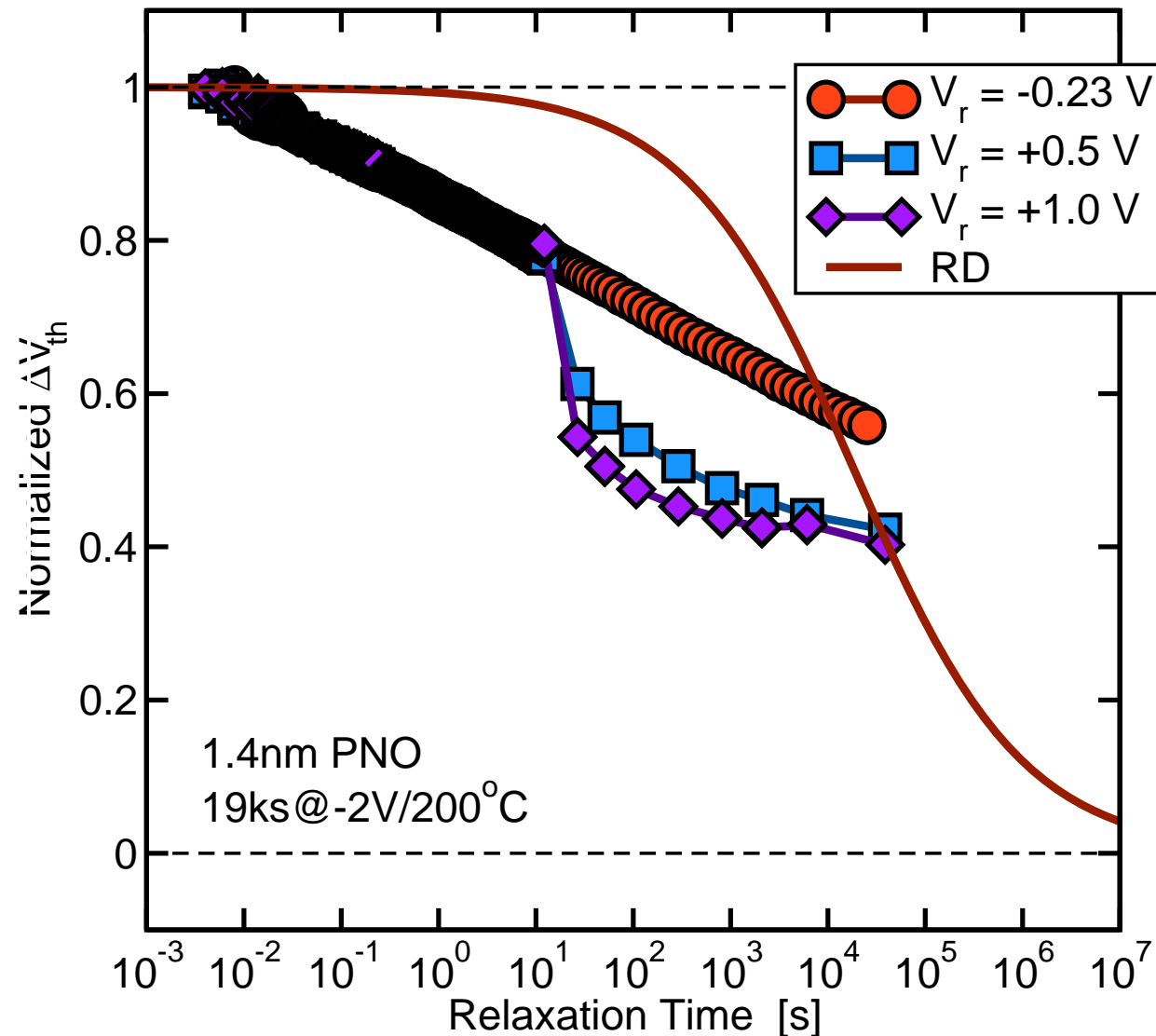
Conventional NBTI Model

Reaction-diffusion (RD) theory

Problem #4: elastic hole trapping (HT) cannot fix recovery

Overview

Introduction

Stochastic NBTI on small-area devices: link NBTI and RTN

New measurement technique

The time dependent defect spectroscopy

Anomalous defect behavior

Present in all defects

Stochastic model

Additional metastable states, multiphonon theory

Implications

Lifetime of nanoscale MOSFETs

Conclusions

What is Really Going On?

Study of NBTI recovery on small-area devices [1] [2] [3] [4] [5]

Stochastic and discrete charge emission events, no diffusion
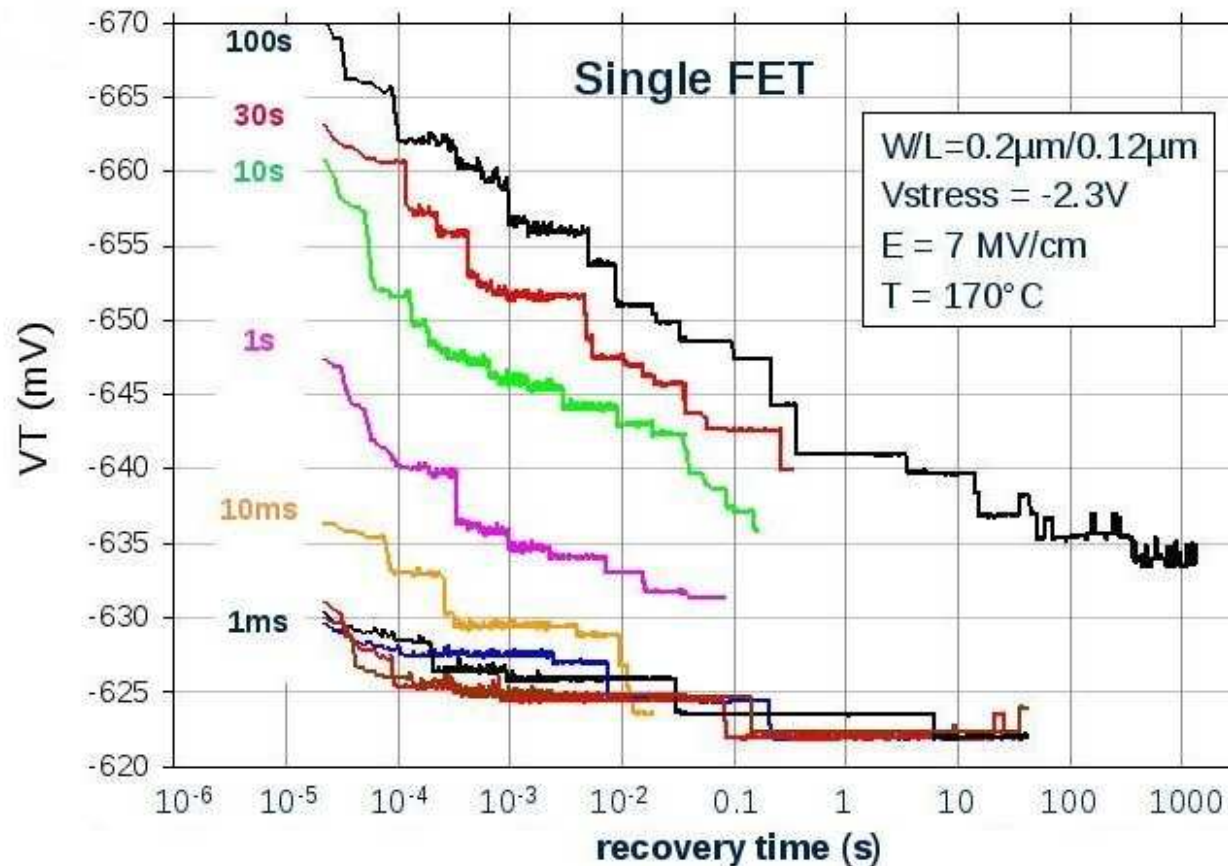
[1] Reisinger et al., IIRW '09 [2] Grasser et al., IEDM '09 [3] Kaczer et al., IRPS '10 [4] Grasser et al., IRPS '10

[5] Reisinger et al., IRPS '10

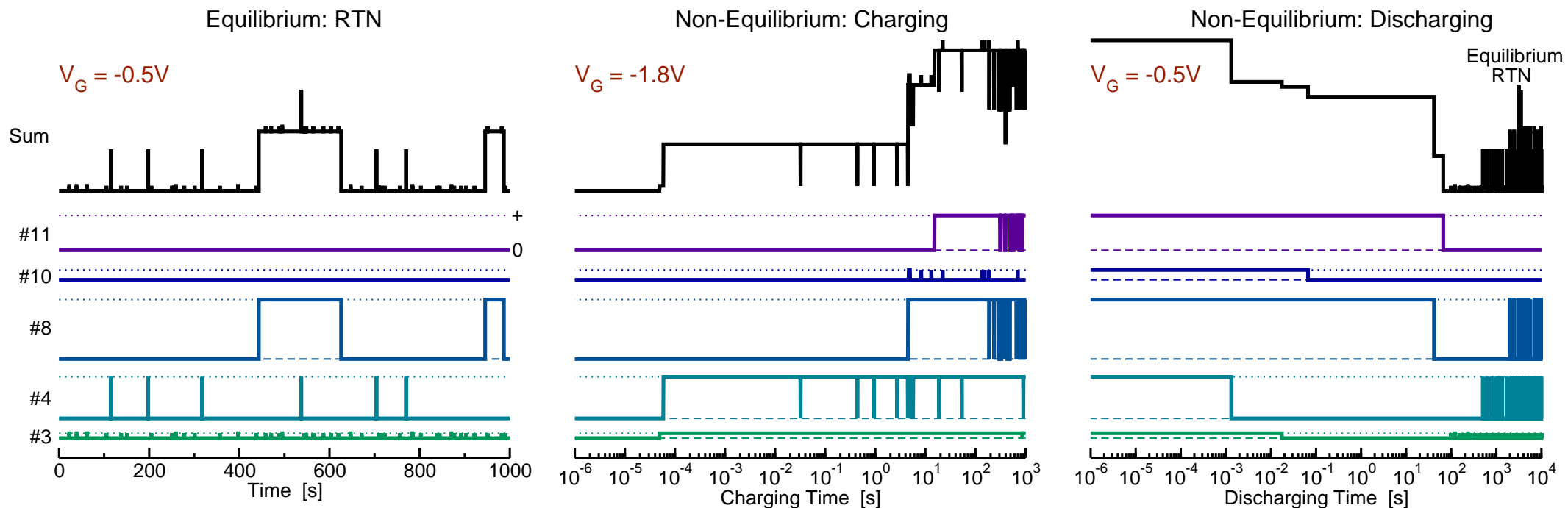# Recoverable NBTI due to the same Defects as RTN

Quasi-equilibrium:
Some defects neutral, others positive, a few produce random telegraph noise (RTN)

Stress:
Defects switch to new equilibrium (mostly positive), a few may produce RTN

Recovery:
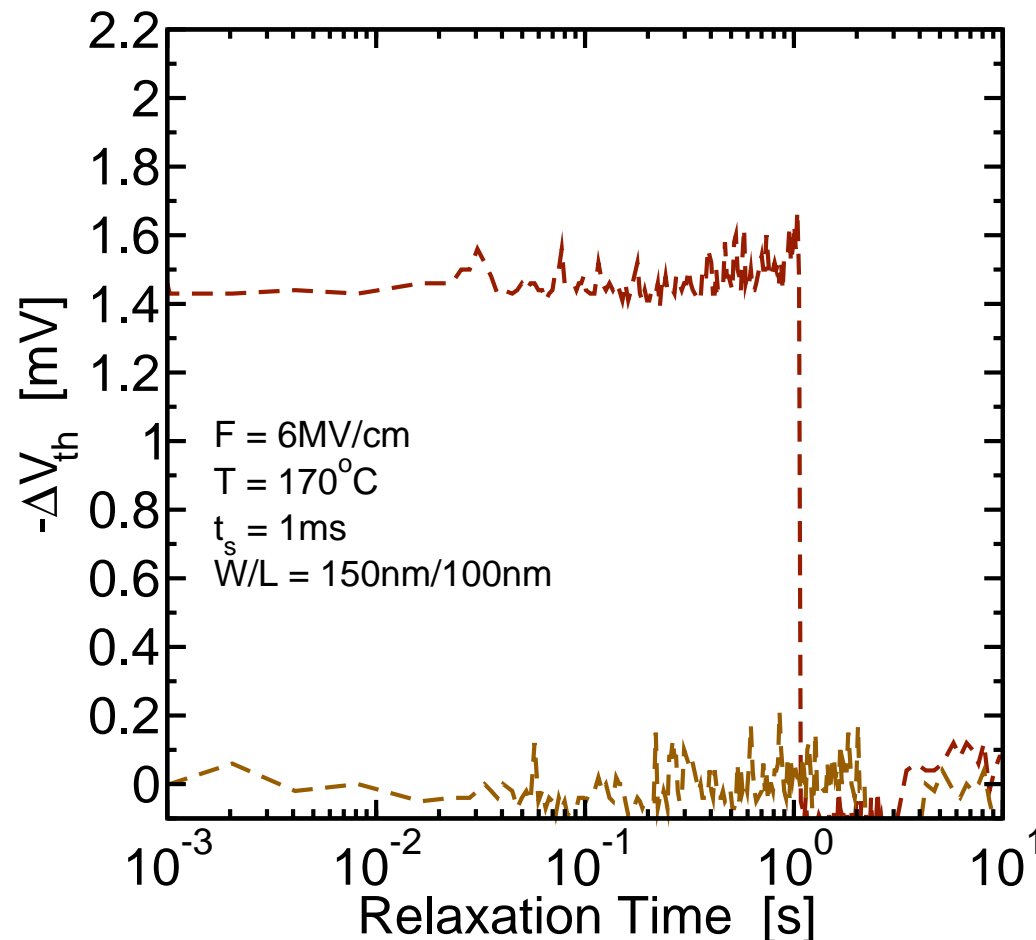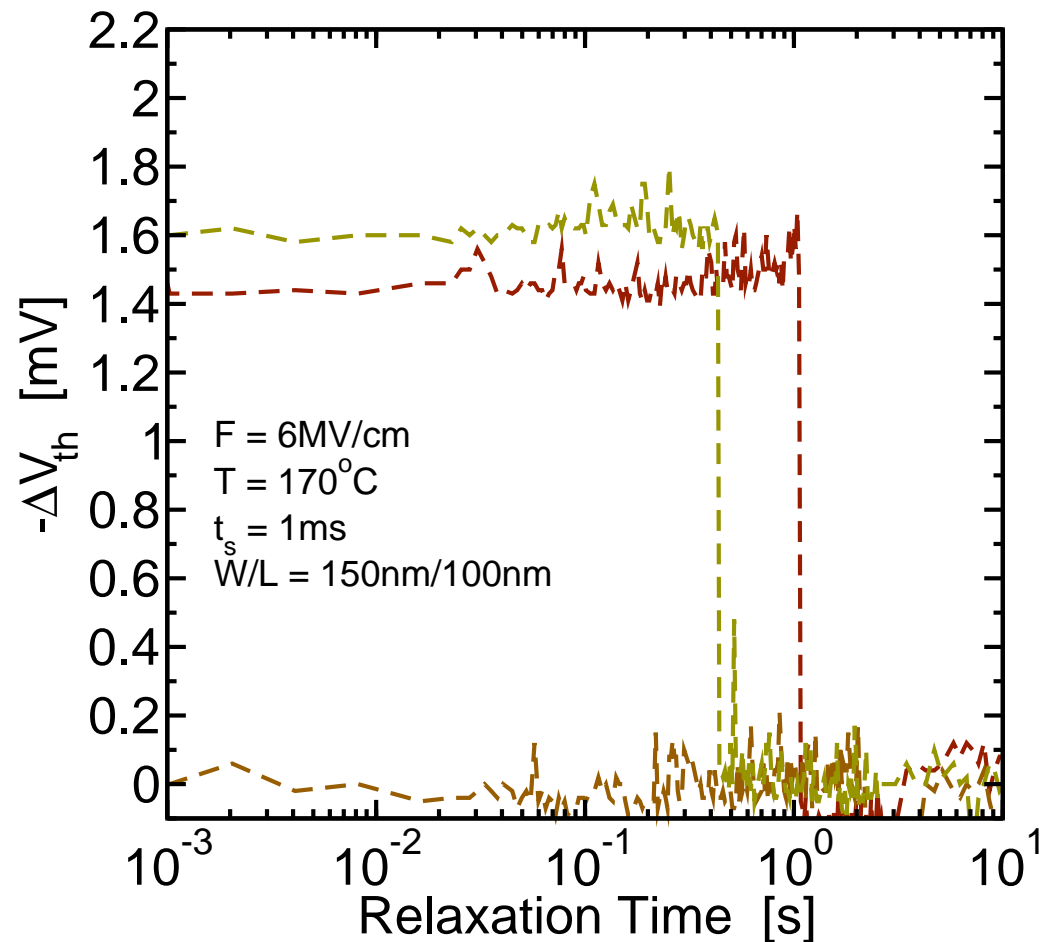Slow transition (broad distribution of timescales) to initial quasi-equilibrium
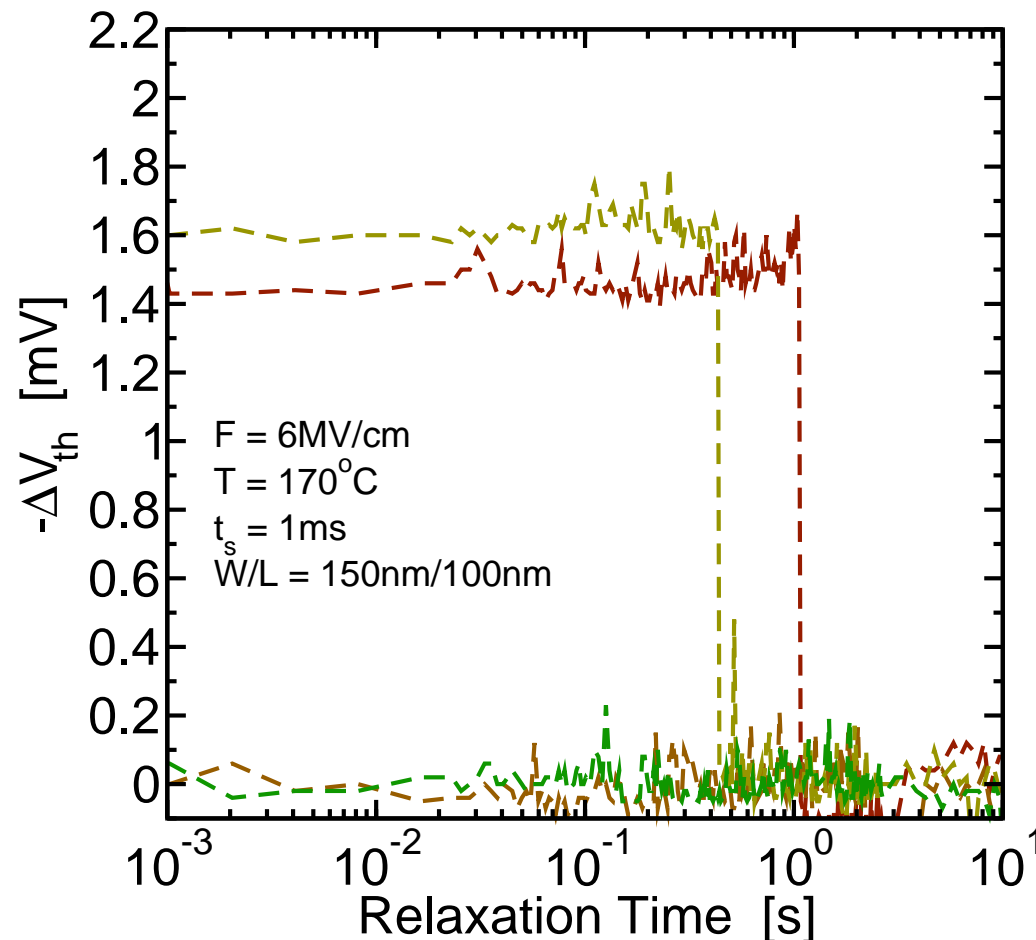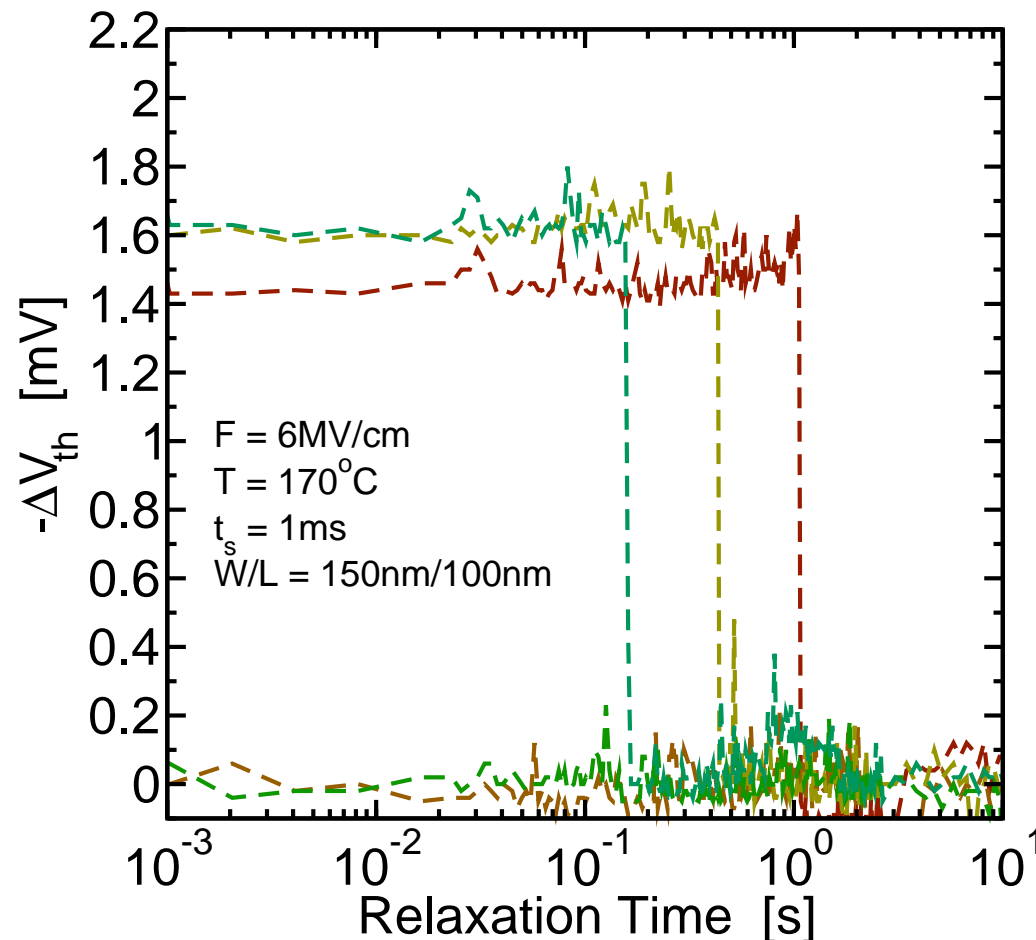
Experimental Results

Short stress may activate only a single defect

Defect initially only charged with 30%, $1 - \exp(-t_s/\tau_c) = 0.3 \Rightarrow \tau_c \gtrsim 3\,\text{ms}$

Defect discharges around $\tau_e = 4\,\text{s}$

Averaging results in the expected $\exp(-t/\tau)$ behavior

F = 6MV/cm
T = 170°C
t_s = 1ms
W/L = 150nm/100nm

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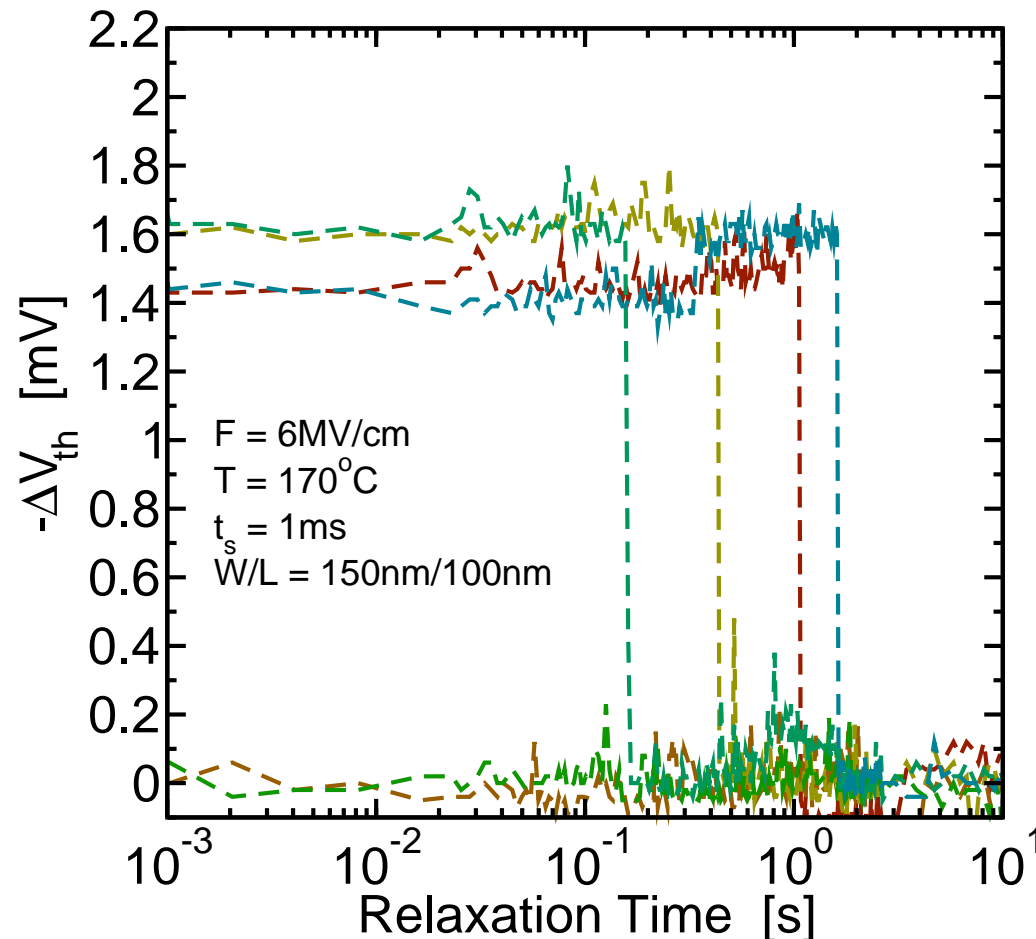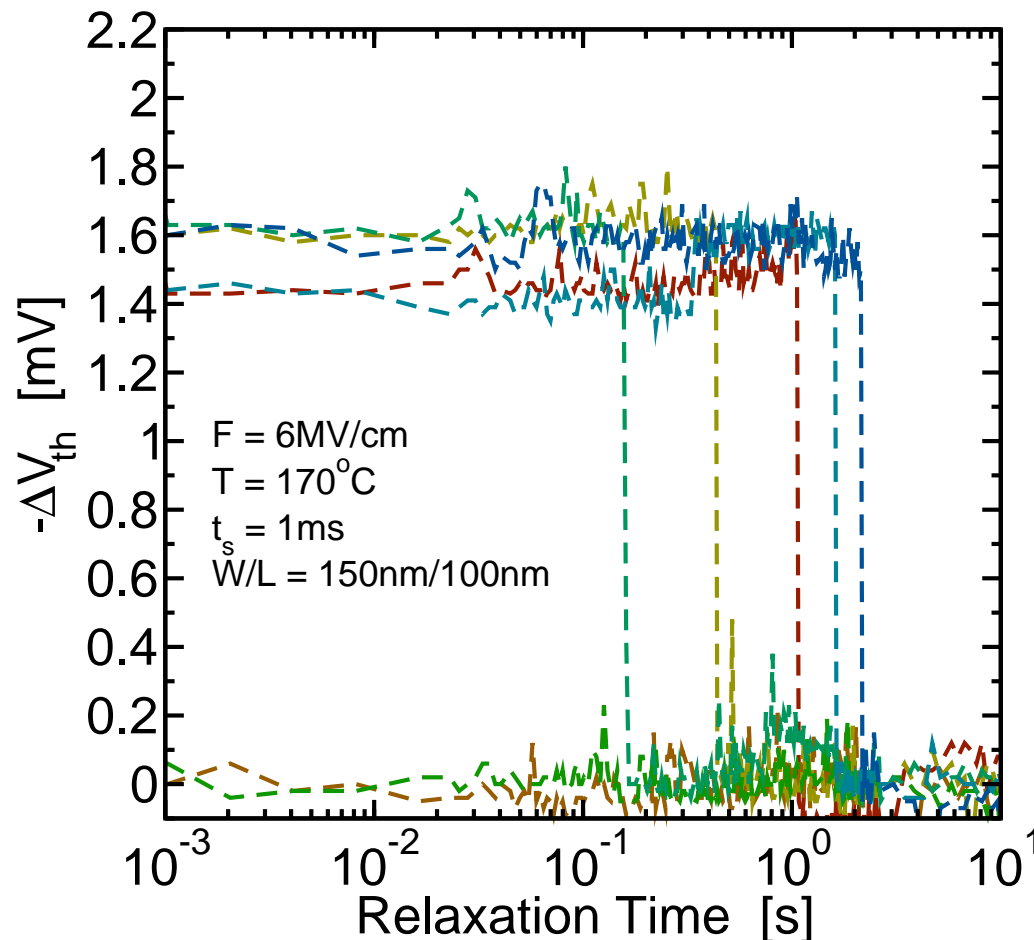Averaging results in the expected $\exp(-t/\tau)$ behavior

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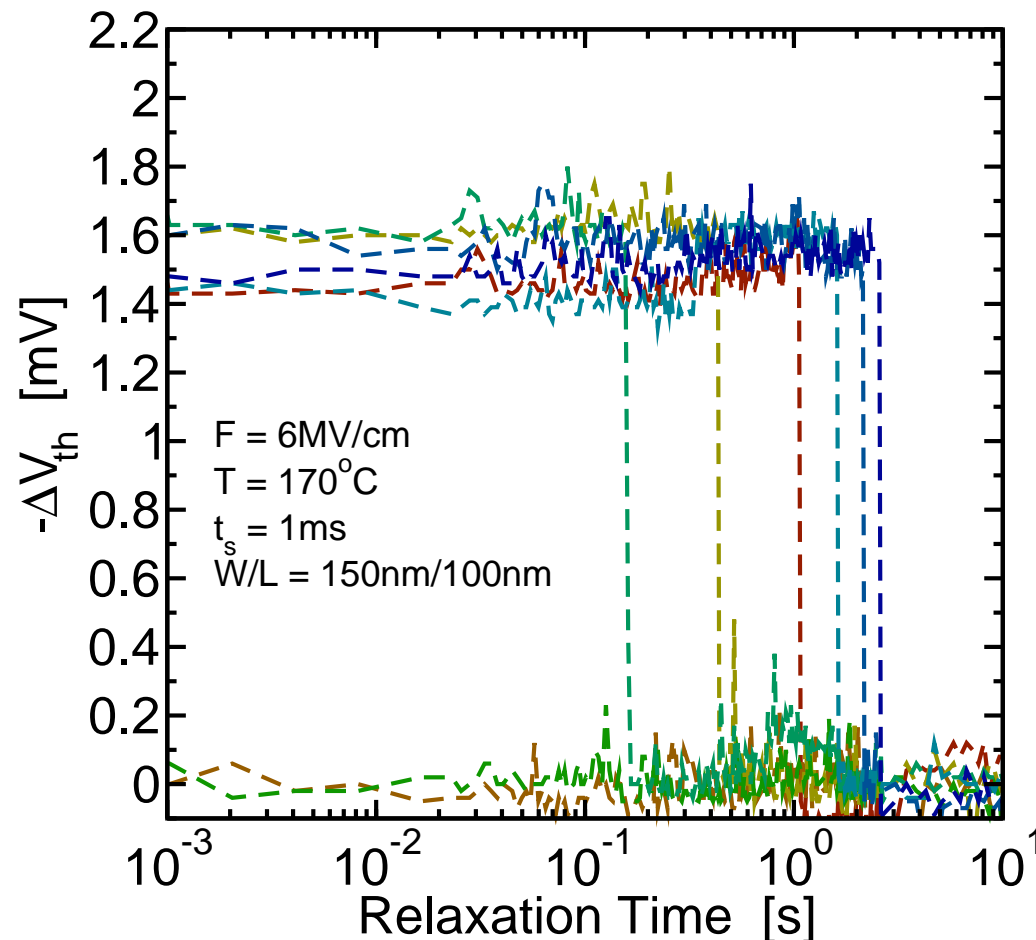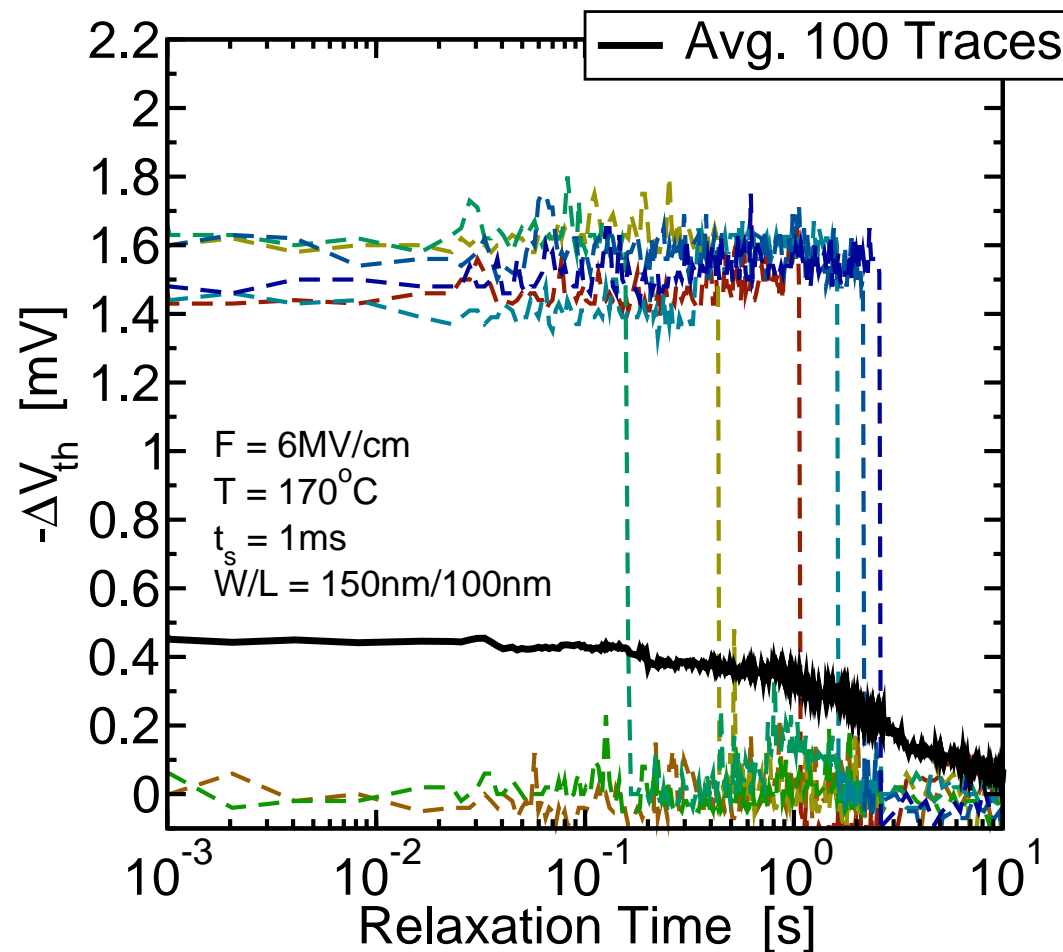Averaging results in the expected $\exp(-t/\tau)$ behavior

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Averaging results in the expected $\exp(-t/\tau)$ behavior

Short stress may activate only a single defect

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Defect discharges around $\tau_\text{e} = 4\,\text{s}$

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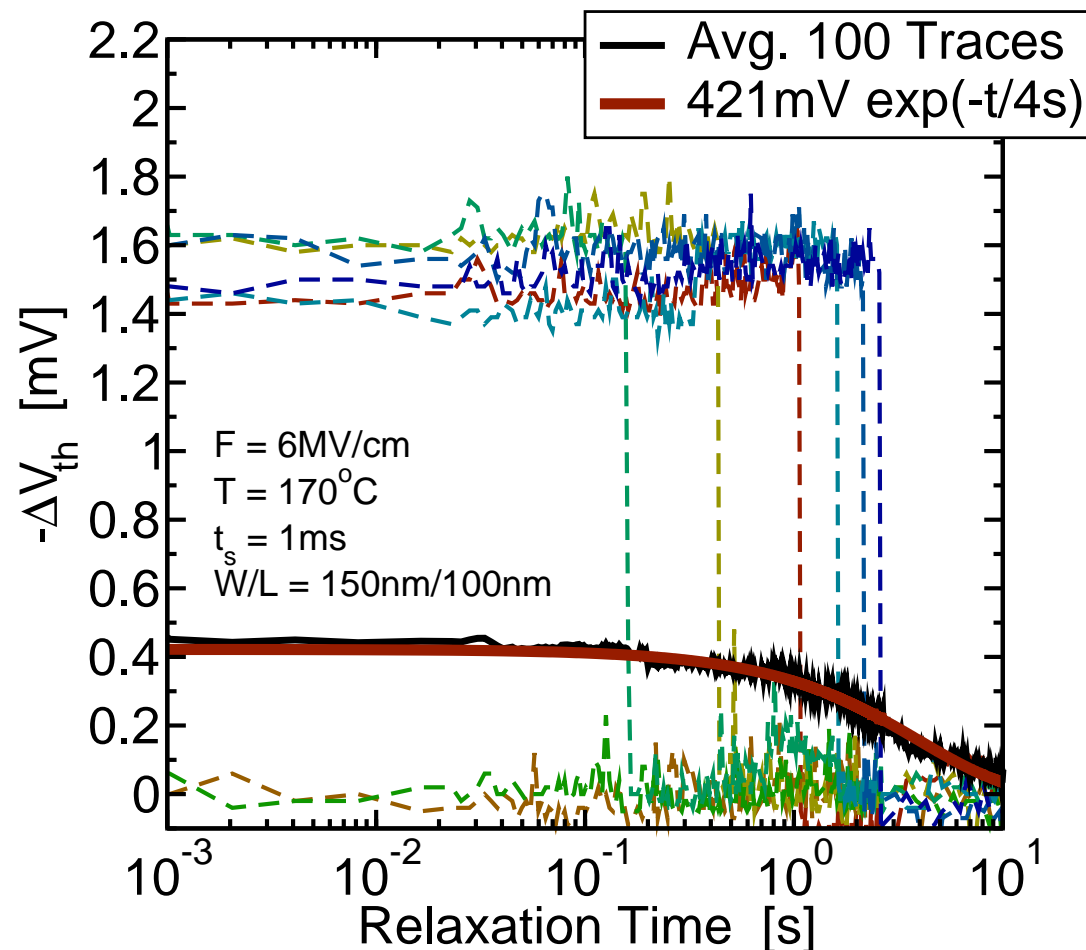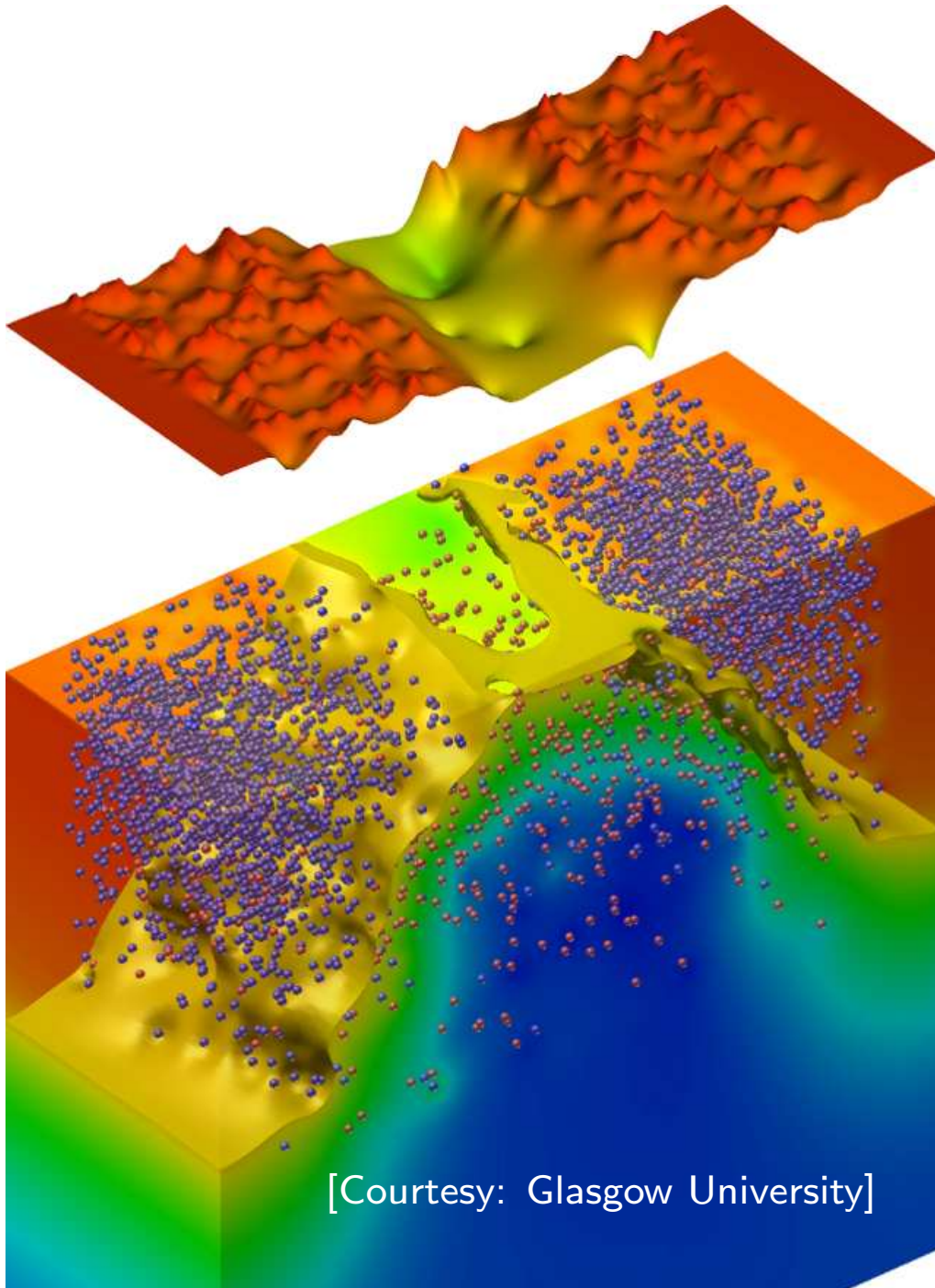
[Courtesy: Glasgow University]
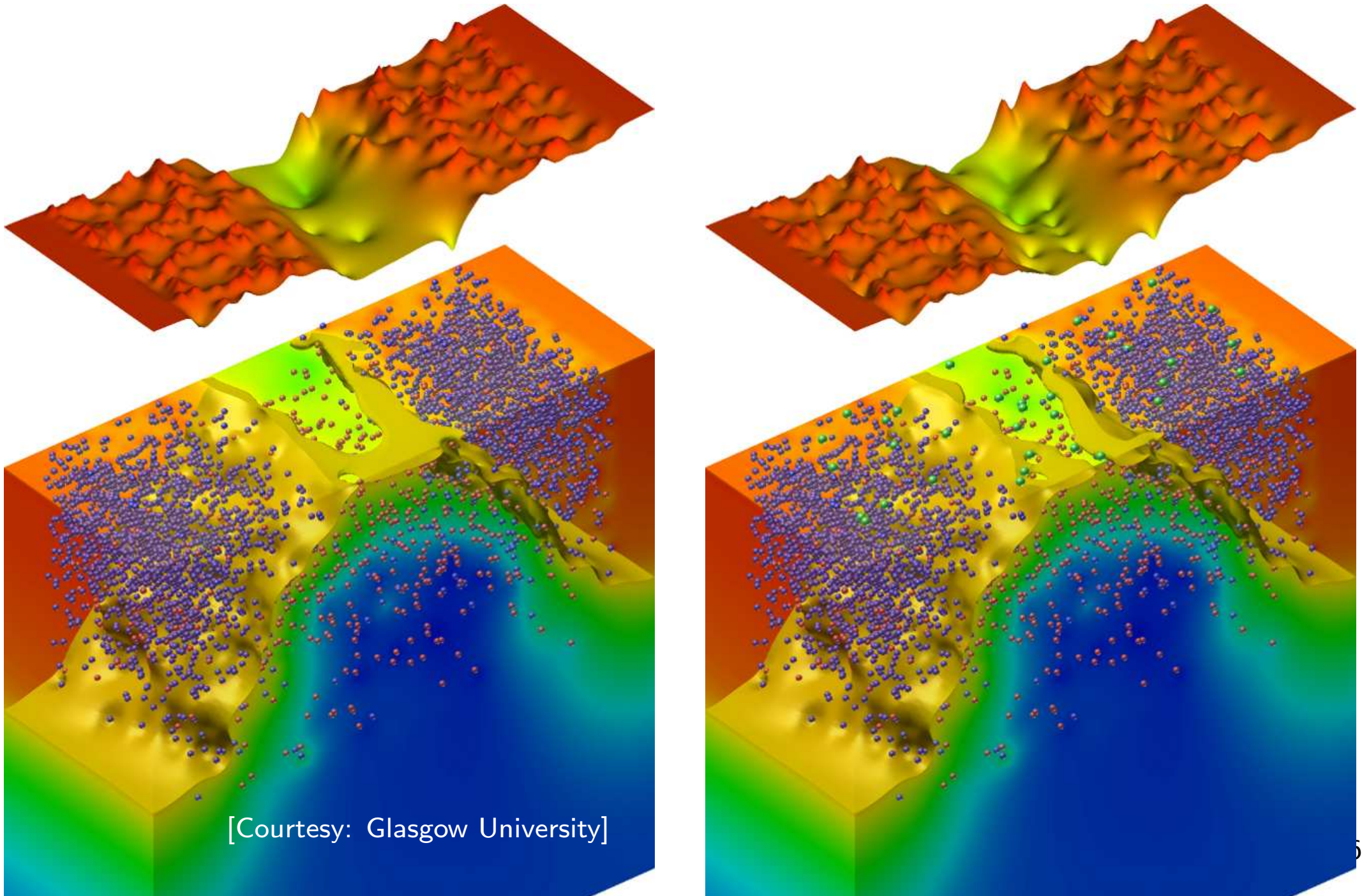
[Courtesy: Glasgow University]

Distribution of Step-Heights

Like RTN, NBTI step-heights are exponentially distributed[1]

Charge-Sheet: 1.2mV

1.5s
1900s

$\eta = 4.4$mV

W/L = 90nm/35nm
0.8nm HfO_2

Lifetime Criterion

Tail of the Distribution
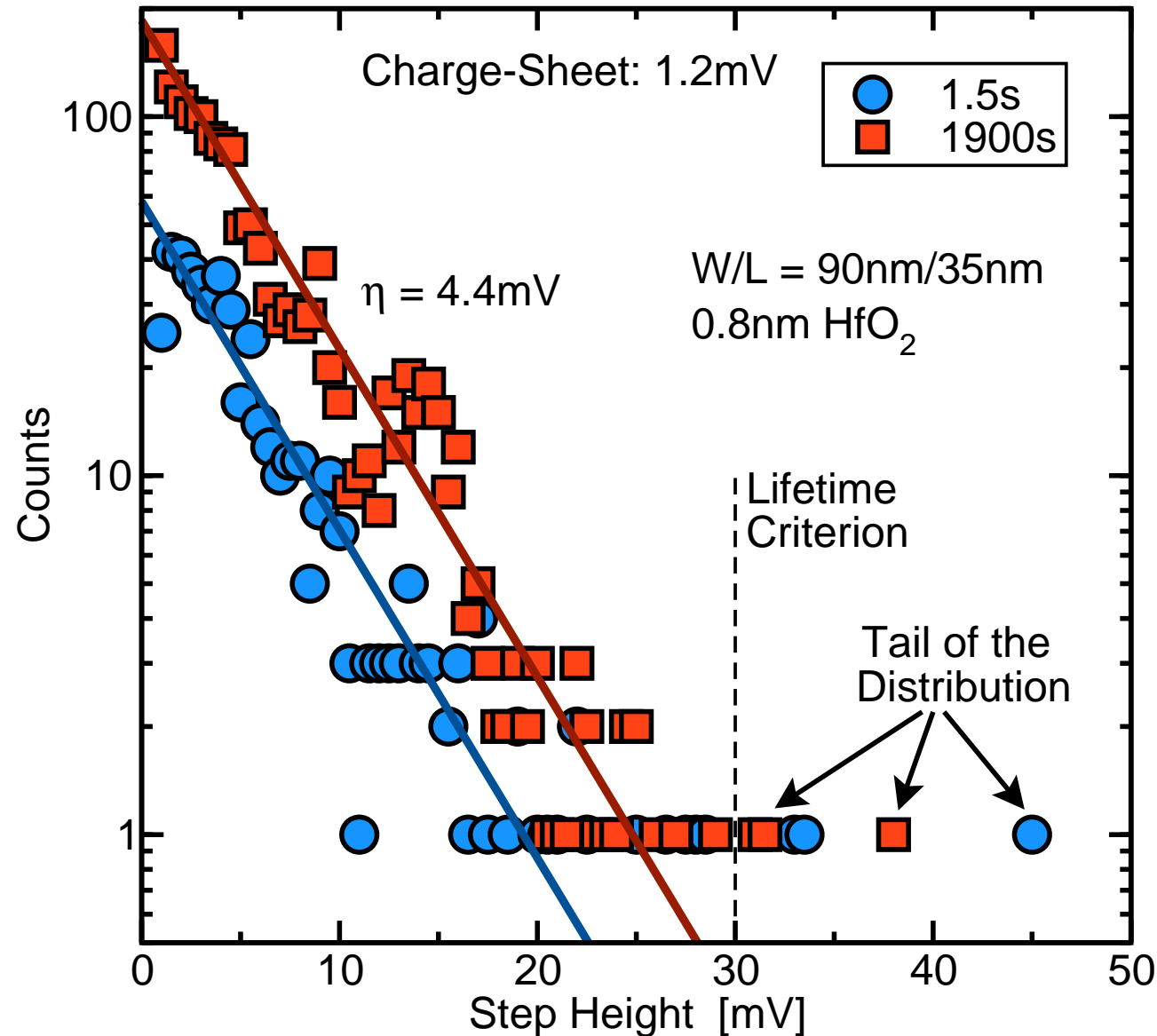
[1] Kaczer, IRPS '10

The Time Dependent Defect Spectroscopy (TDDS)

Analyzes contributions from multiple traps via spectral maps [1] [2]
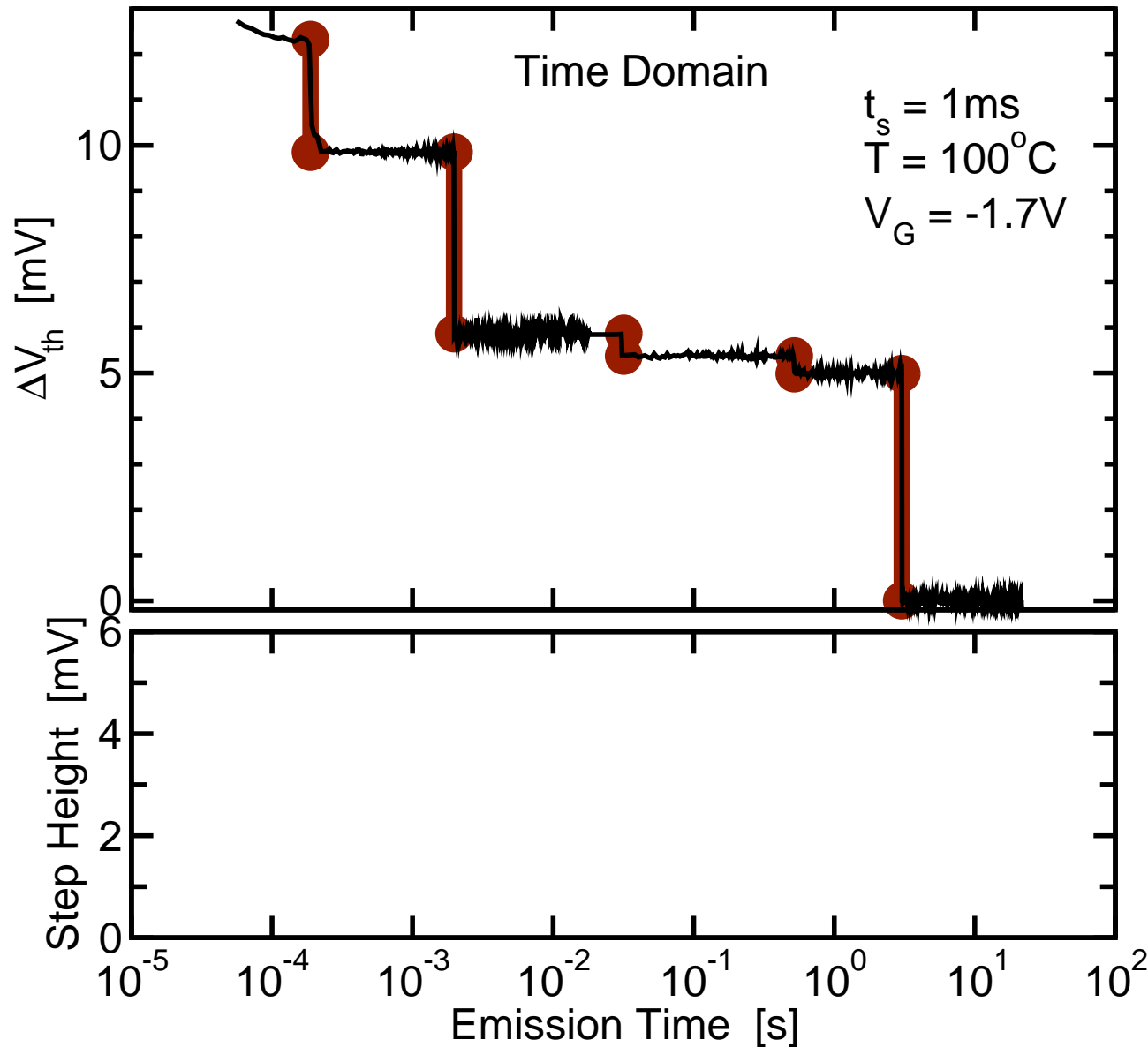
[1] Grasser *et al.*, IRPS '10   [2] Grasser *et al.*, PRB '10

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The Time Dependent Defect Spectroscopy (TDDS)

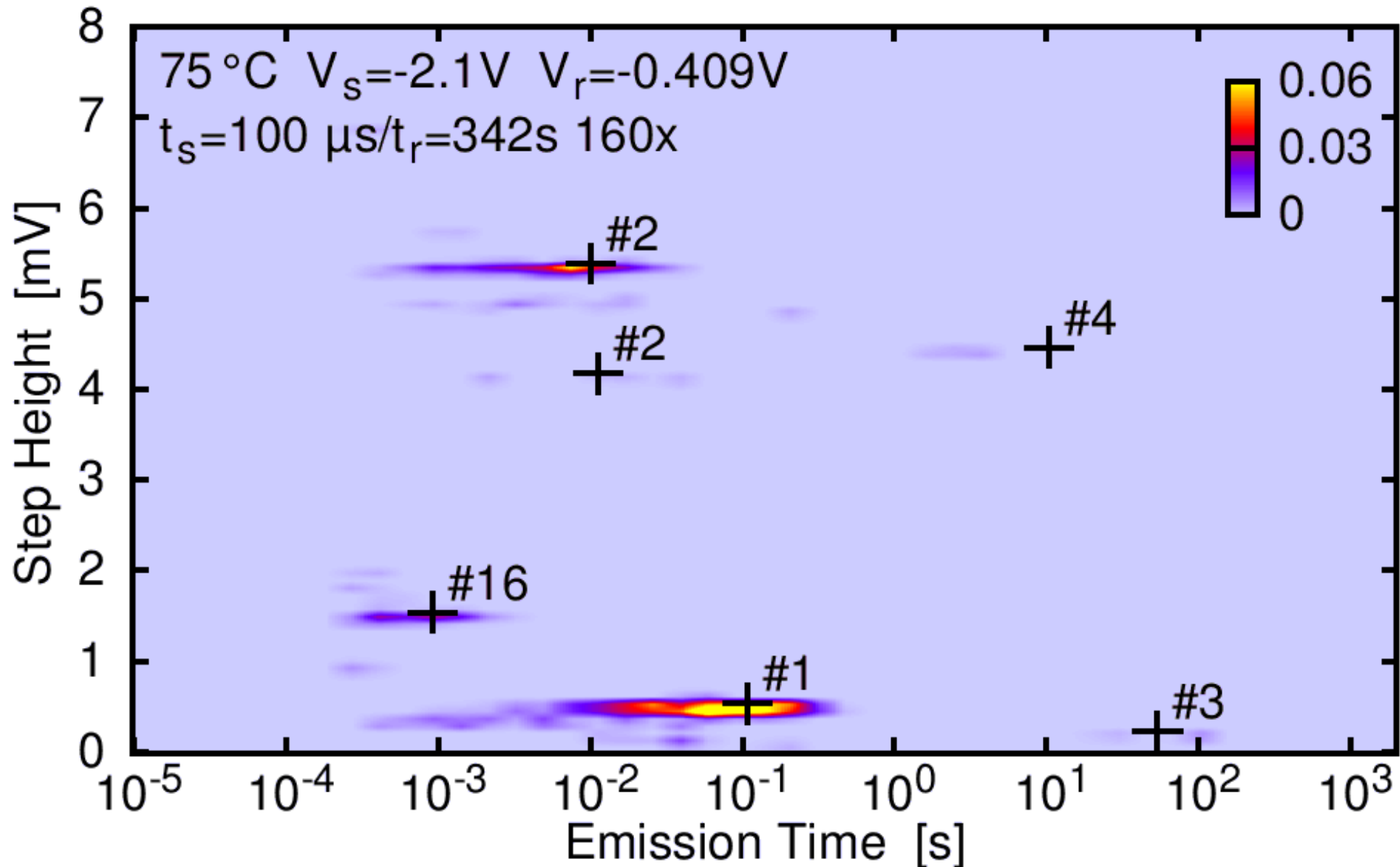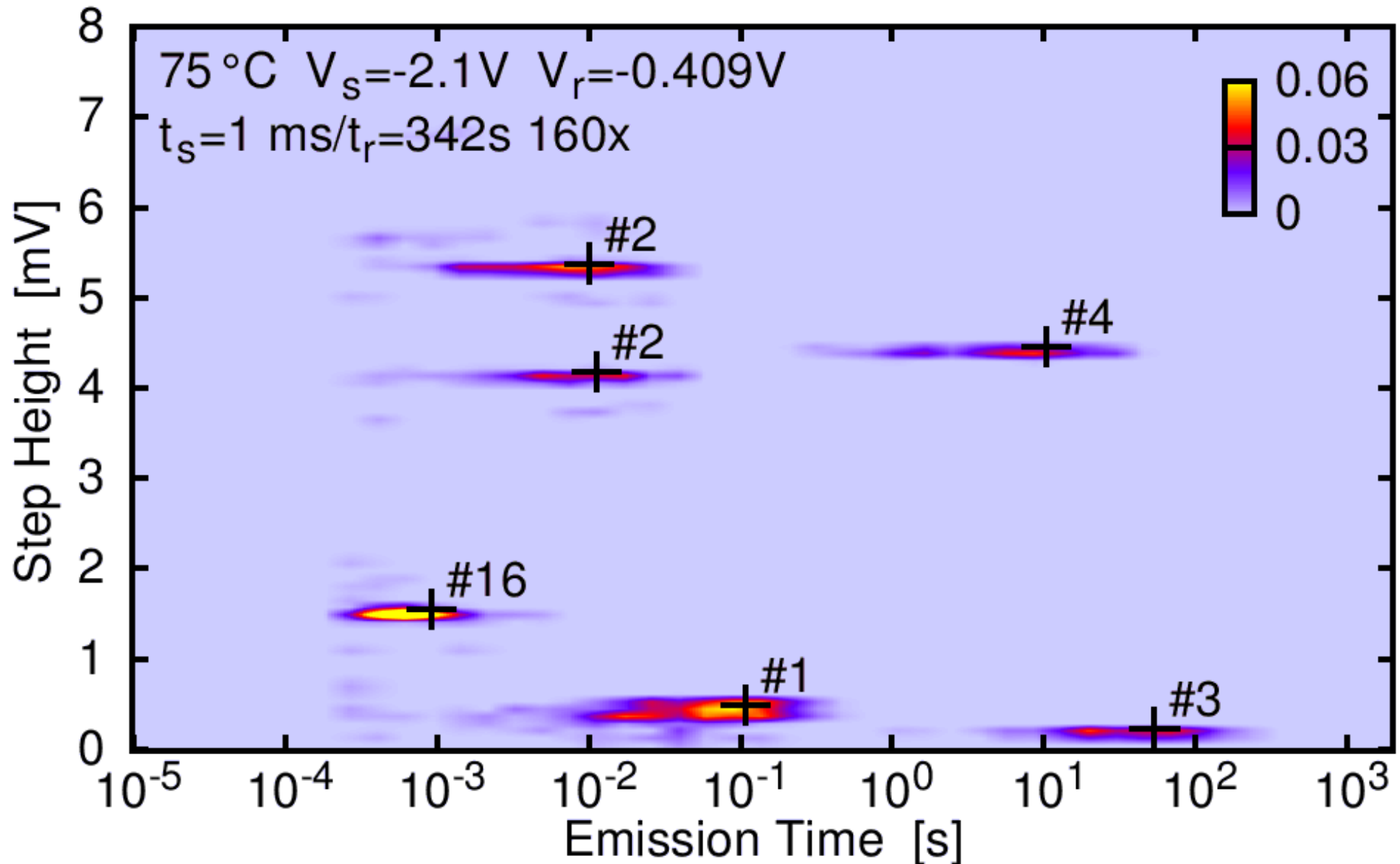Analyzes contributions from multiple traps via spectral maps

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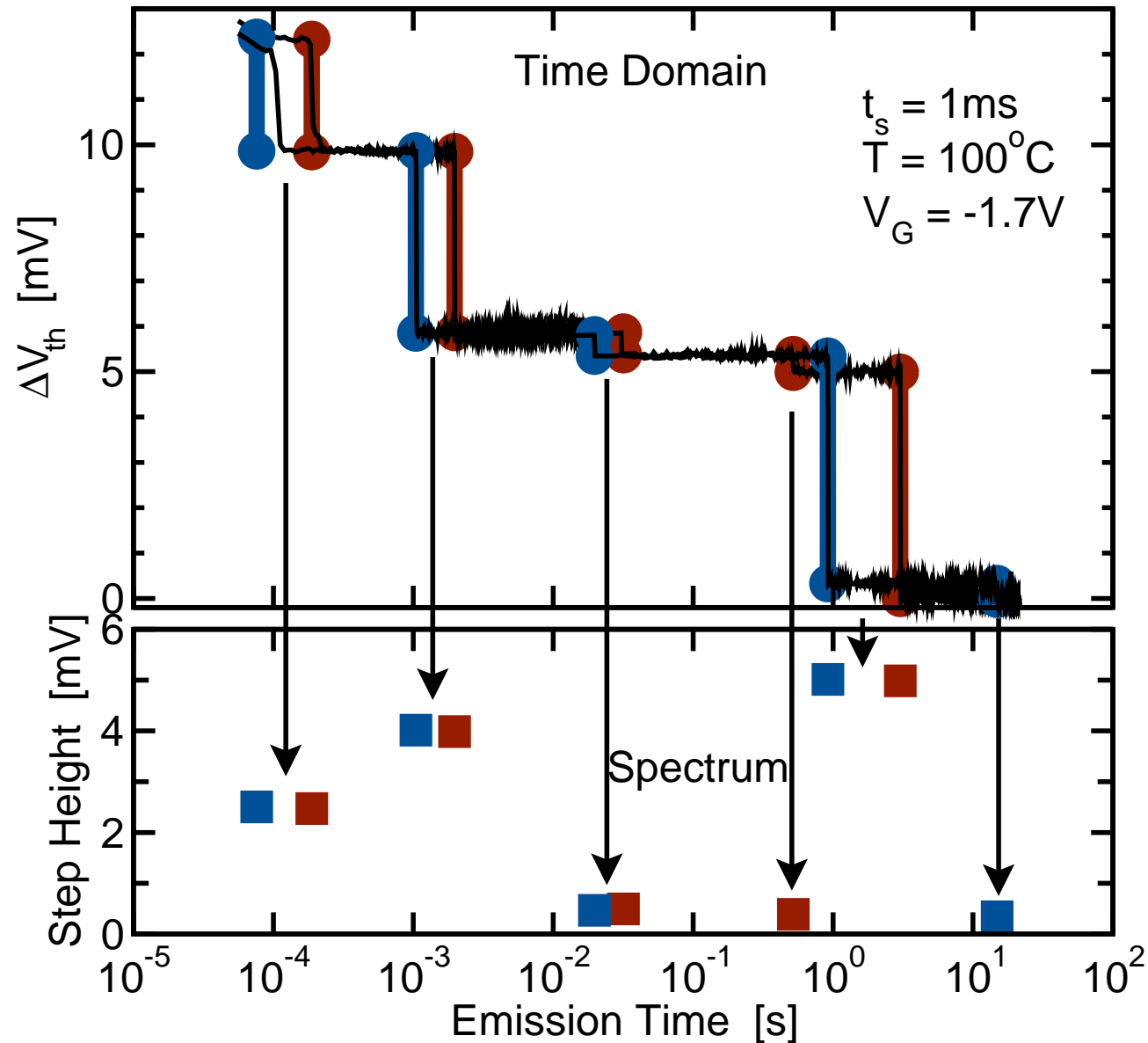
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The Time Dependent Defect Spectroscopy
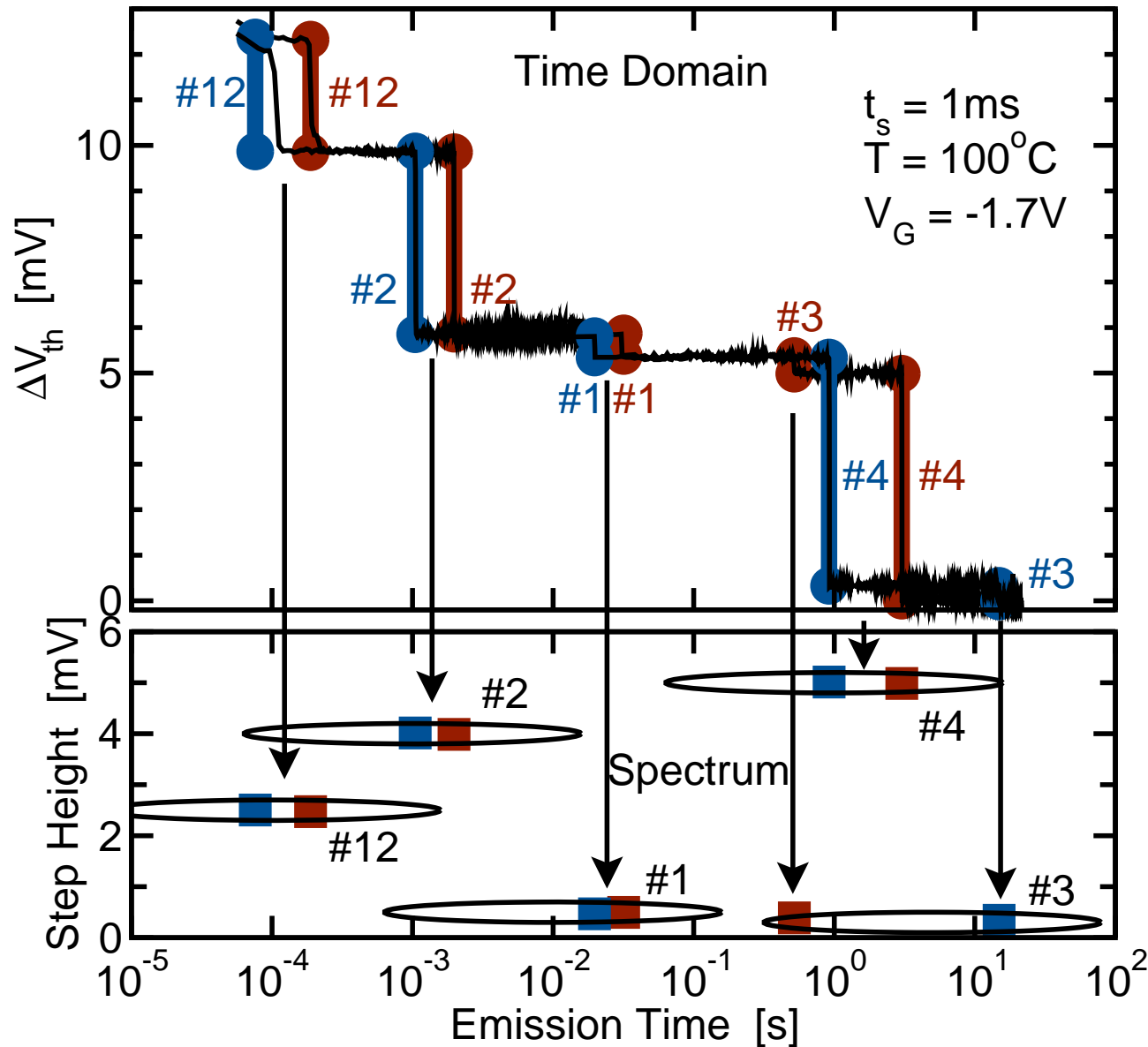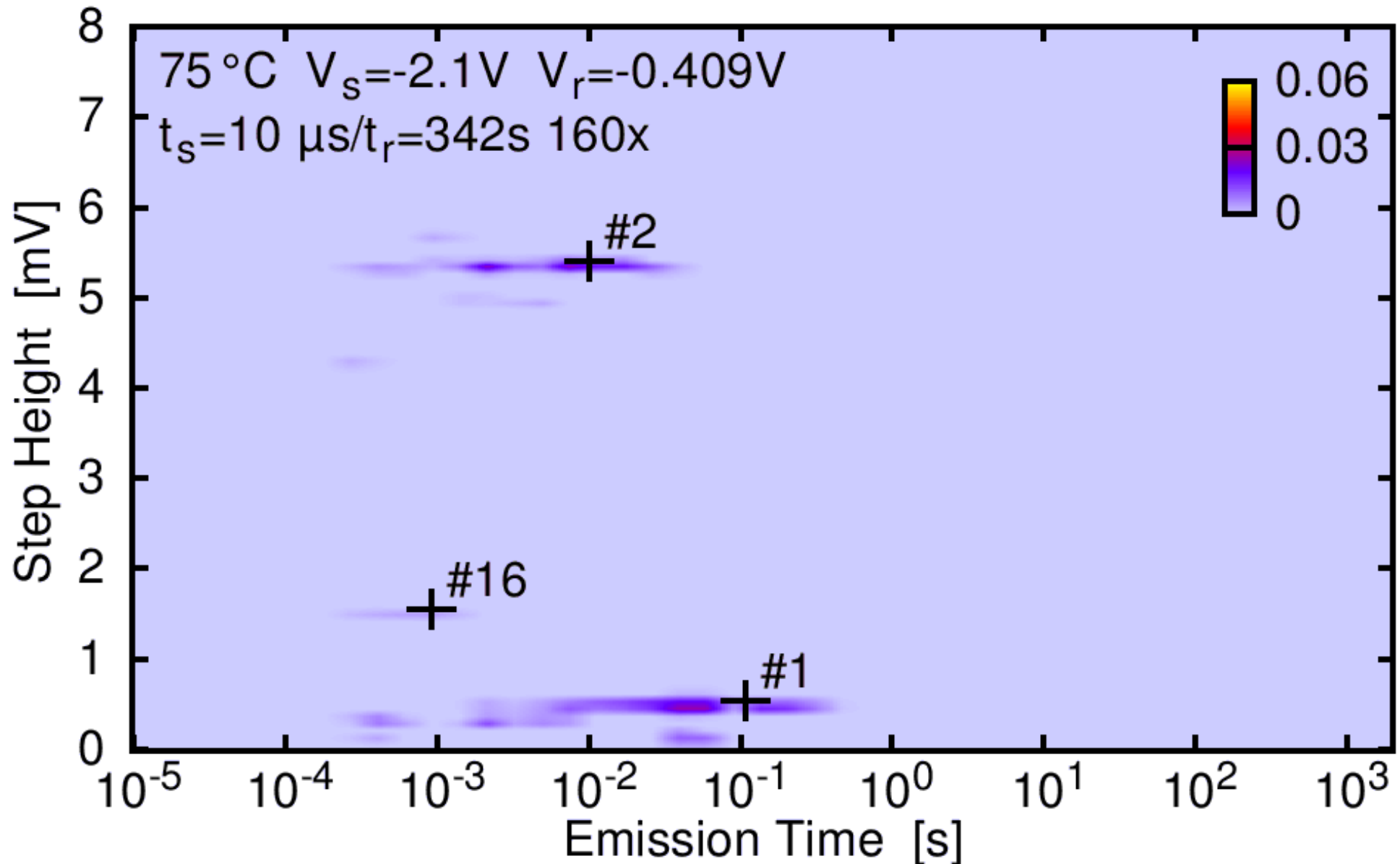
Function of stress time t_s

Function of stress time t_s

The Time Dependent Defect Spectroscopy

Function of stress time t_s

Function of stress time t_s

Function of temperature
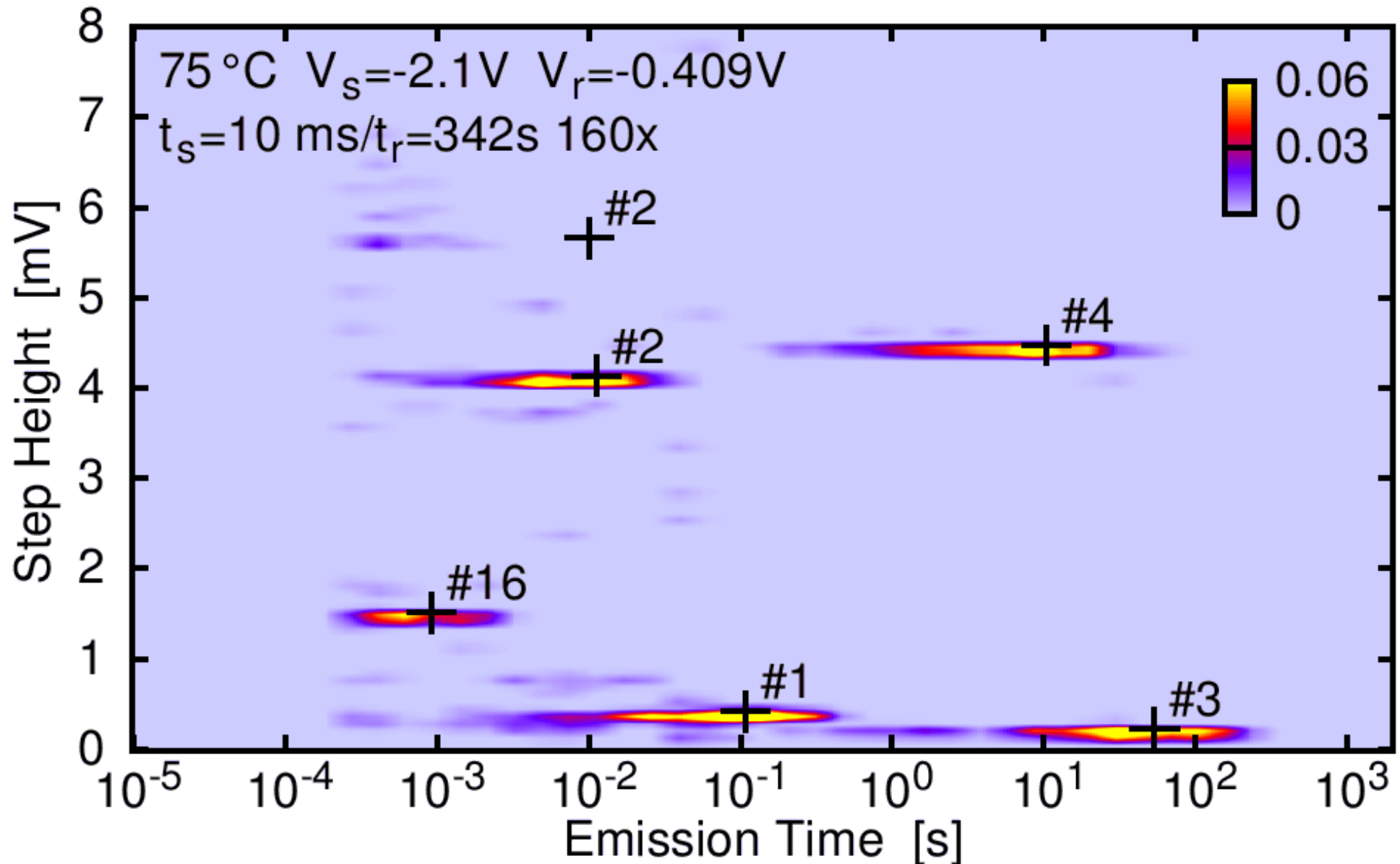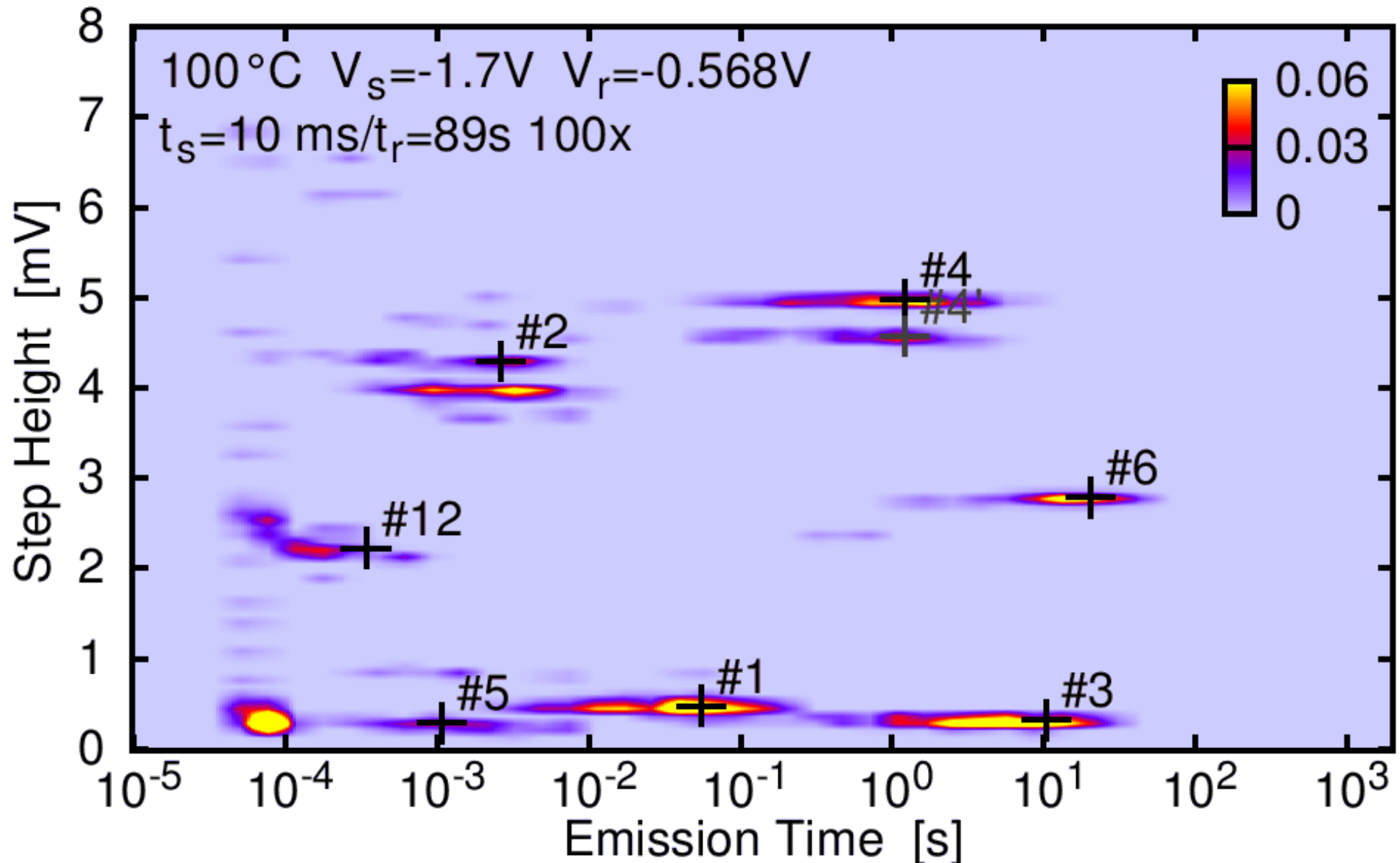
Function of temperature
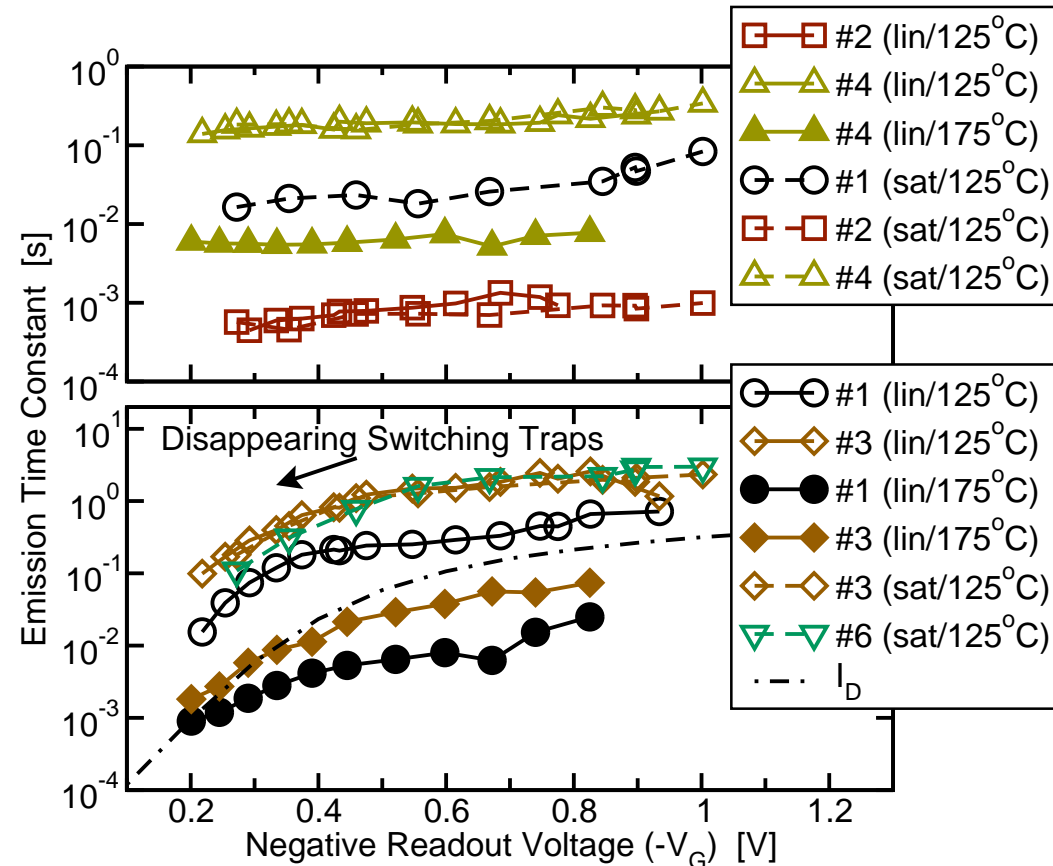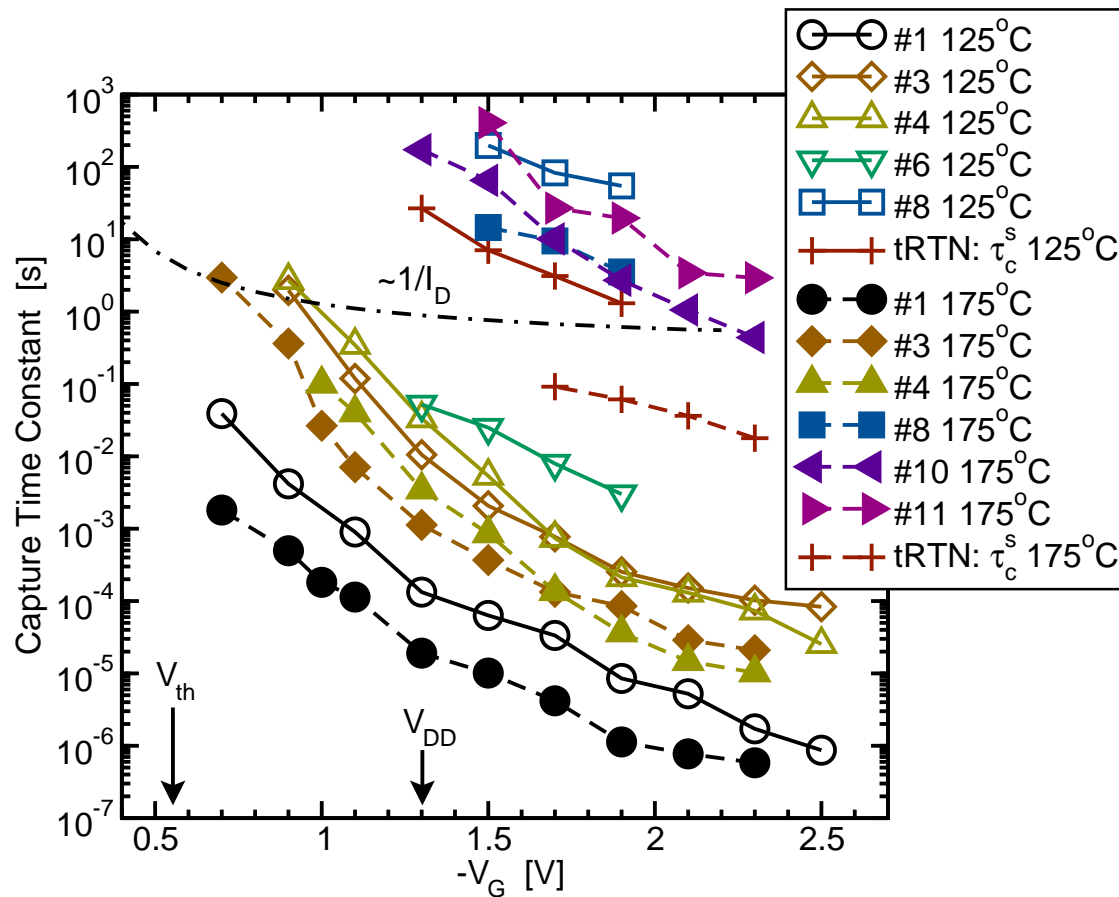
Function of temperature

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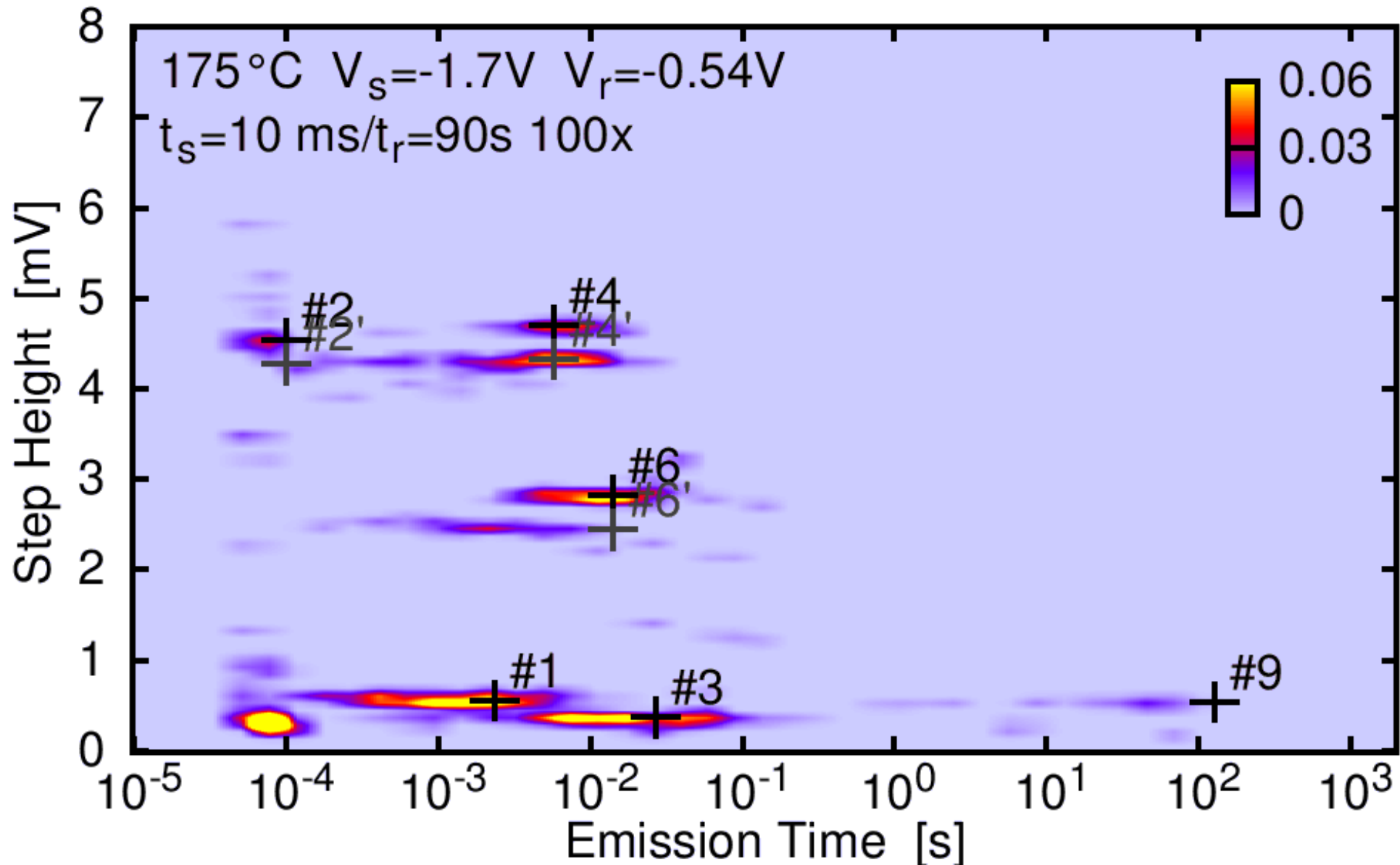
The Time Dependent Defect Spectroscopy

Different non-linear field dependence of the capture time constants

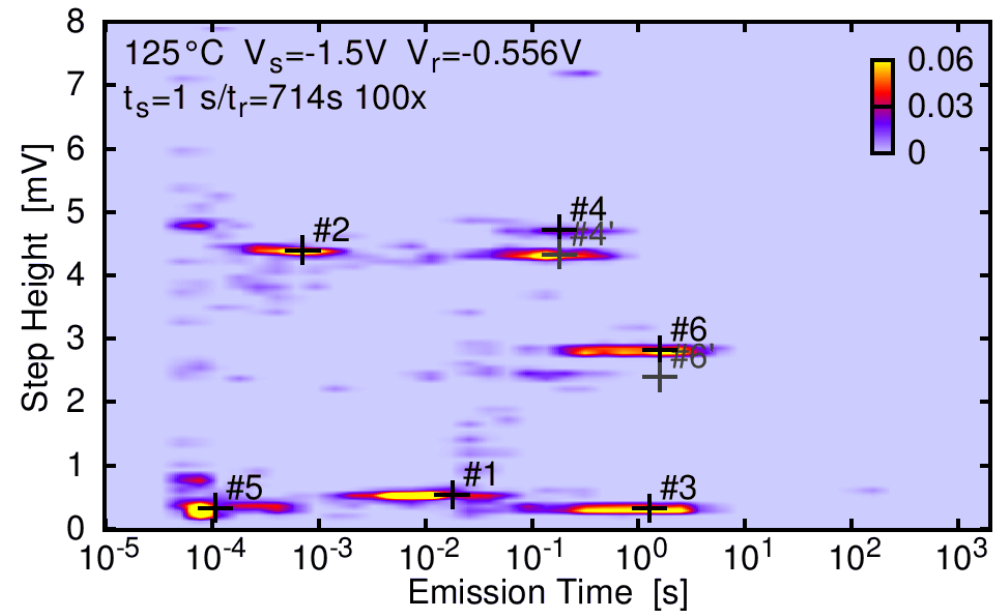Different bias dependence of emission time constant: two defect types?
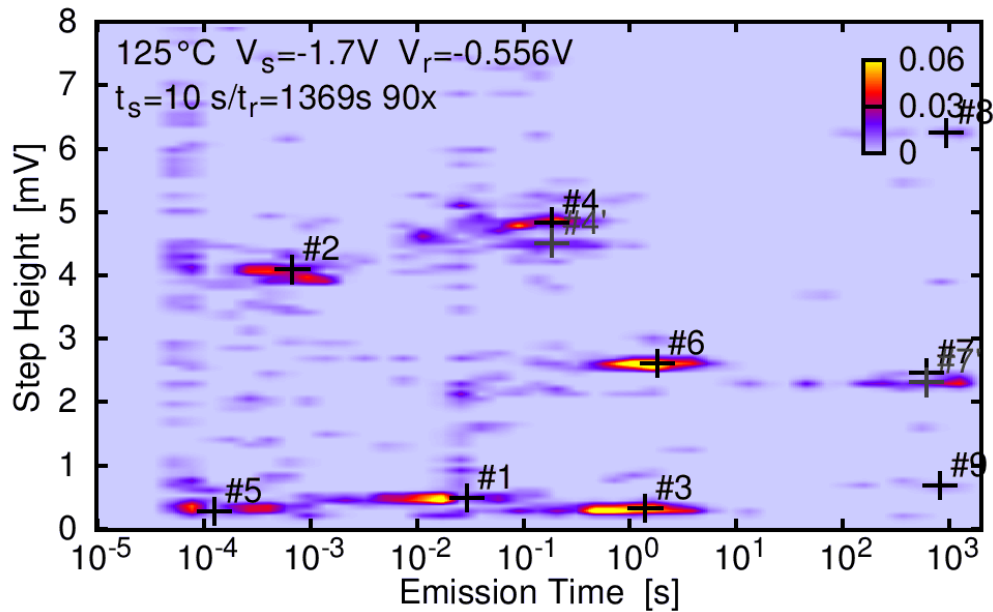

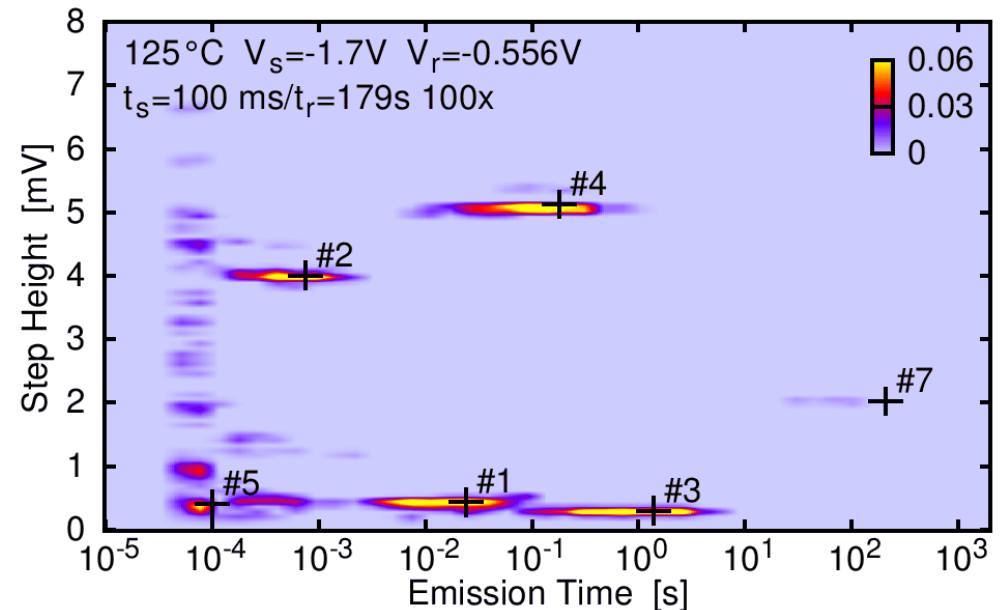Compare SRH-like model: $\tau_c = \tau_0\, e^{\beta \Delta E_B}\, \dfrac{N_v}{\color{red}p}$
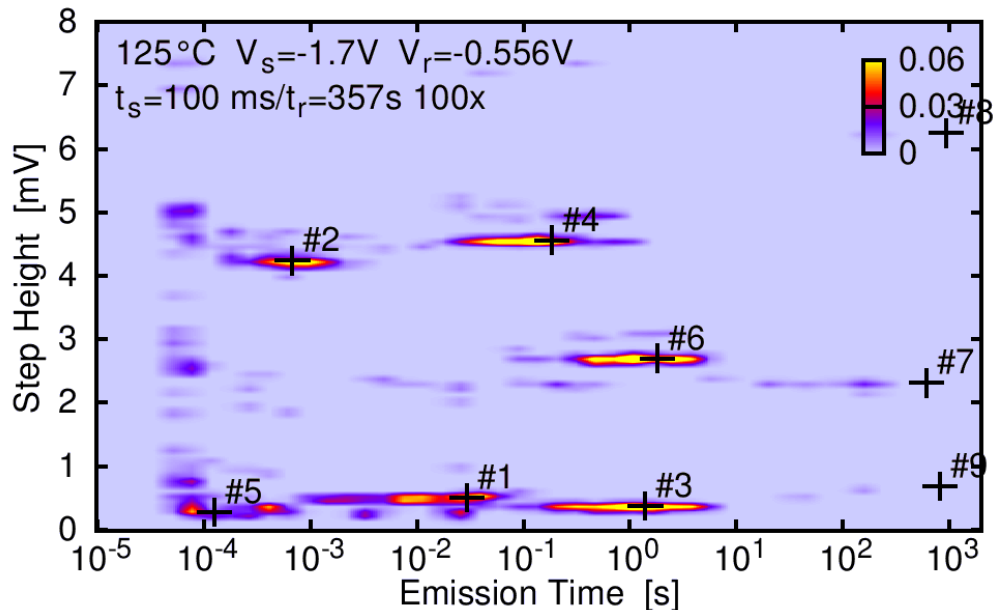
$\tau_e = \tau_0\, e^{\beta \Delta E_B}\, e^{\beta \Delta E_T}\, e^{x{\color{red}F}/V_T}$

Anomalous Defect Behavior

Defects disappear temporarily from the map (#7)

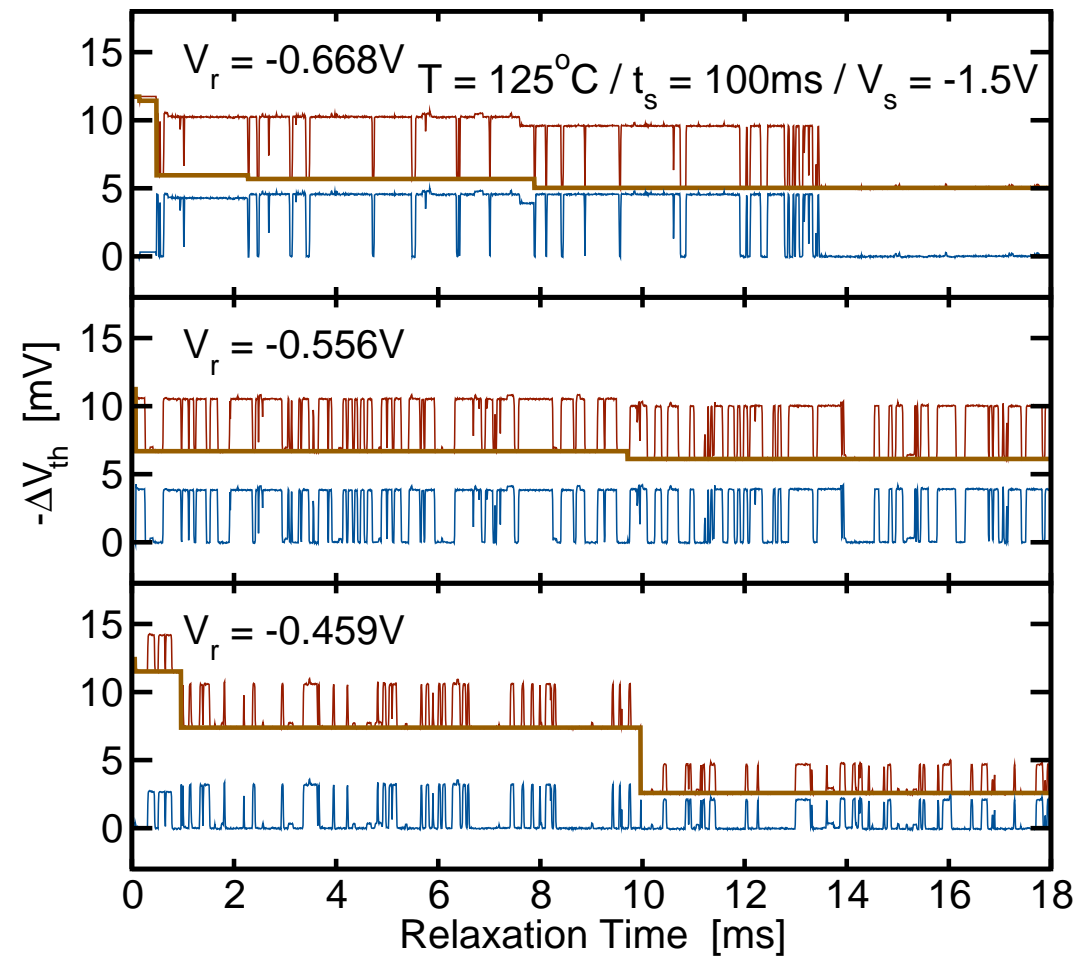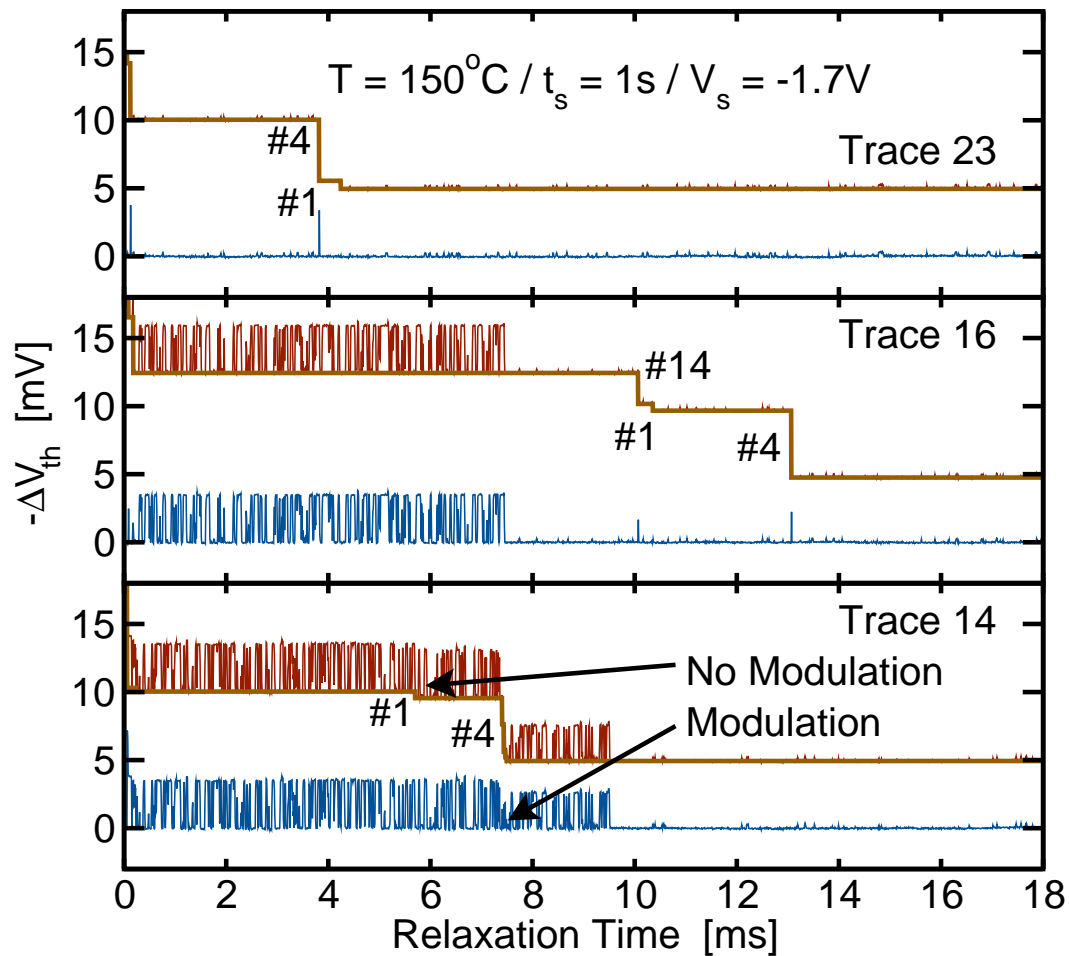## Long term stability: defect #6 missing for a few months now

Temporary random telegraph noise (tRTN)

How Can We Model All That?

Charging of Oxide Defects
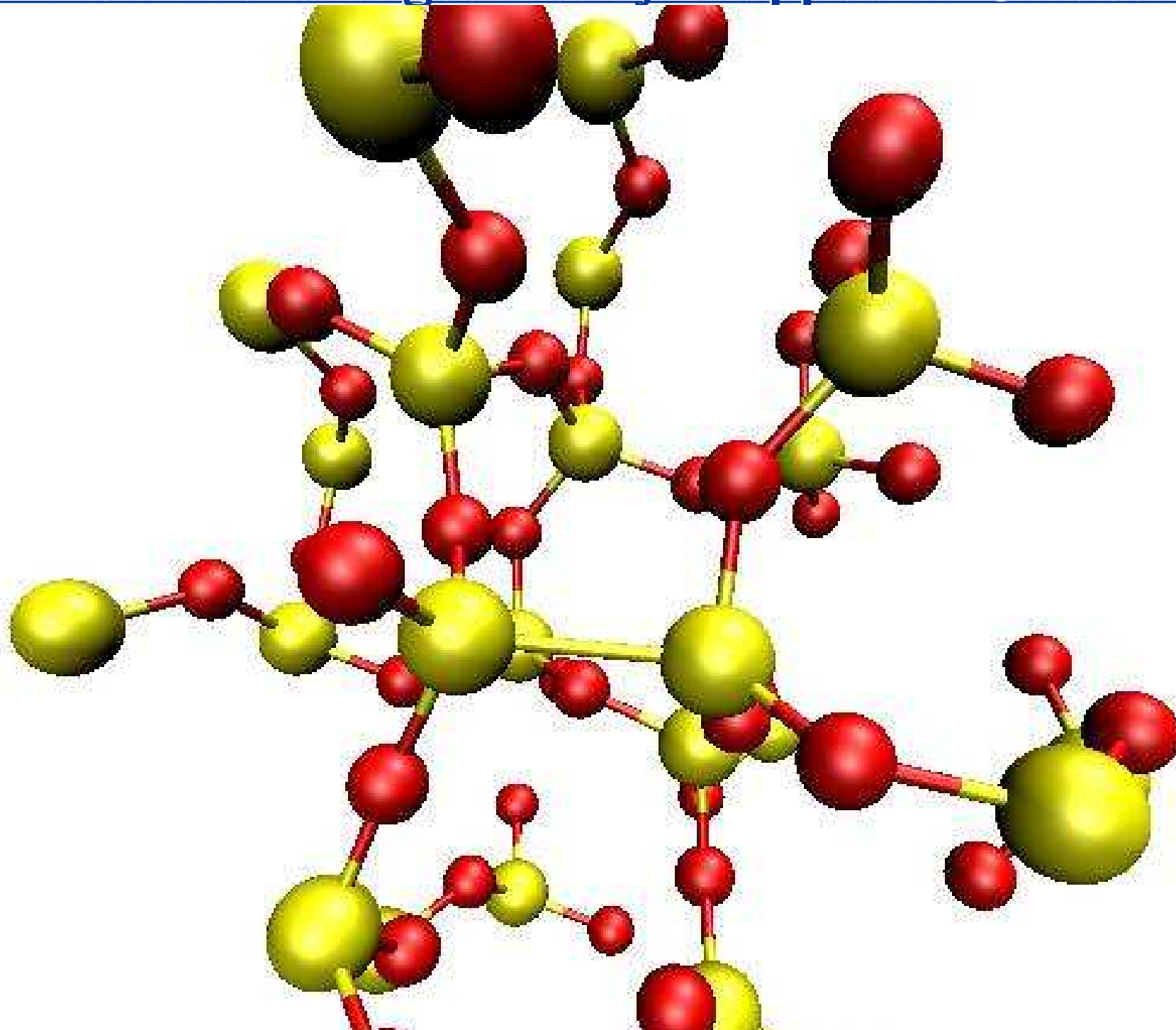
Conventional model

Elastic tunneling, results in a 'tunneling front' (1 nm in 10 ms)
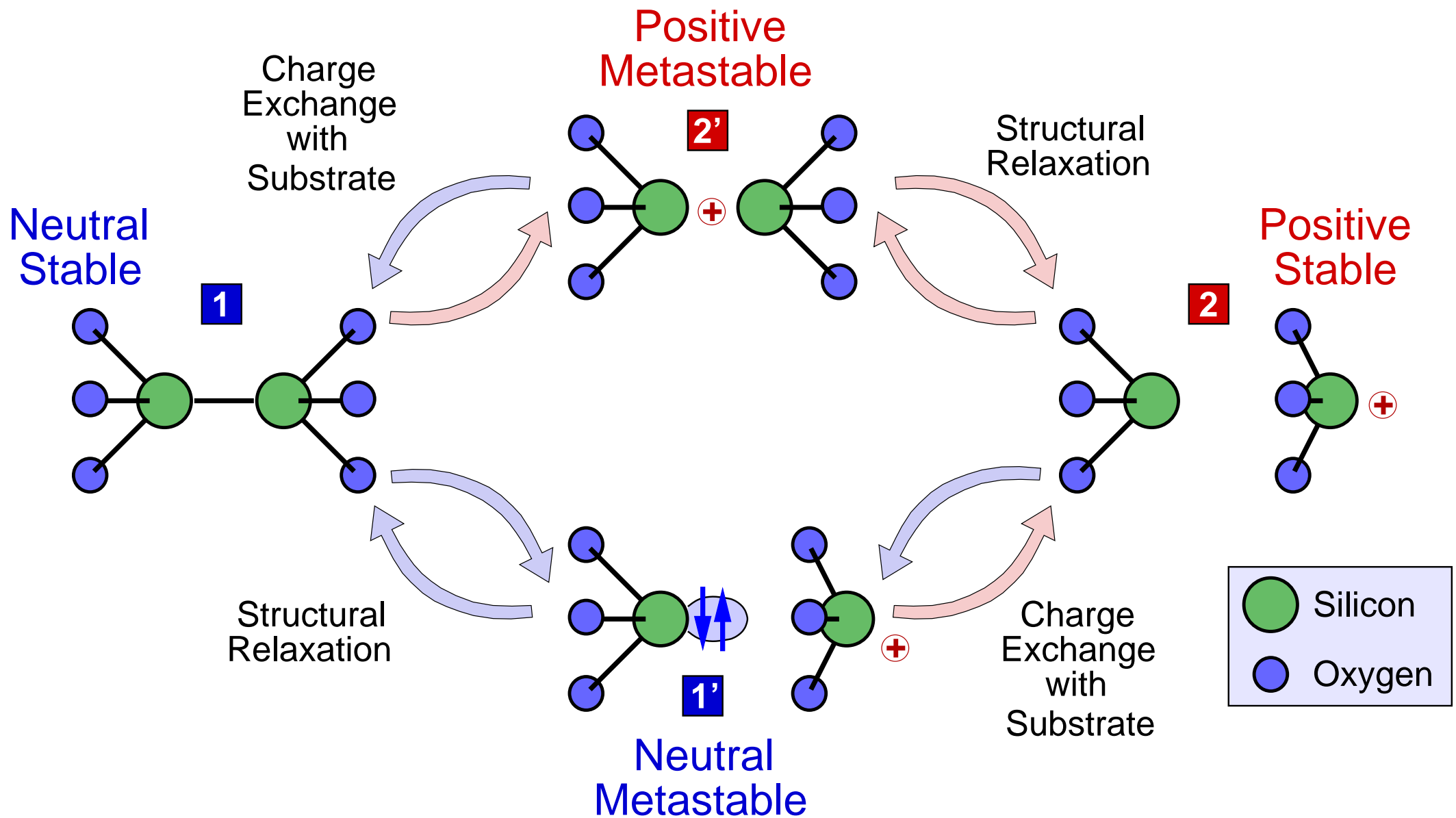
Nonradiative Multiphonon Theory

Developed for F-centers and defects in III-V semiconductors[1] [2]

O in GaP, Fe and Cr in GaAs, etc.

Thermal vibrations modulate E_T
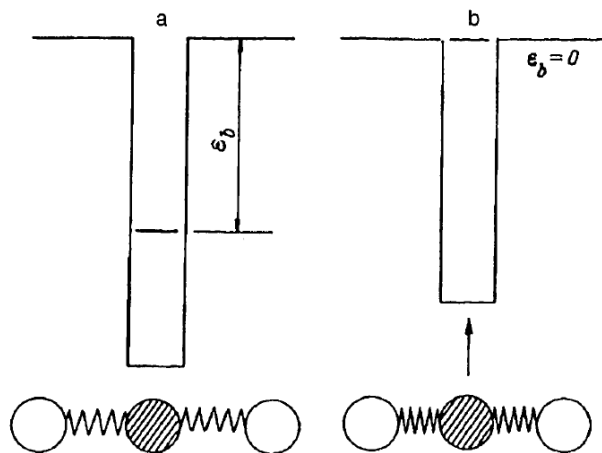
Total energy: vibrational plus electronic

Adiabatic approximation

Linear coupling: changes defect level

Quadratic coupling: changes in vibrational frequency
Explains optical energies

[1] Huang and Rhys, Proc.Roy.Soc.A 50   [2] Henry and Lang, PRB 77
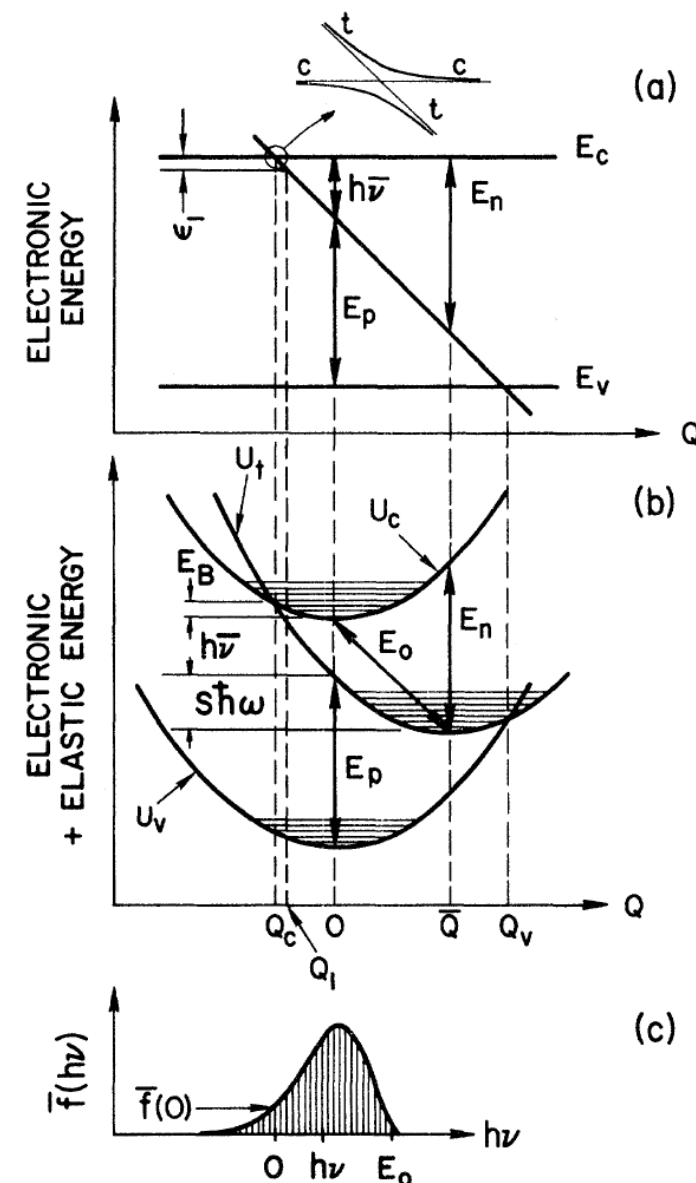
Model

Different adiabatic potentials for the neutral and positive defect

Metastable states 2' and 1' are secondary minima

Thermal transitions to ground states 1 and 2

Stochastic Markov-model for defect kinetics based on multiphonon theory

Nonradiative multiphonon model

Inelastic tunneling, no 'tunneling front'

Normal random telegraph noise (RTN)

Very similar energetical position of the minimas 1 and 2

Kirton and Uren, Adv. Phys. '89

Anomalous RTN

Very similar energetical position of the three minima 1, 2, and 1'

Uren *et al.*, PRB '88

Temporary random telegraph noise (tRTN)

Very similar energetical position of the minima 2 and 1'
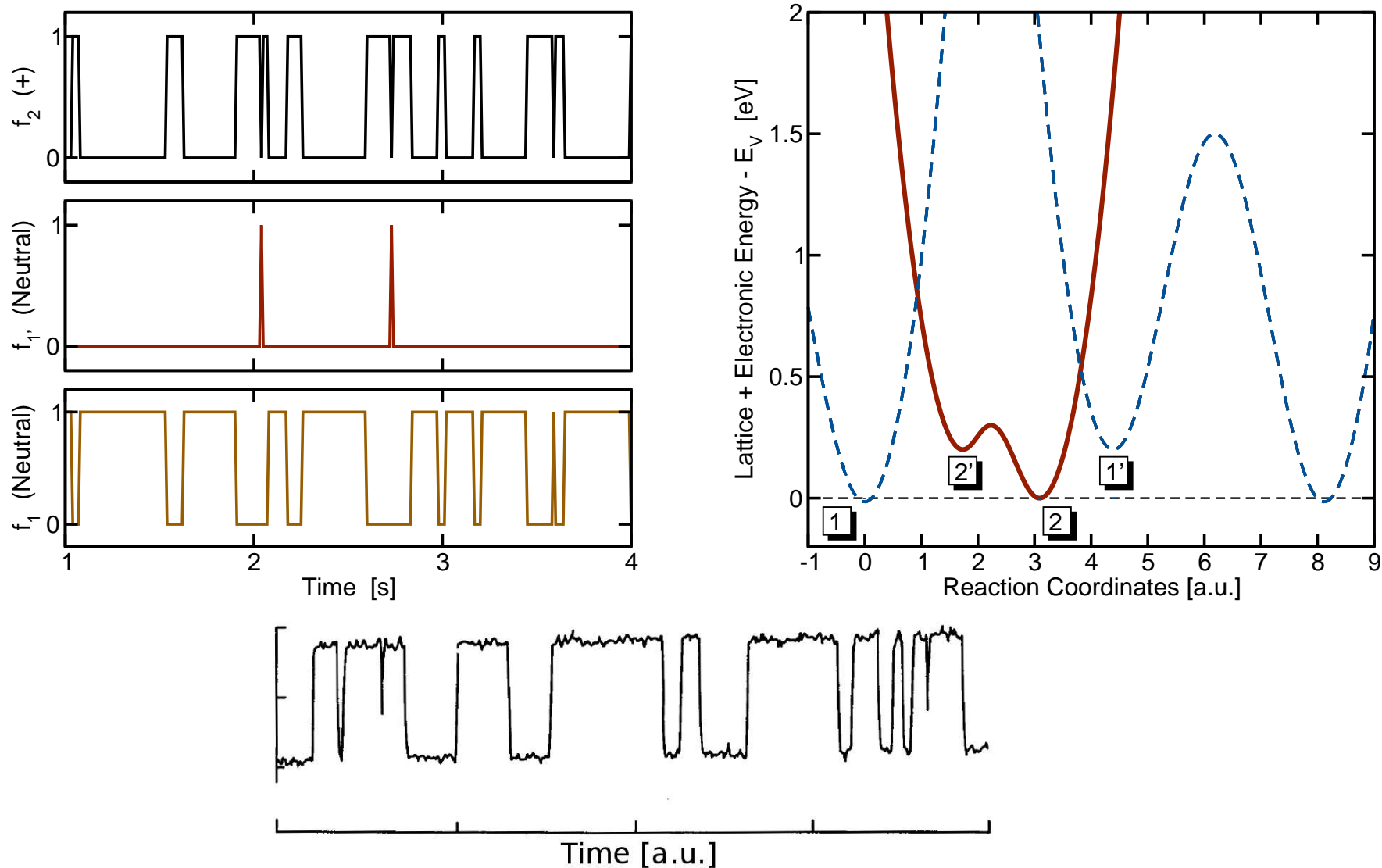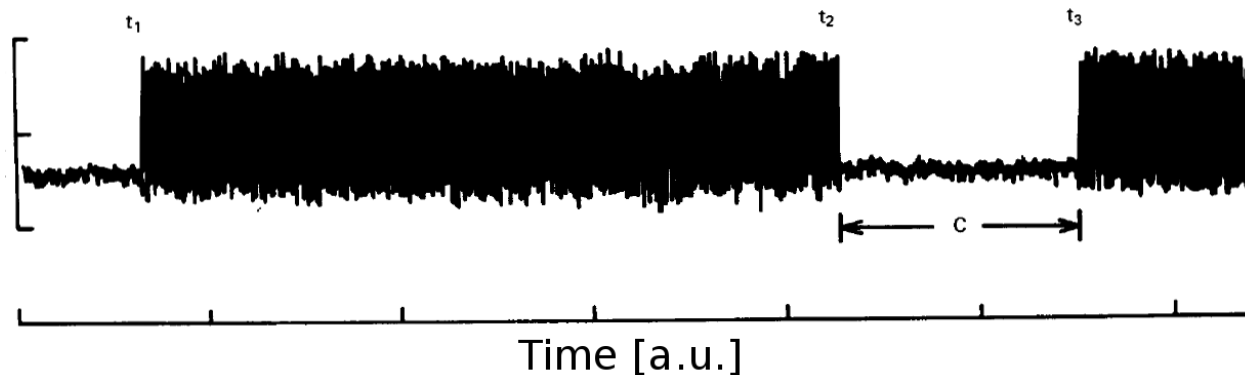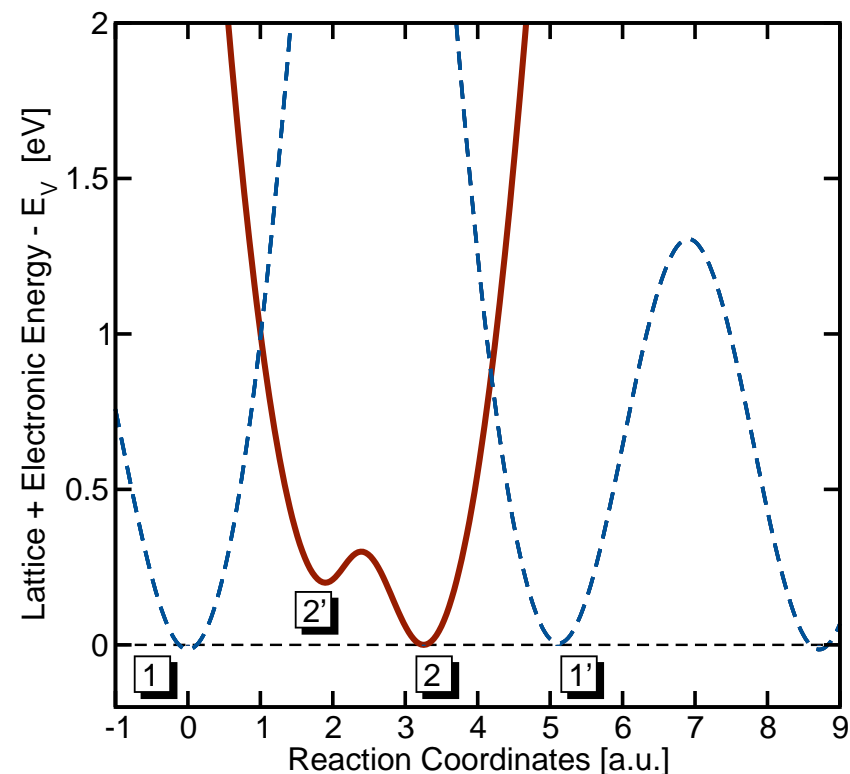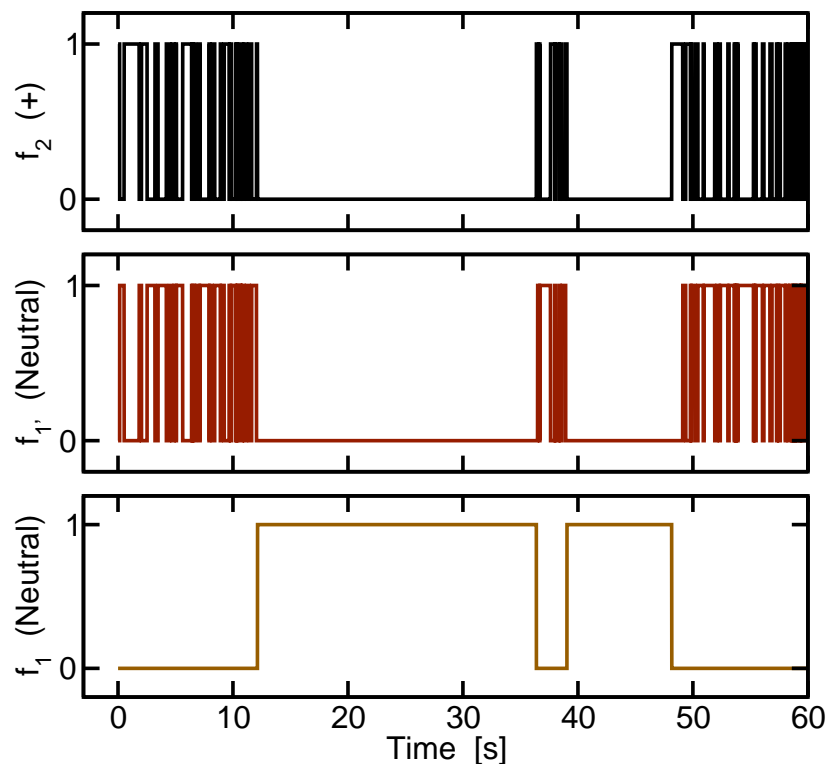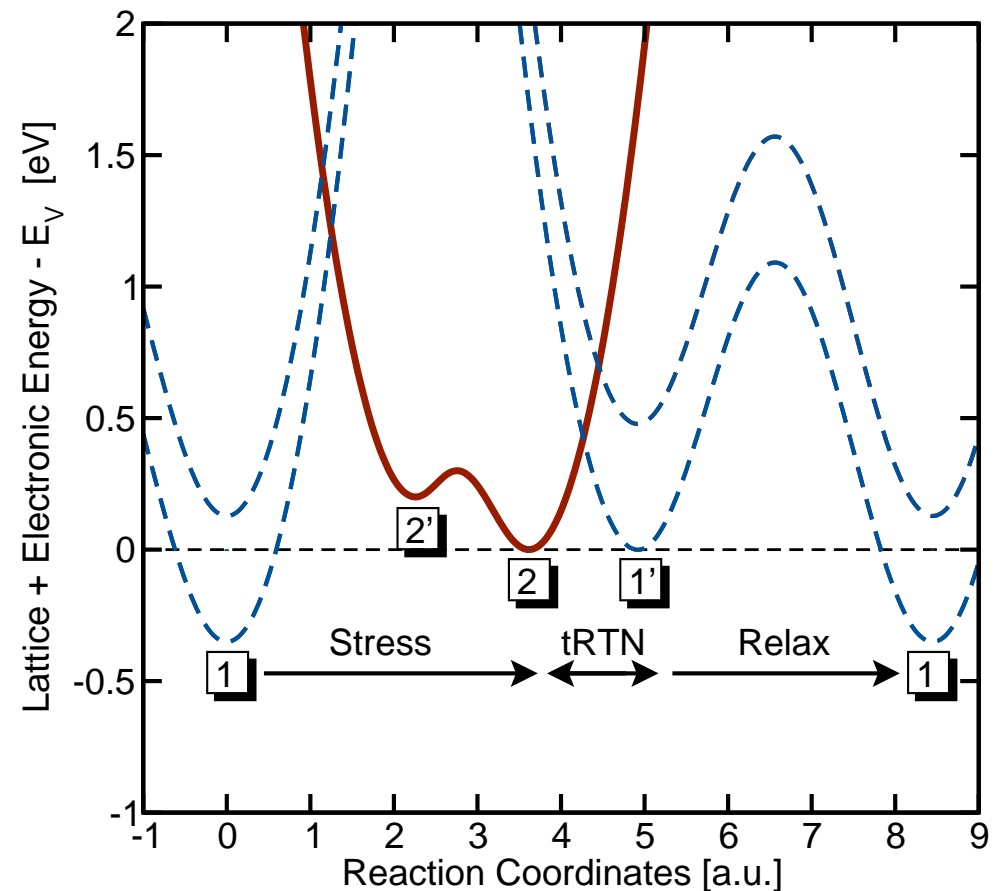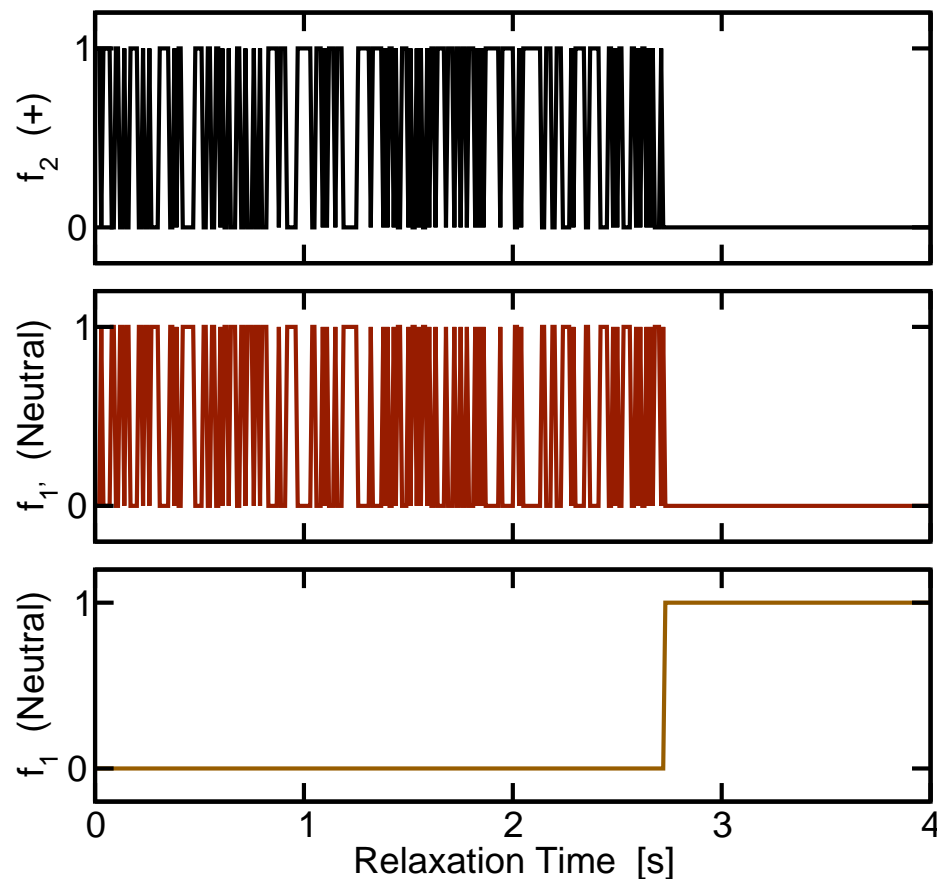
Quantitative Model Evaluation

Excellent agreement for both capture and emission time constants

Capture time: particularly important for back-extrapolation of stress data

Emission time: determines recovery behavior

Does the defect act like a switching trap?

Depends on the defect configuration
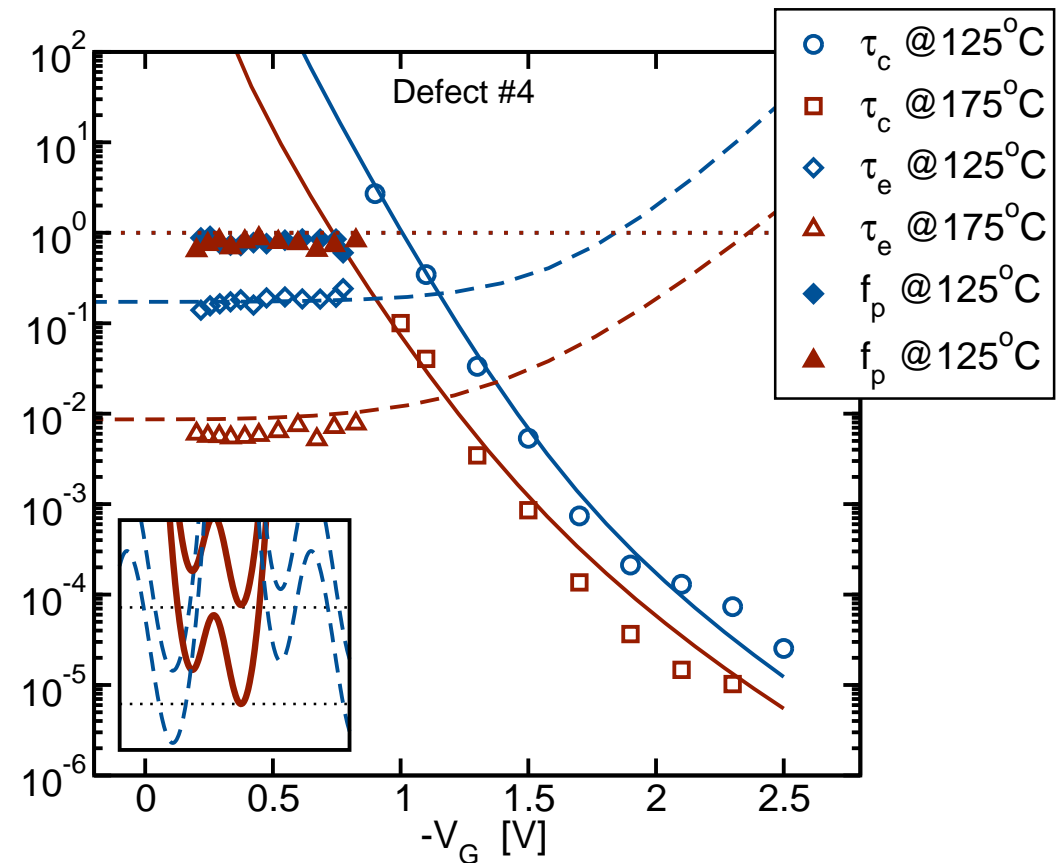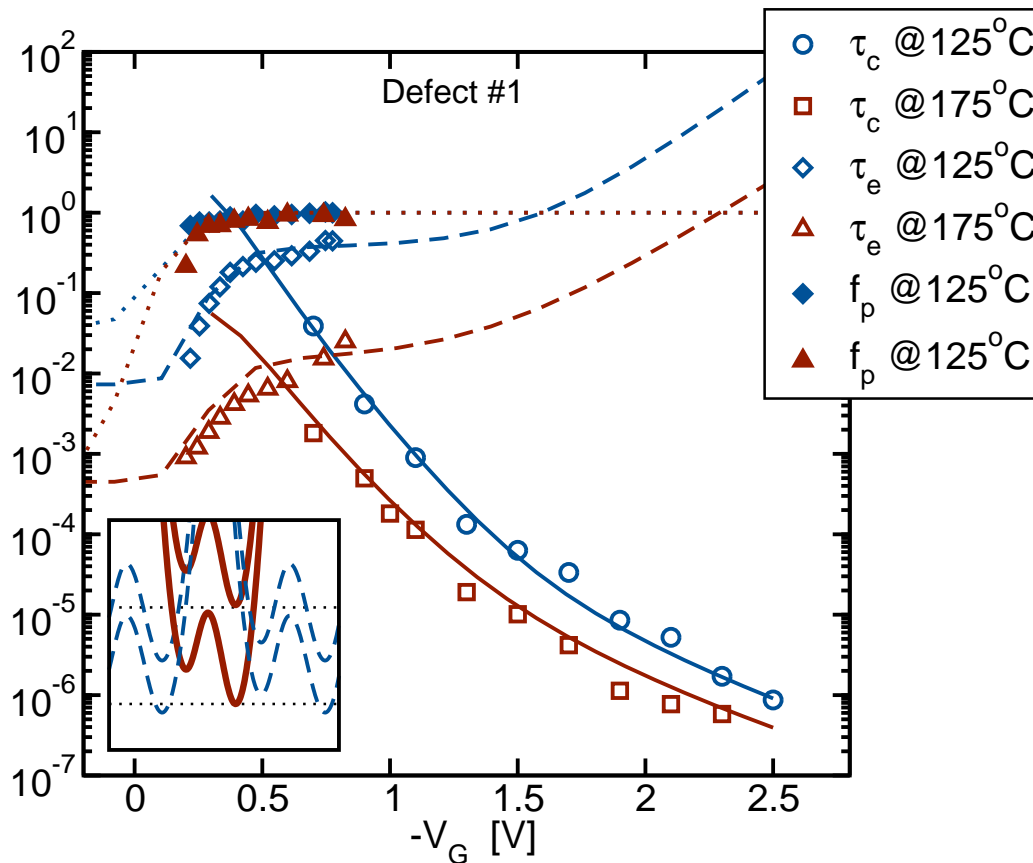
Model Summary

All features can be consistently explained with a general defect model

Differences simple consequences of defect potentials (amorphous oxide!)

Standard RTN

Anomalous RTN

Total Energy

Reaction Coordinate

● Neutral
○ Positively charged

Standard NBTI

NBTI Switching Trap/Temporary RTN

Stress

Relax
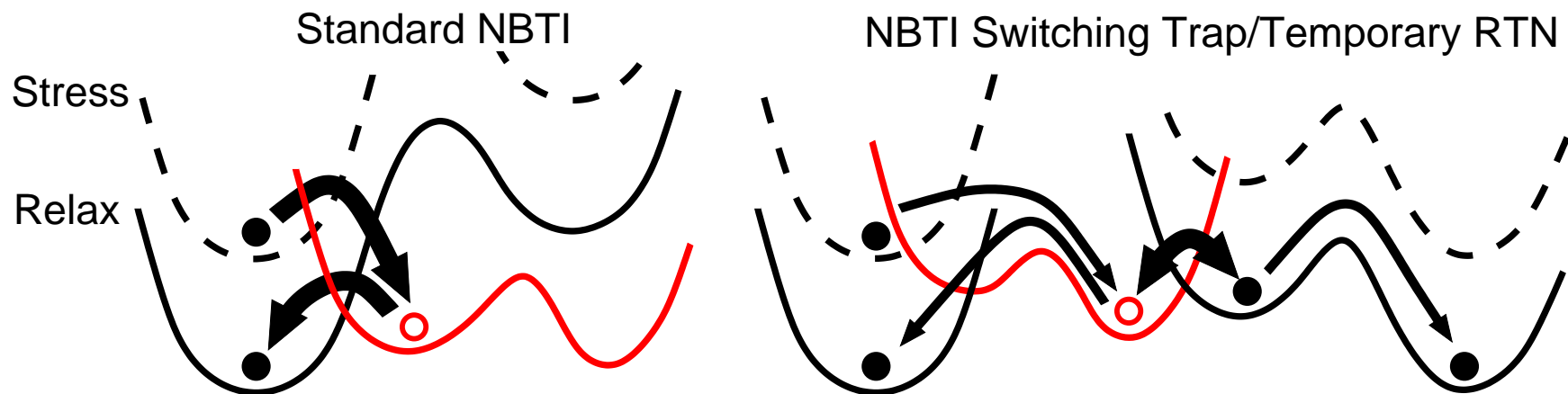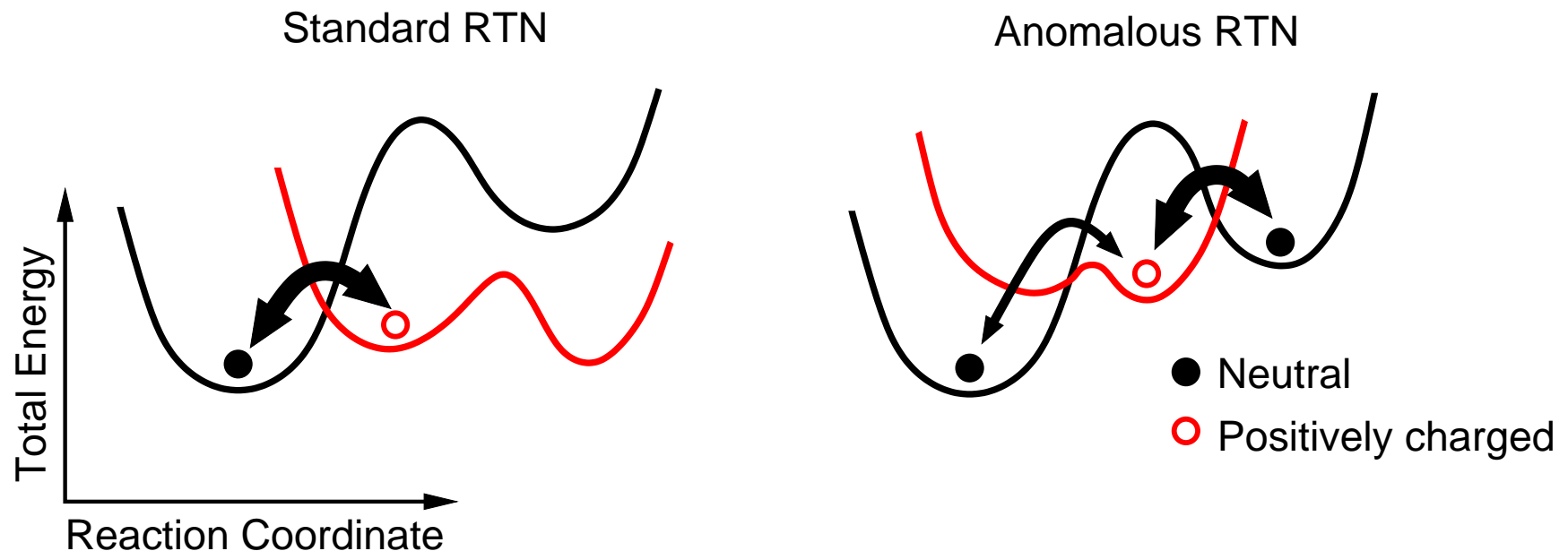
NBTI model based on switching traps (Grasser *et al.*, IRPS '09)
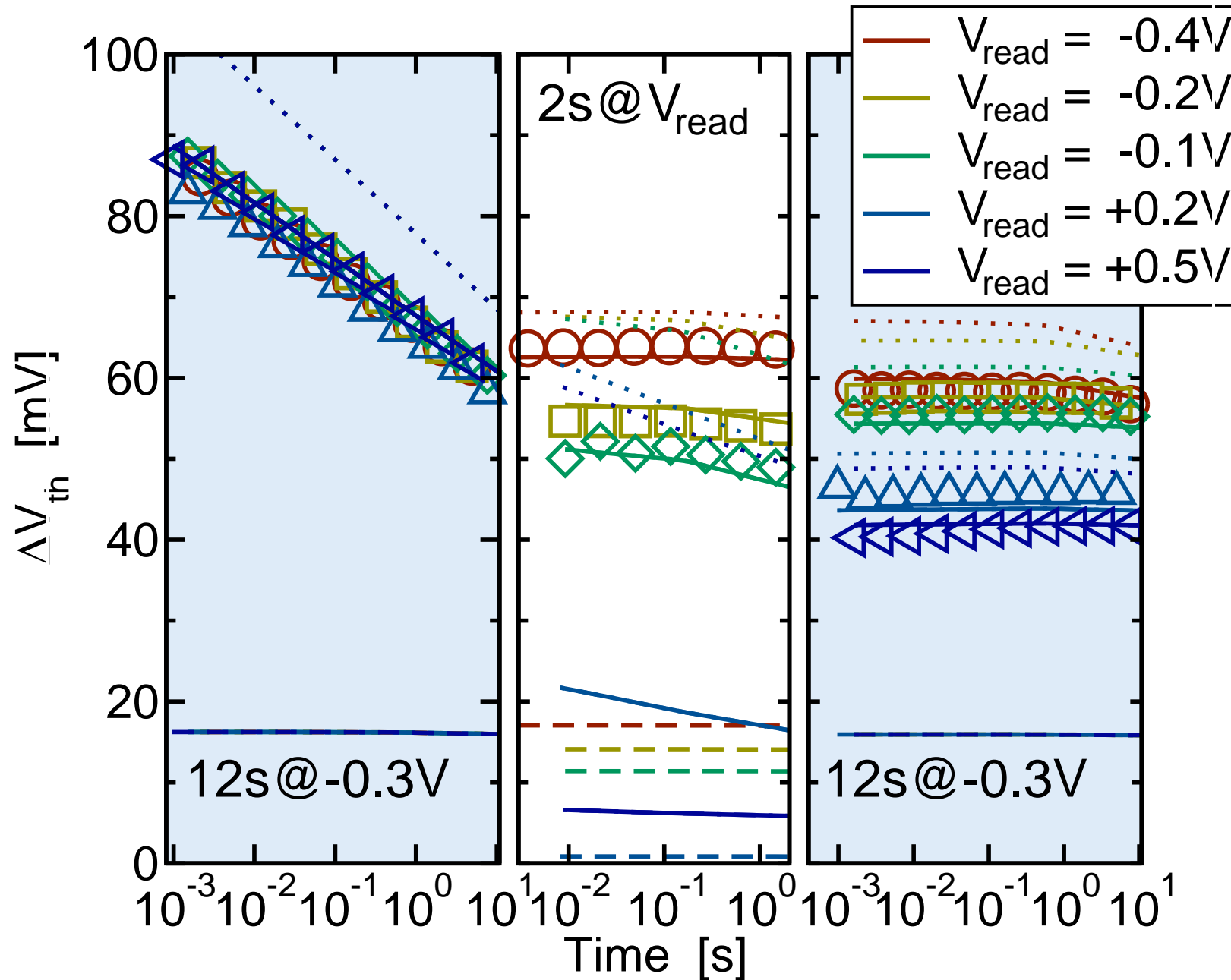
Why Would We Care?

How to Determine the Lifetime?

Small area devices: lifetime is a stochastic quantity [1]

Charge capture/emission stochastic events

Capture and emission times distributed

$N_t = 10^{12} \, \text{cm}^{-2}$; $W \times L = 100 \, \text{nm} \times 100 \, \text{nm} \Rightarrow 100$ defects;

[1] Grasser et al. IEDM '10

How to Determine the Lifetime?

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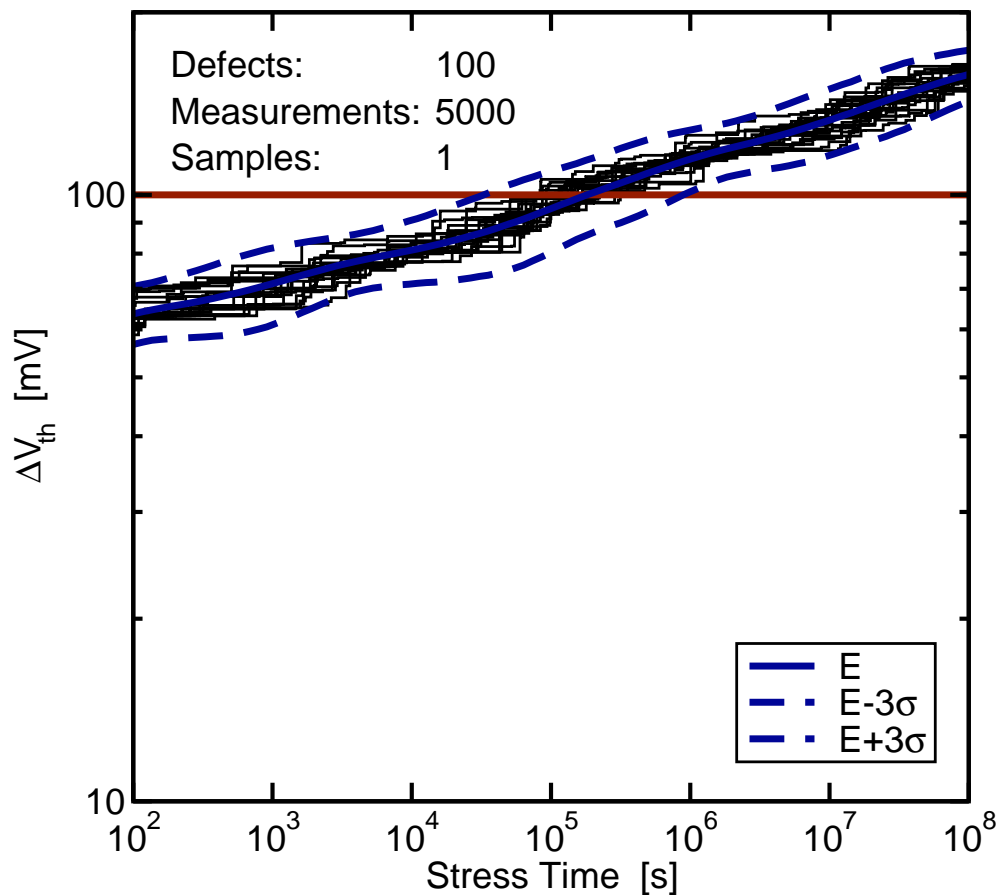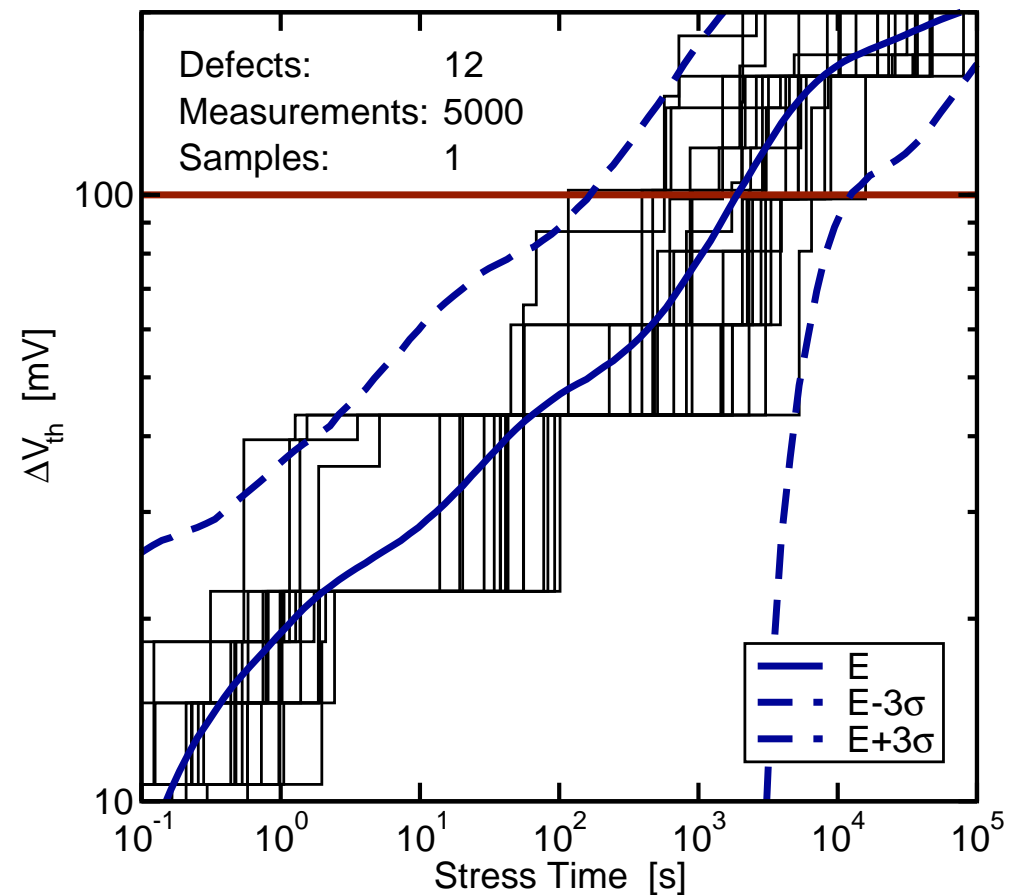
$N_t = 10^{12} \, \text{cm}^{-2}; \; W \times L = 100 \, \text{nm} \times 100 \, \text{nm} \Rightarrow 100 \text{ defects};$ $\qquad 35 \, \text{nm} \times 35 \, \text{nm} \Rightarrow 12 \text{ defects}$

How to Determine the Lifetime?

Small area devices: lifetime is a stochastic quantity [1]

- Charge capture/emission stochastic events
- Capture and emission times distributed
- Number of defects follow Poisson distribution

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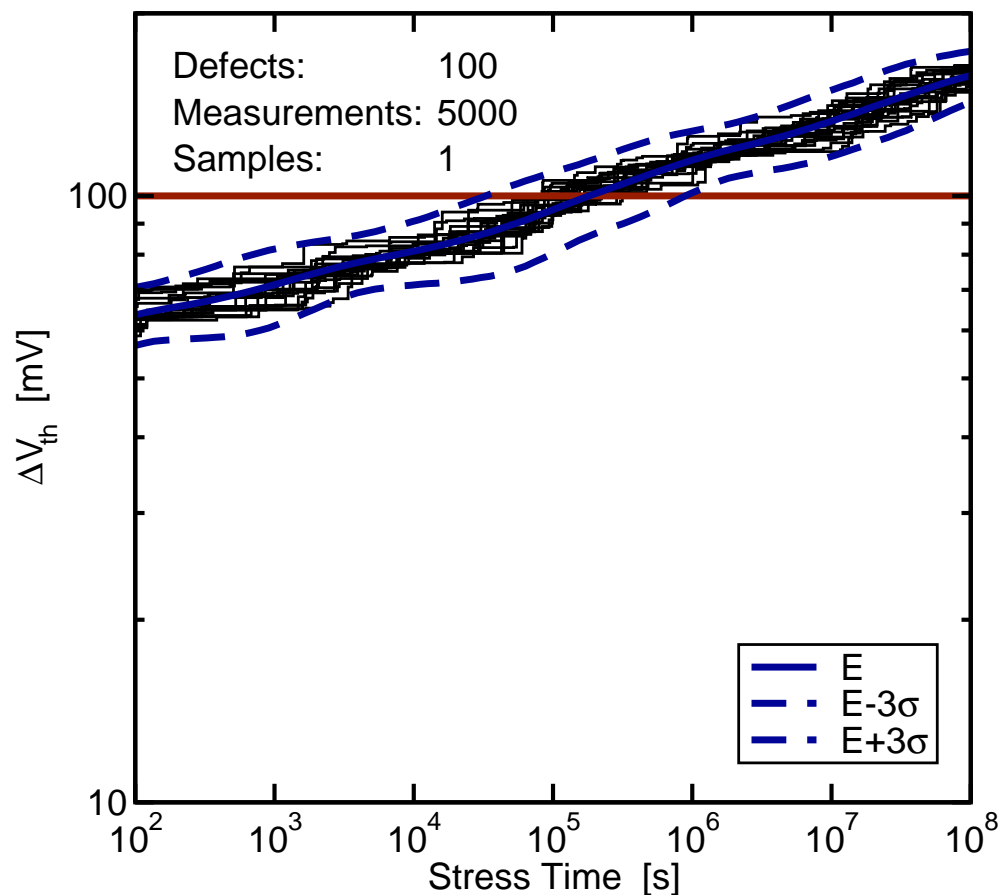[1] Grasser *et al.* IEDM '10

Small area devices: lifetime is a stochastic quantity

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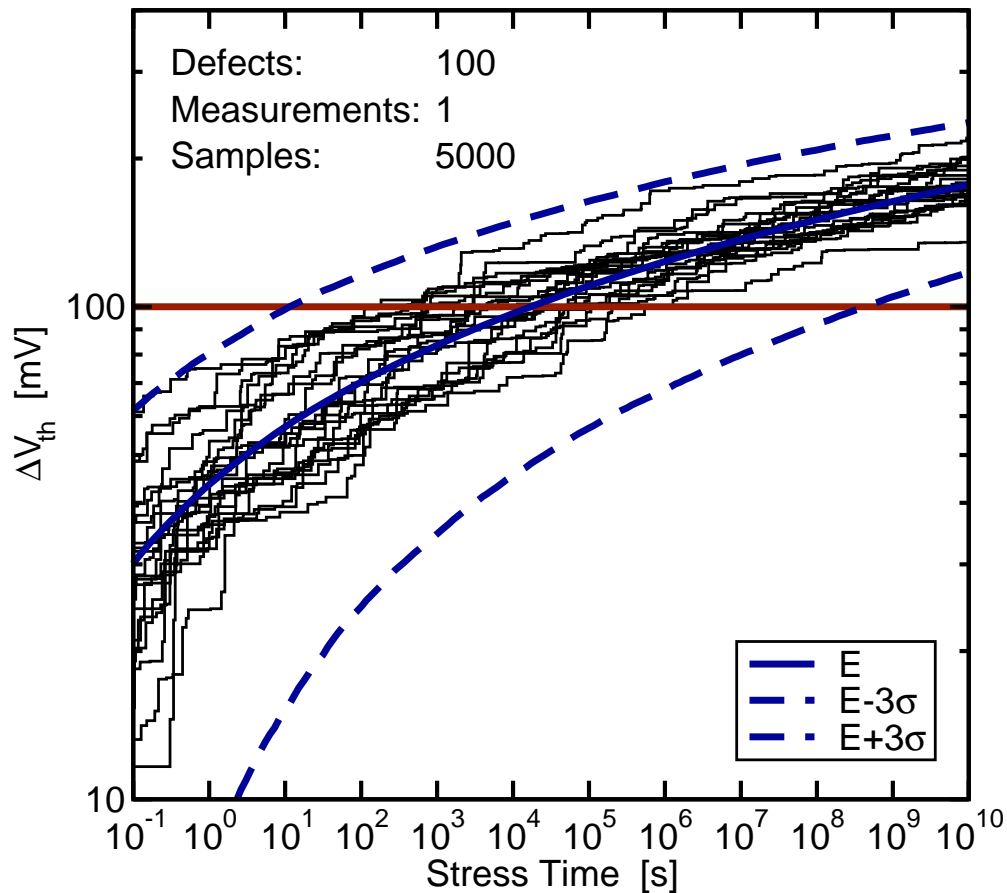
$N_t = 10^{12}\ cm^{-2}$; $W \times L = 100\ nm \times 100\ nm \Rightarrow 100$ defects;
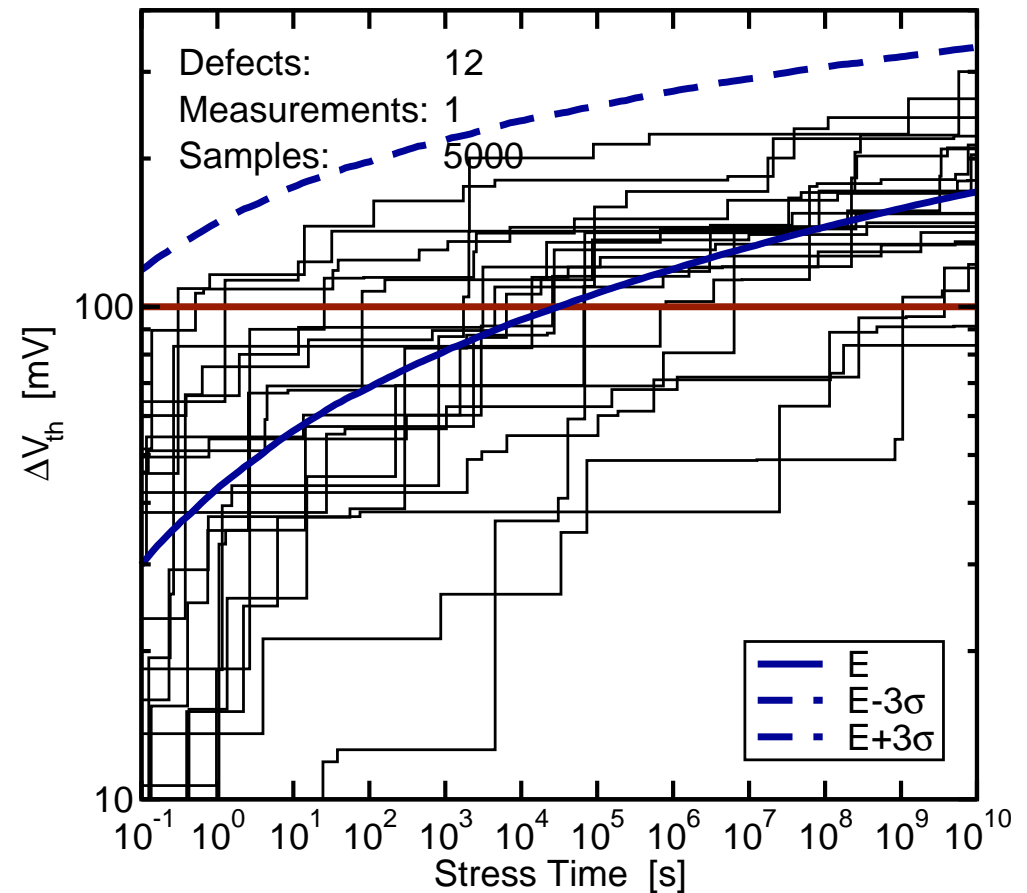
$35\ nm \times 35\ nm \Rightarrow 12$ defects

Stochastic Lifetimes

Distribution of lifetime[1]

Variance increases with decreasing number of defects
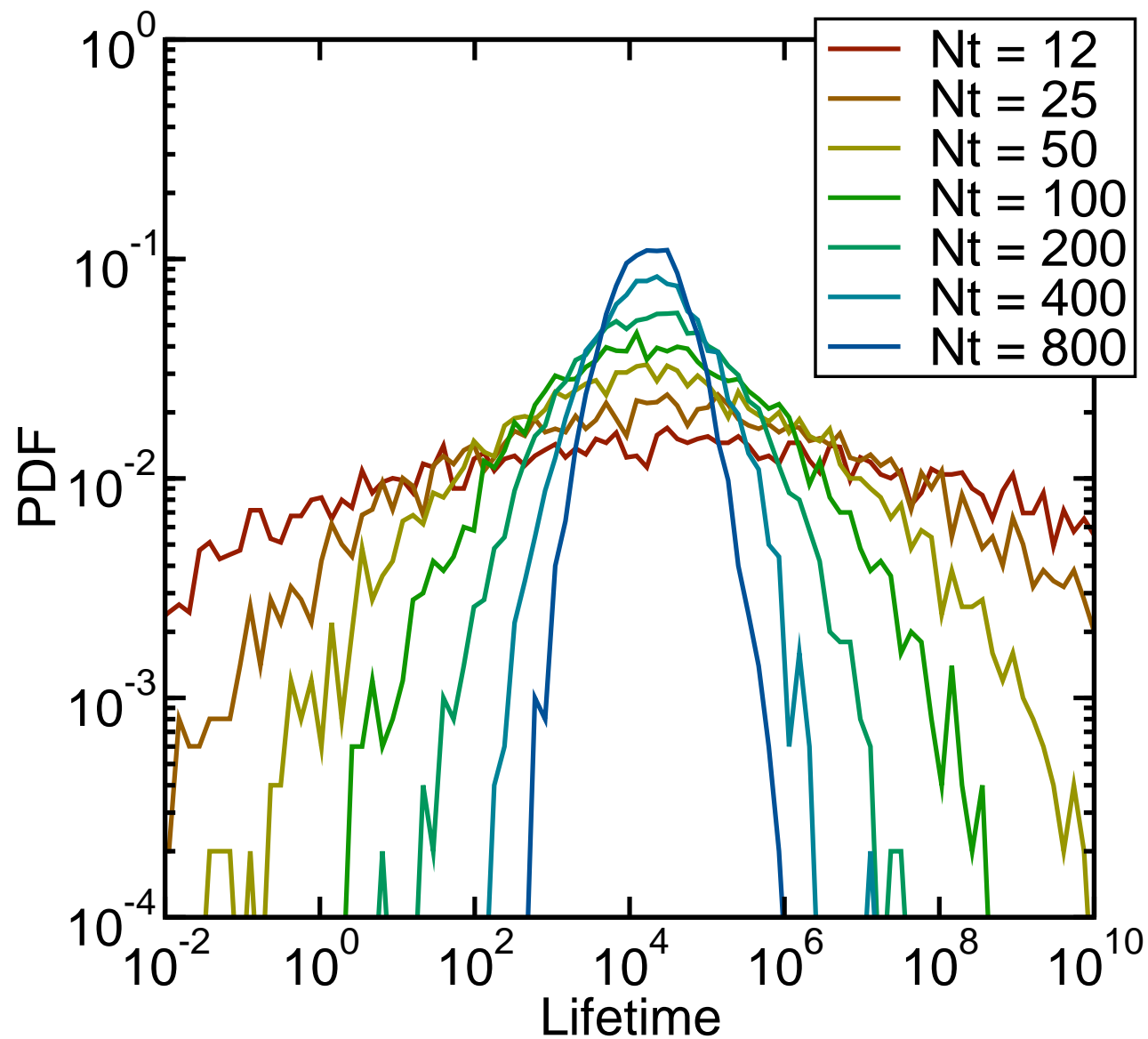
How to Model This with SPICE?
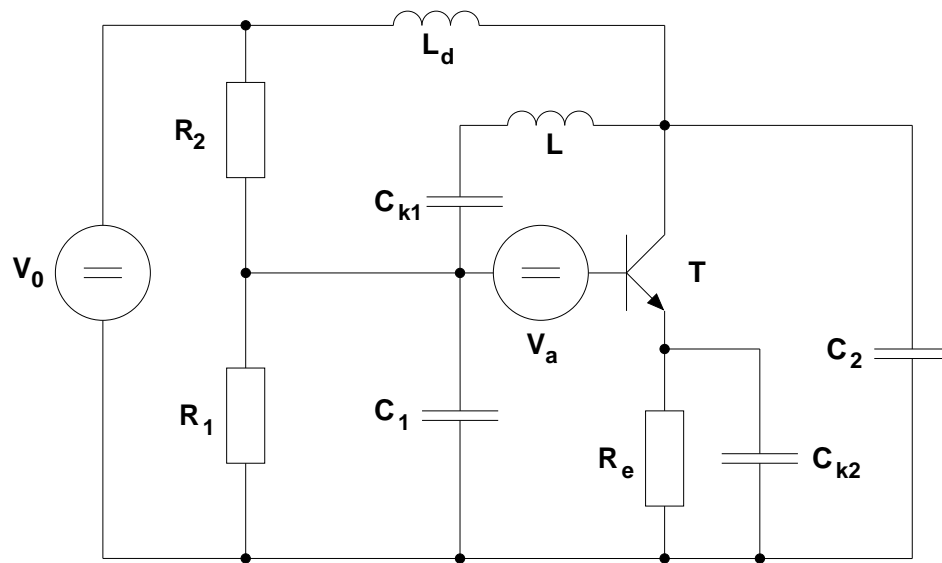
Compact Modeling

First attempt: approximate multi-state model by two-state model[1] [2]

    Try to capture the notoriously difficult dynamics first

    Effective capture and emission time constants

Differential equation for a two-state model

    Corresponds to an RC equivalent circuit

    Two branches: charging vs. discharging
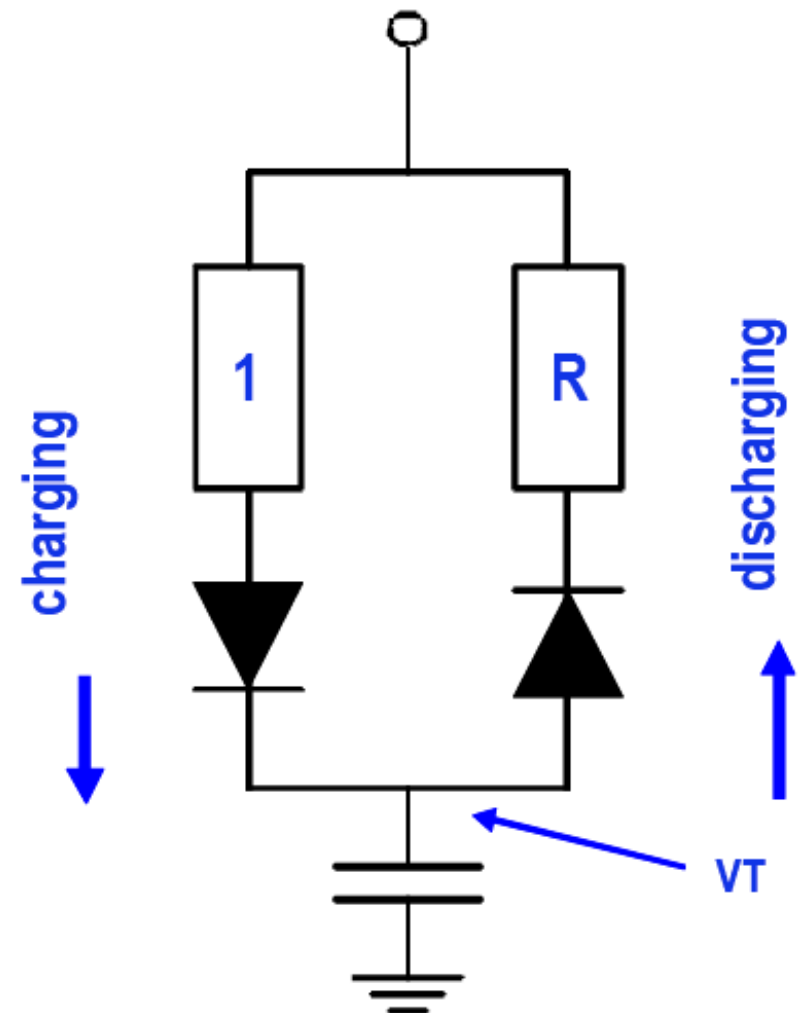
[1] Kaczer *et al.*, IRPS '10   [2] Reisinger *et al.*, IRPS '10

Compact Modeling

Example: modeling of recovery[1]

Crude approximation: 1 RC element every 3 decades

[1] Reisinger *et al.*, IRPS '10

Example: modeling of recovery[1]

Finer approximation: 2 RC elements every 3 decades
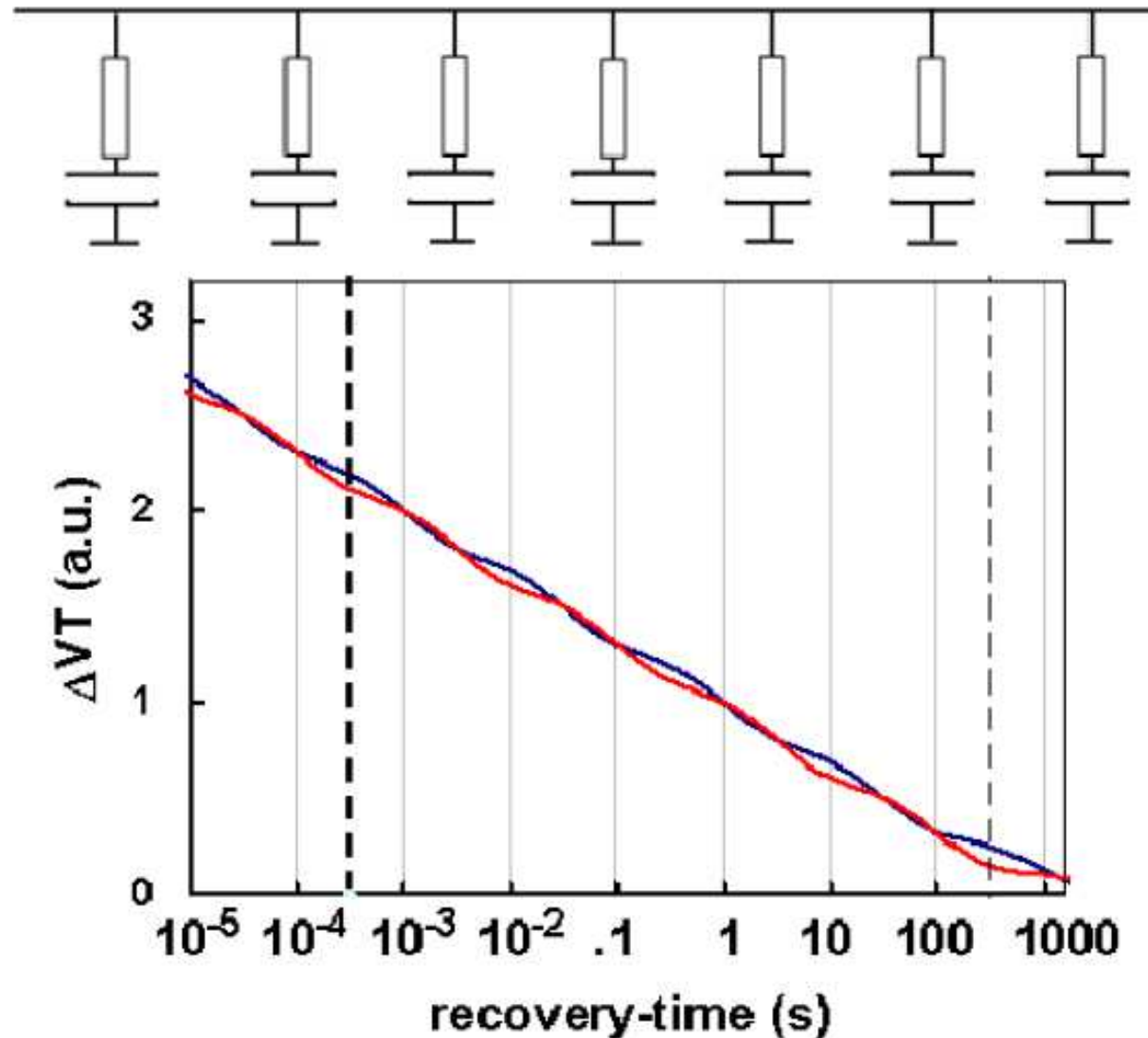
[1] Reisinger *et al.*, IRPS '10

Extraction of the time constants[1]
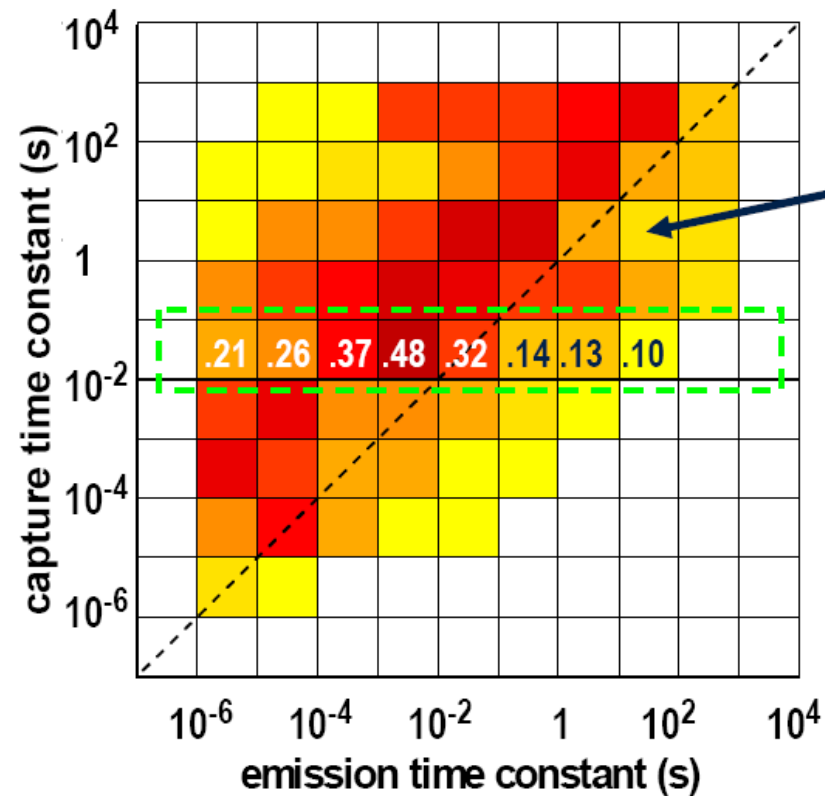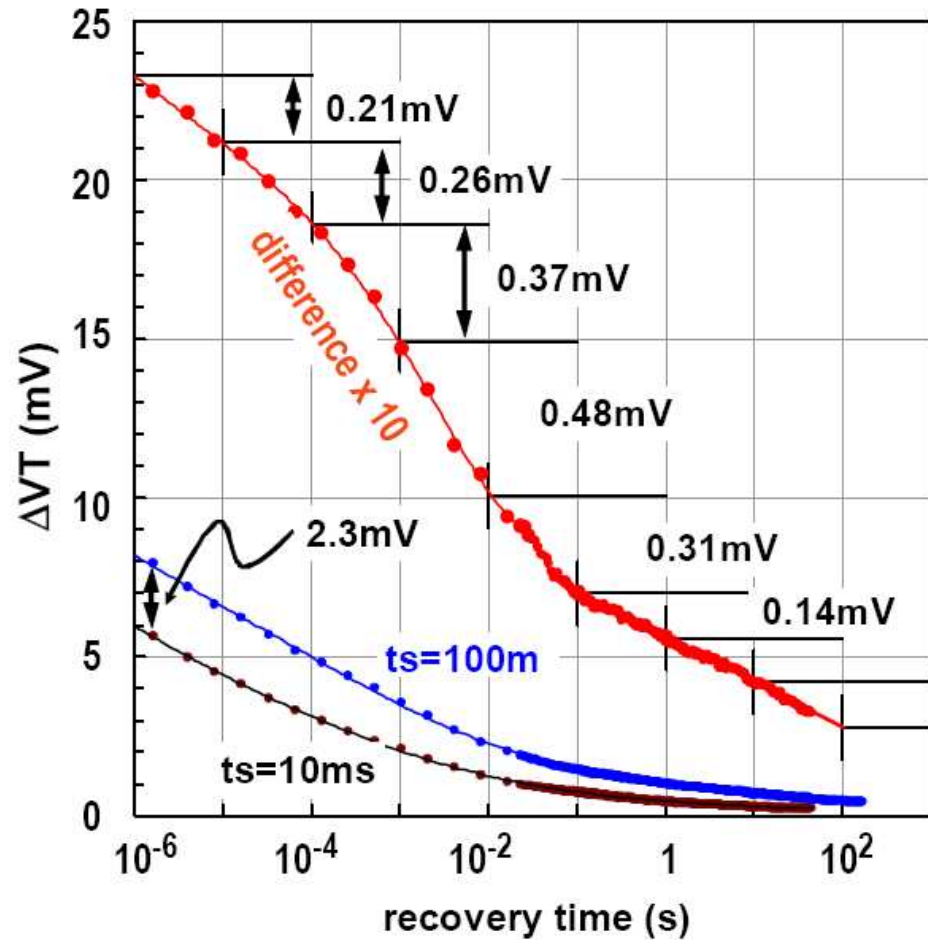
[1] Reisinger *et al.*, IRPS '10

Compact Modeling

Example: dynamic stress/recovery experiment[1]

same data as on left side, recovery on log time scale (to restore the fast recovery times during the fast downturns)

almost perfect fit, max.-error < 0.3 mV, note the lin-scale.
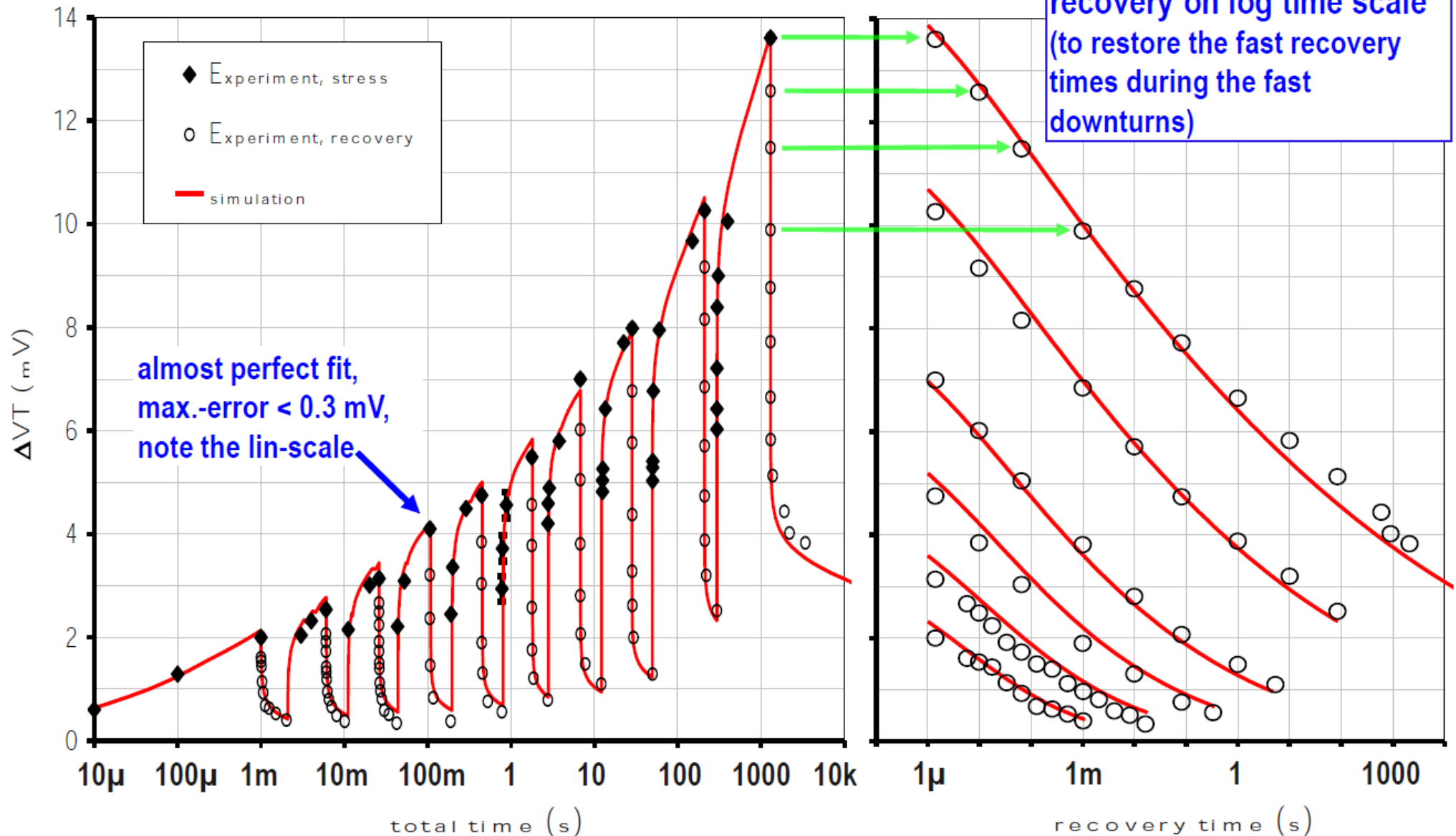
[1] Reisinger *et al.*, IRPS '10 and IRPS '11 (Tutorial)
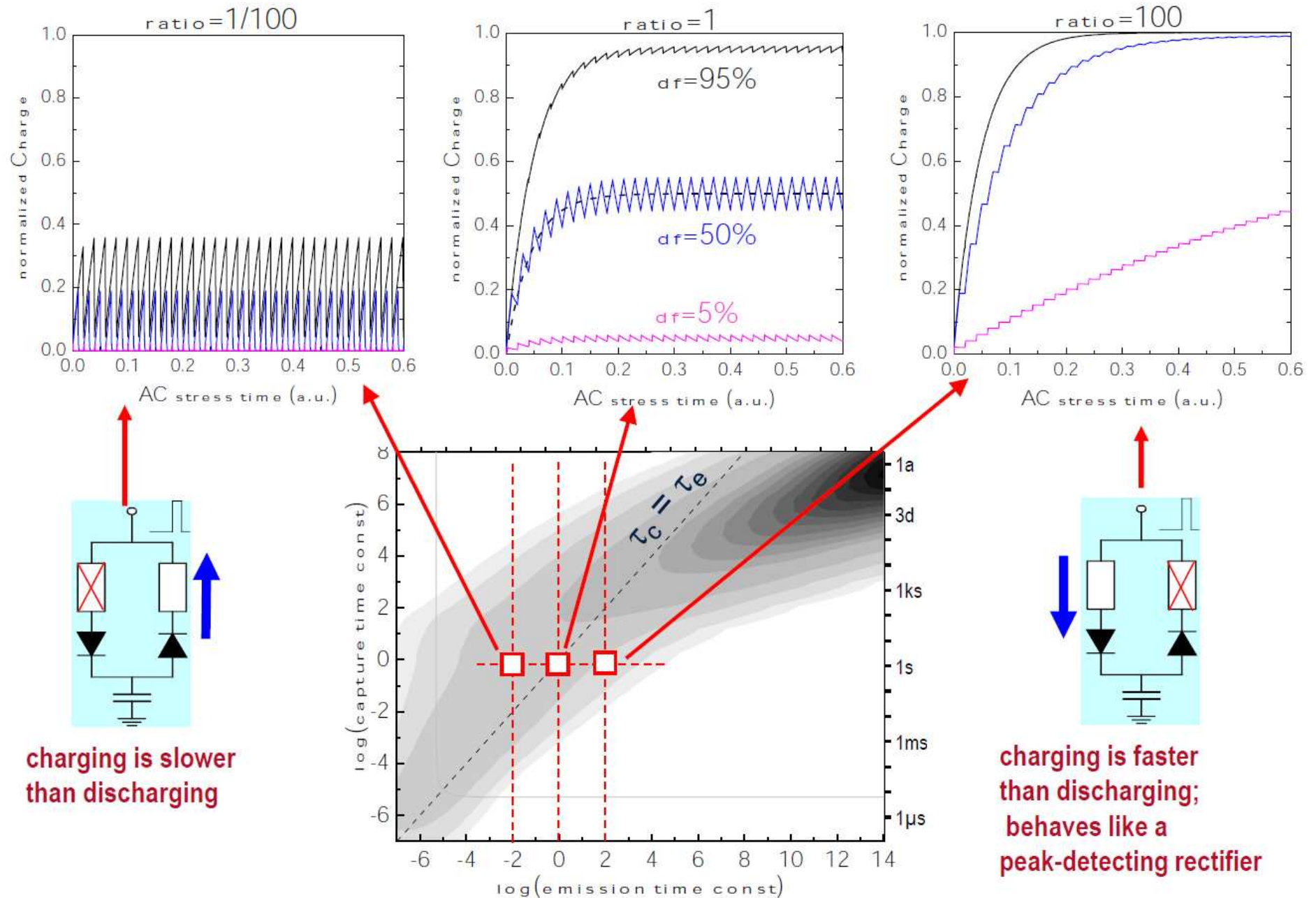
[1] Grasser *et al.*, IEDM '07 [2] Grasser *et al.*, IRPS '08 (Tutorial) [3] Reisinger *et al.*, IRPS '10/IRPS '11 (Tut.)

Notorious problem[1] [2] [3]

[1] Grasser *et al.*, IEDM '07 [2] Grasser *et al.*, IRPS '08 (Tutorial) [3] Reisinger *et al.*, IRPS '10/IRPS '11 (Tut.)
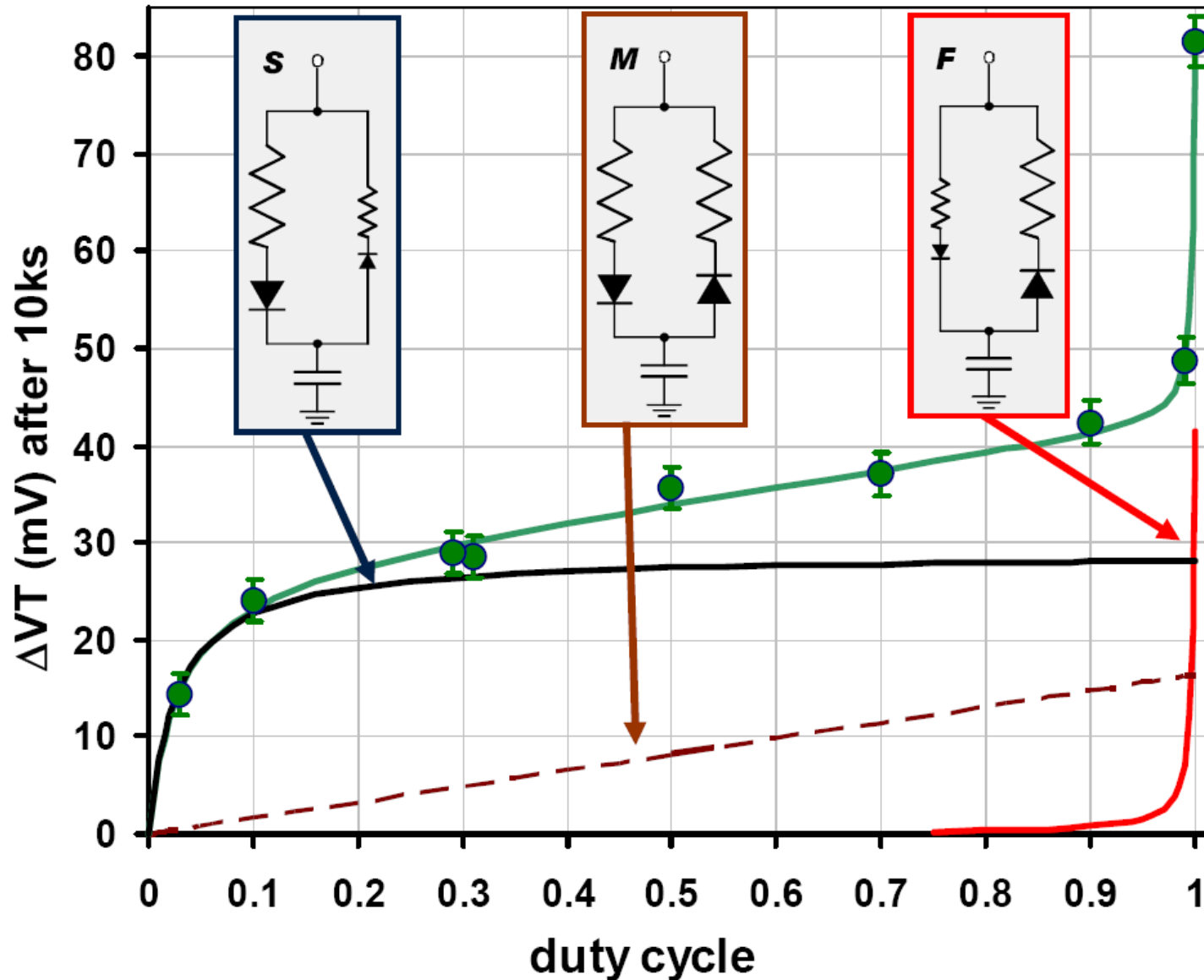
Stochastic Impact on Circuit

Implementation of stochastic behavior of distributed traps in VERILOG[1]

[1] Kaczer *et al.*, IRPS '11
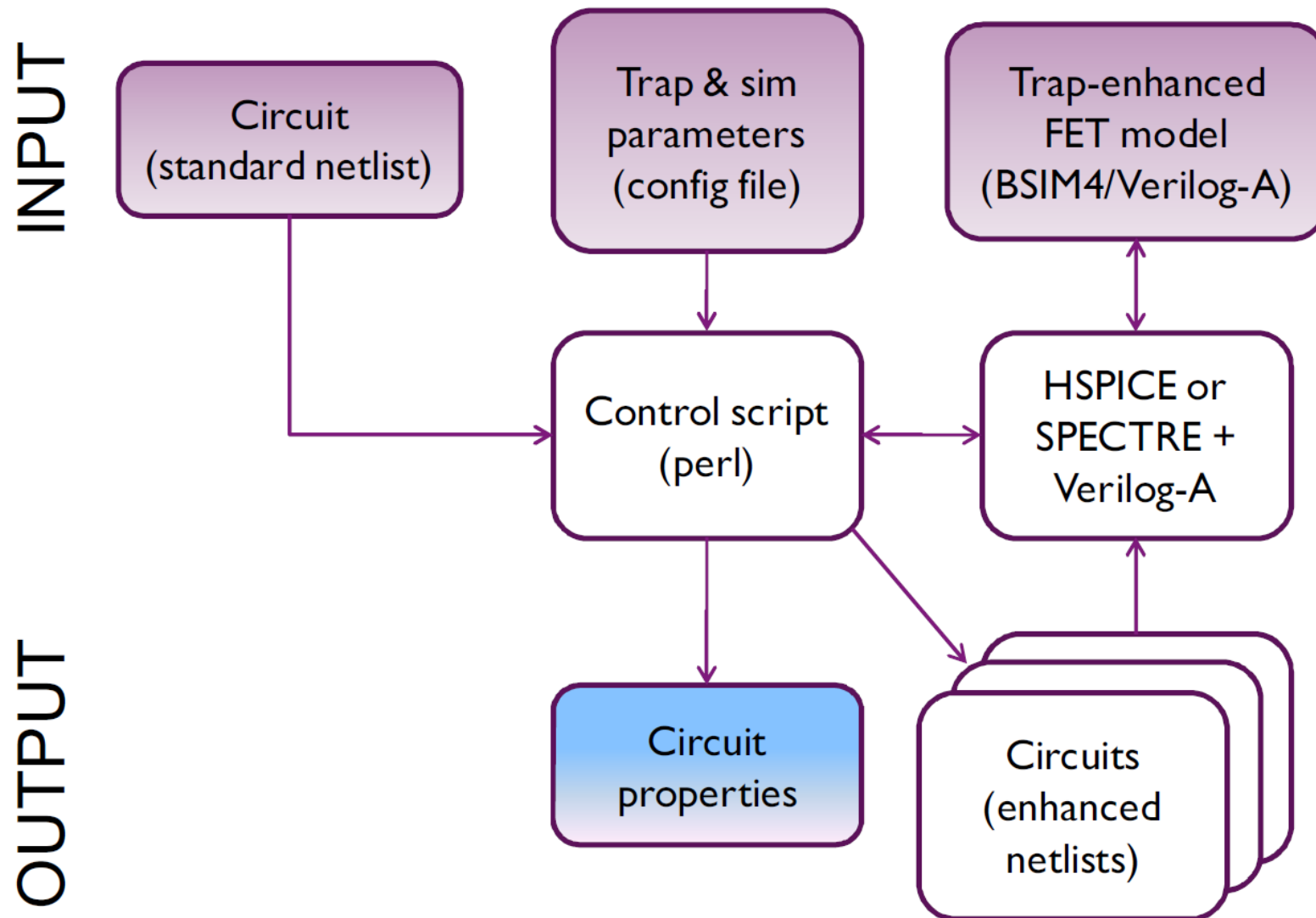
Stochastic Impact on Circuit

Model correctly incorporates distribution of ΔV_{th}

$t_s = 10^{-8}, 10^{-4}, 10^0, 10^4, 10^8$ s

$N = 1, 2, \ldots$

Y-axis: $\ln(-\ln(1-F))$

X-axis: $\Delta Vth / \eta$
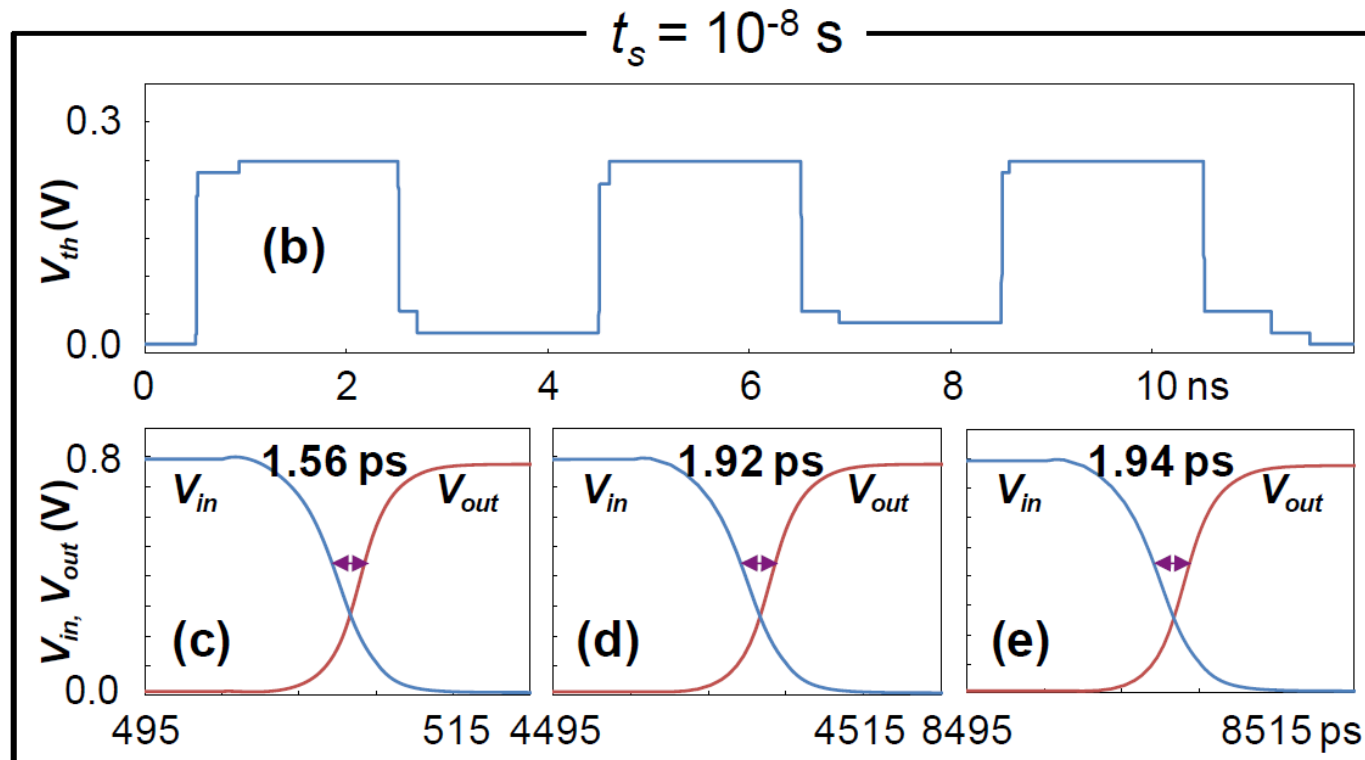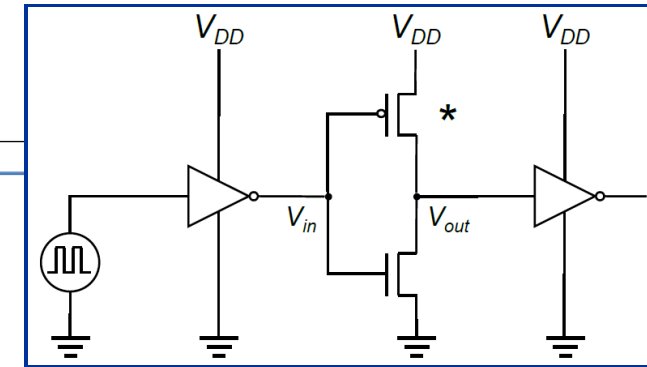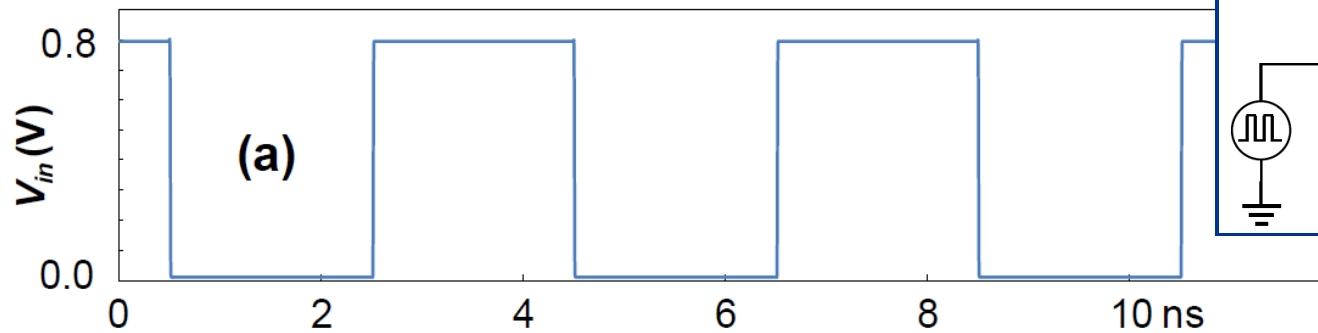
Stochastic Impact on Circuit

Example circuit with inverter: Jitter vs. NBTI[1]

Stochastic Impact on Circuit

Example circuit with inverter: Jitter vs. NBTI[1]

[1] Kaczer et al., IRPS '11
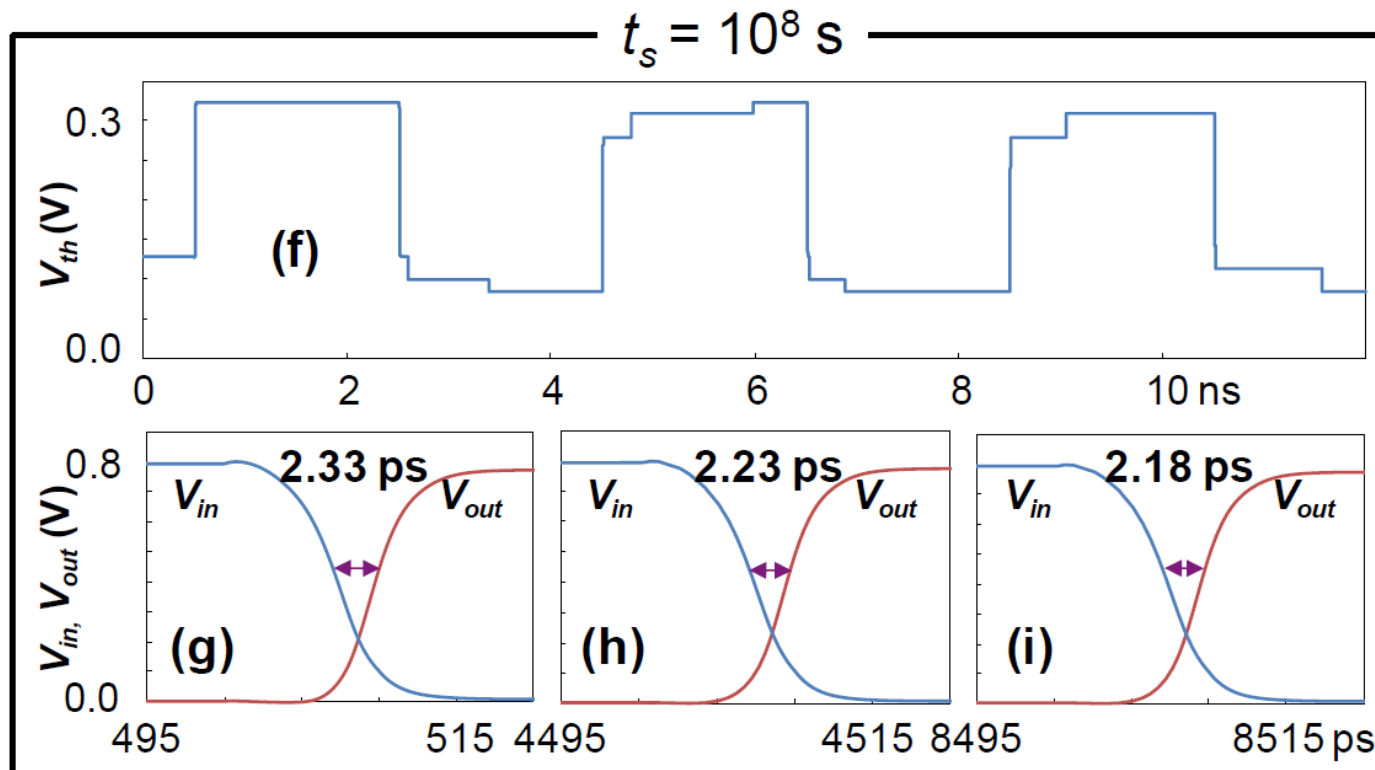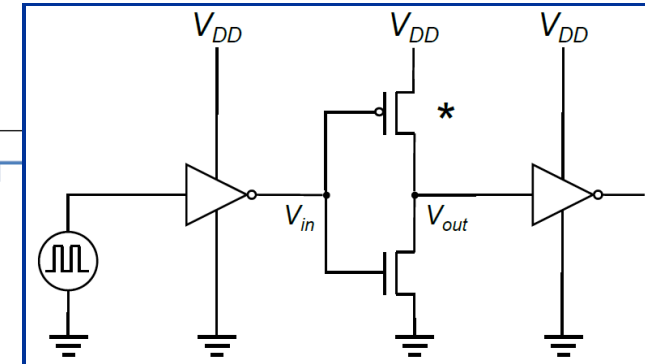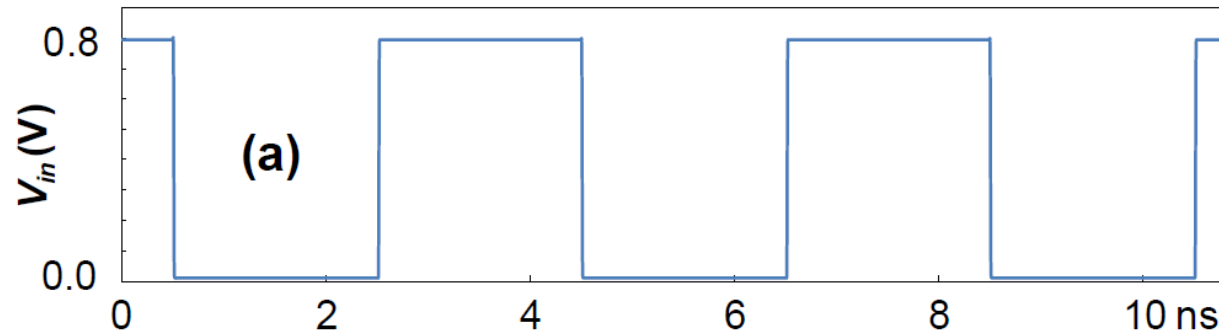
Stochastic Impact on Circuit

Distribution of delay widens with time[1]

[1] Kaczer *et al.*, IRPS '11
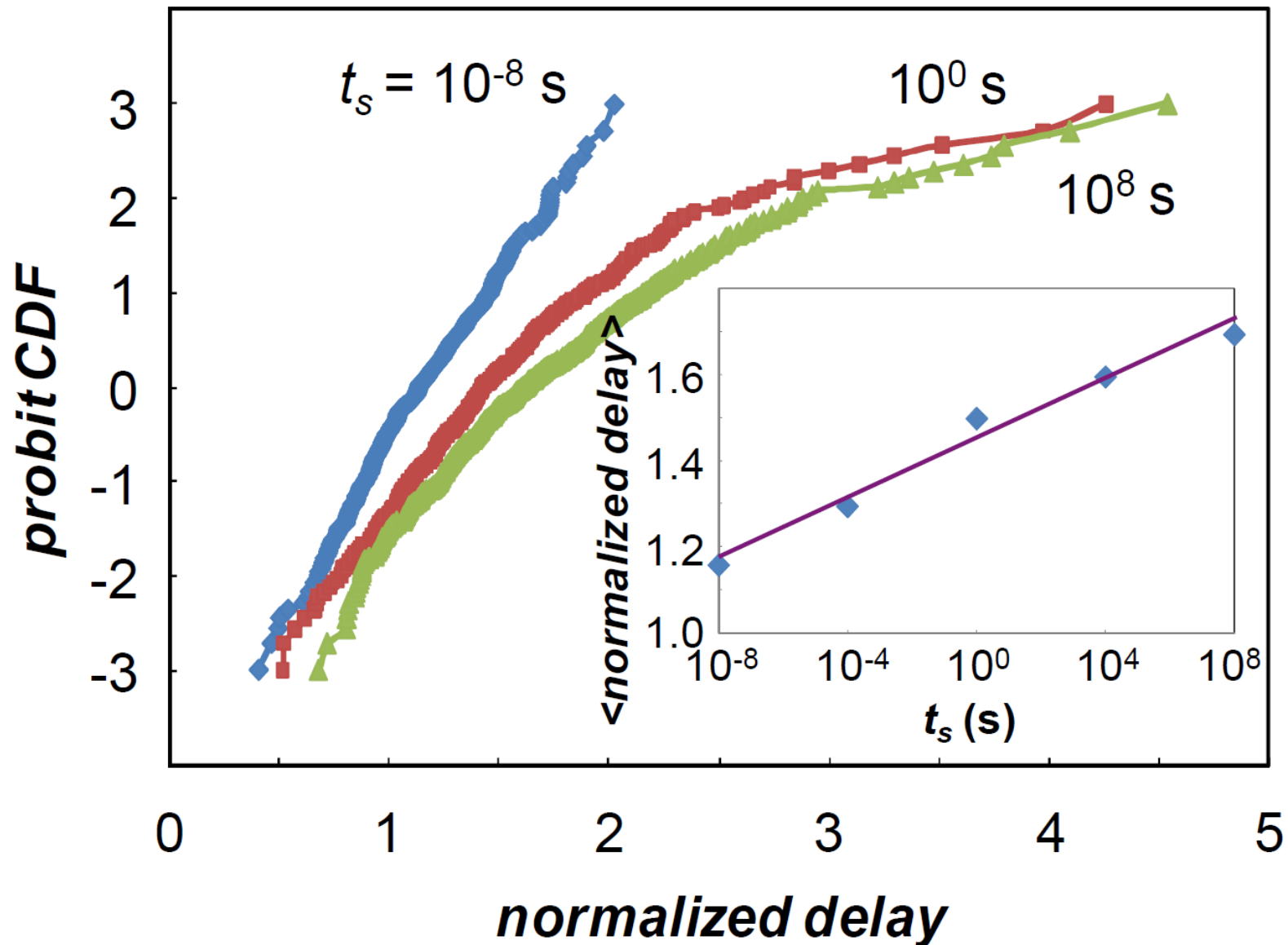
Stochastic Impact on Circuit

Normalized delay-power plot shifts and widens with time[1]
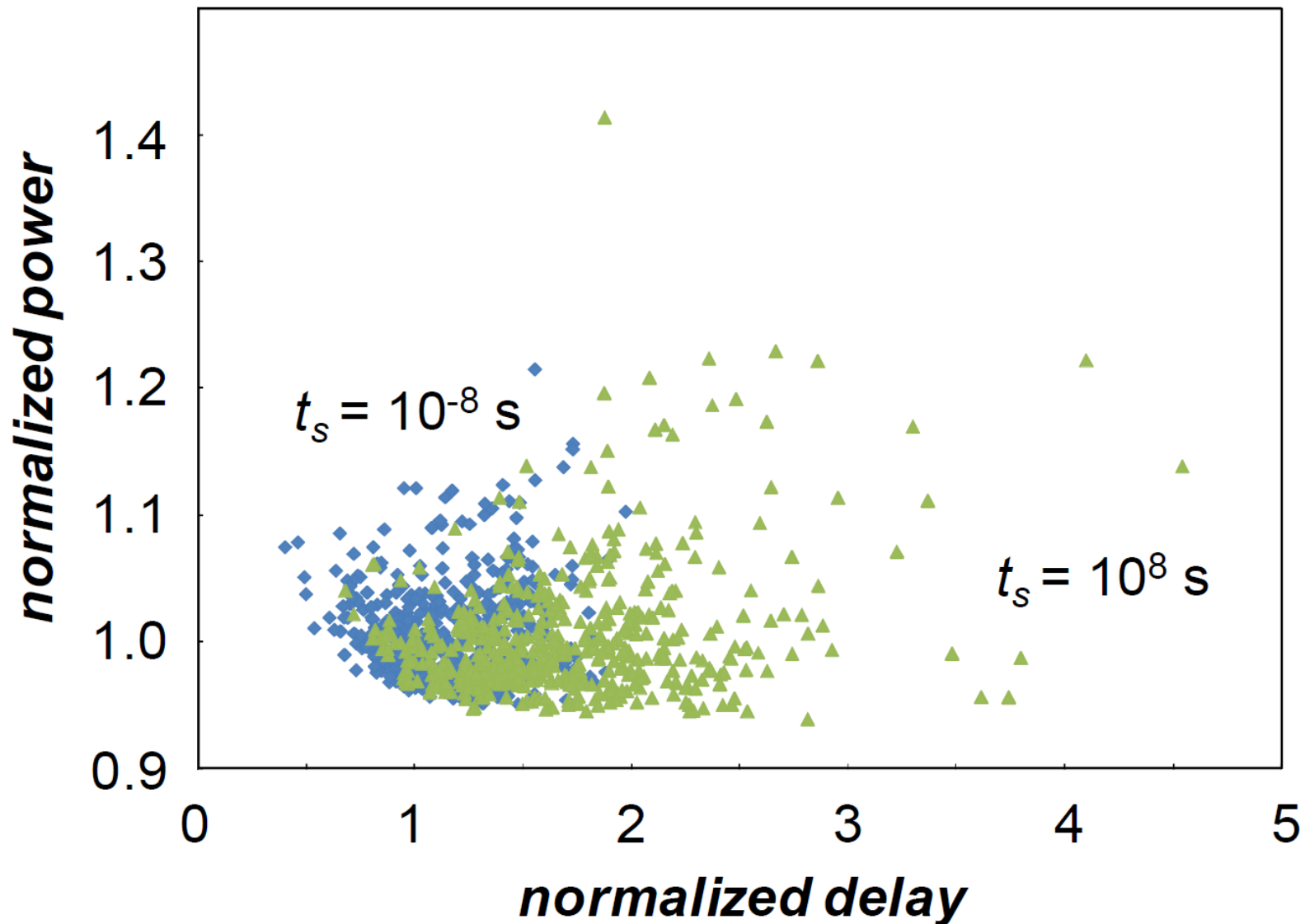
[1] Kaczer *et al.*, IRPS '11

Stochastic Impact on Circuit

In this model, jitter is independent of aging[1]
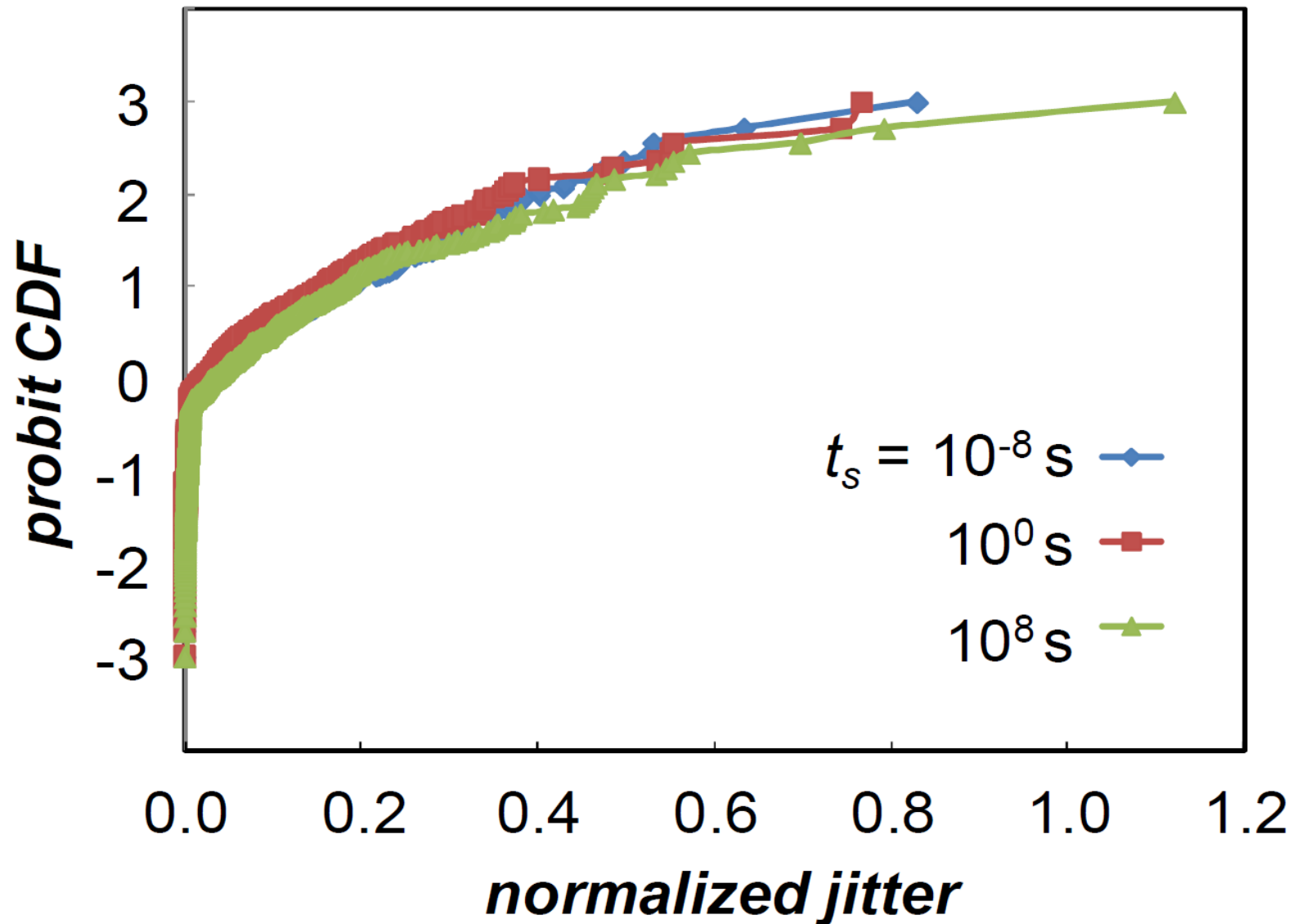
[1] Kaczer et al., IRPS '11

Stochastic Impact on Circuit

Runtime penalty of VERILOG implementation

    Example circuit with 6 MOSFETs

    15 traps per MOSFET (90 traps in total)

SPECTRE 7.1.1 + BSIM4.4	SPECTRE + Verilog-A	SPECTRE + trap-enhanced Verilog-A
16.5 s	69 s	95 s
24%	100%	138%

Conclusions

Statistics of individual defects become important in nanoscale MOSFETs

- Random number of traps
- Random distribution of traps in space
- Random defect properties
- Interaction with random discrete dopants
- Discrete stochastic charge capture and emission events

Measurement method: time dependent defect spectroscopy (TDDS)

- Allows extraction of $\bar{\tau}_e$, $\bar{\tau}_c$, and step-height over very wide range
- Allows simultaneous analysis of multiple defects

Fundamental implications on device reliability

- Lifetime is a stochastic quantity
- Lifetime will have a huge variance

Circuit modeling

- Capture expectation values using distributed RC elements in SPICE
- Capture all features using a VERILOG implementation

This work would have been impossible without the support of ...

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Longstanding collaboration, tons of measurement data, discussion/theory

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Financial support, measurement data, and discussion

R. Minixhofer and H. Enichlmair (austriamicrosystems)

Financial support, measurement data, and discussion

H. Reisinger, C. Schlünder, and W. Gustin (Infineon Munich)

Ultra fast measurement data, discussion/theory

'Reliability community'

P. Lenahan, J. Campbell, G. Bersuker, V. Huard, N. Mielke, A.T. Krishnan, ...

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